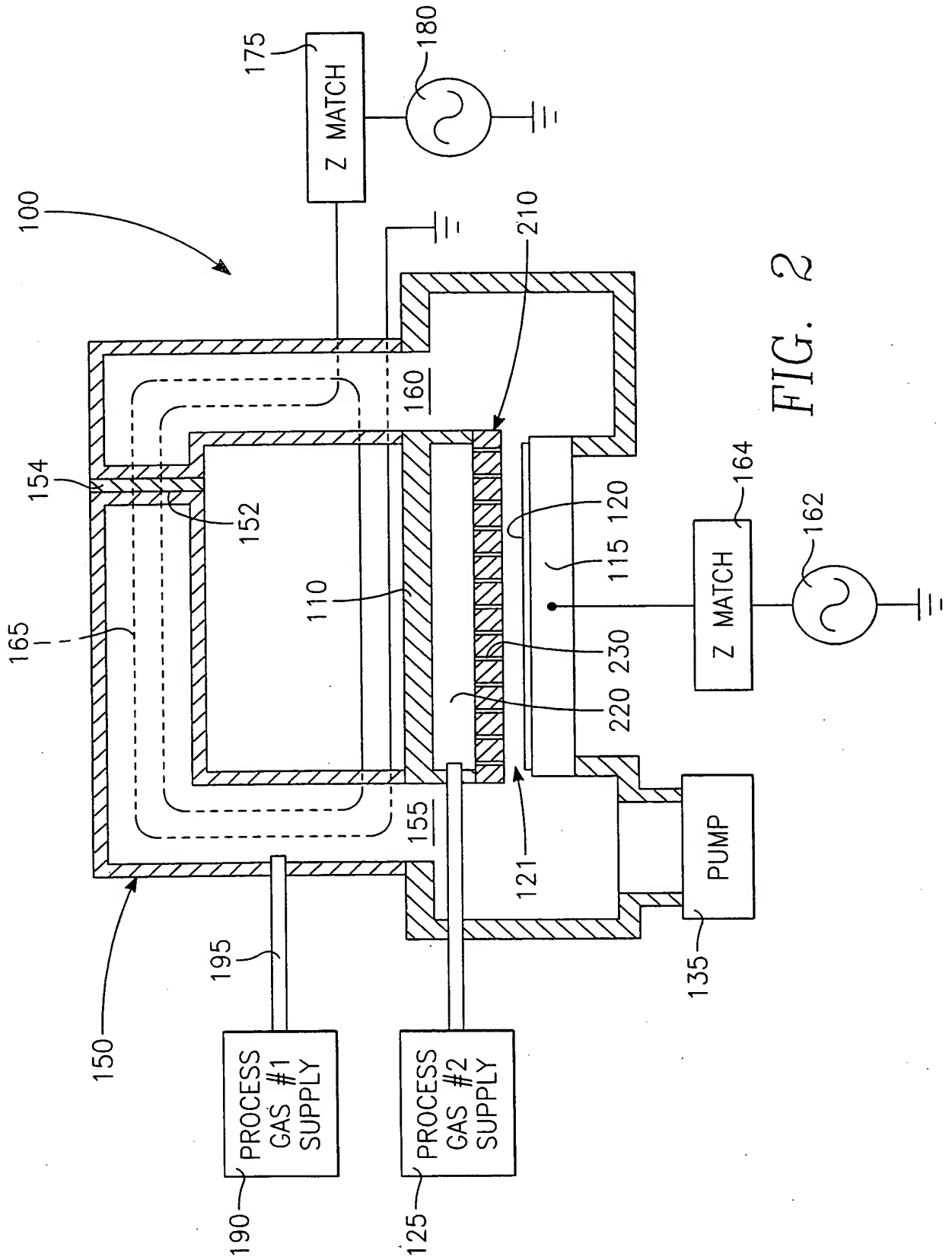
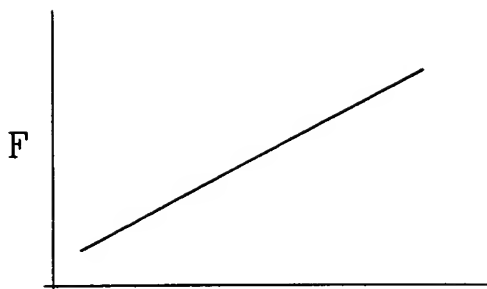


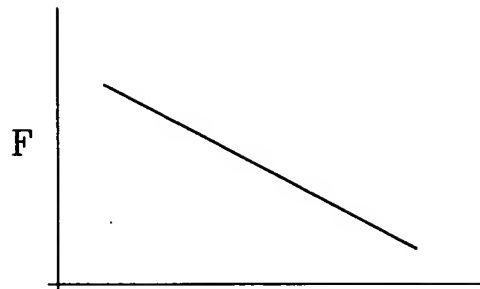
FIG. 1





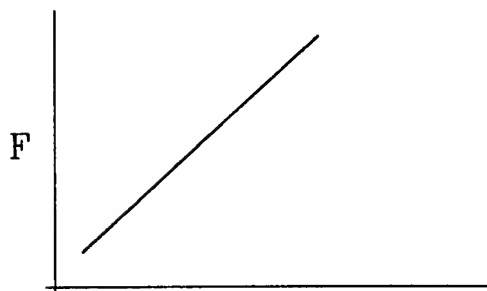
GAP DISTANCE

FIG. 3



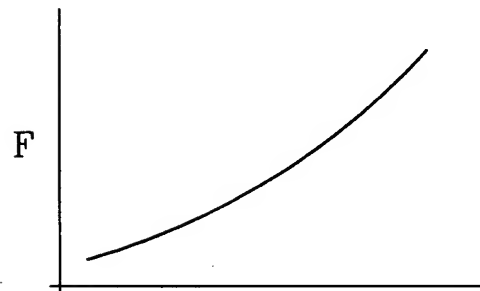
BIAS POWER

FIG. 4



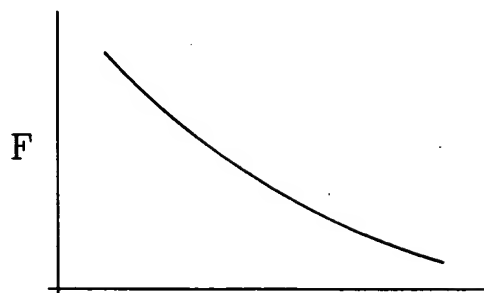
SOURCE POWER

FIG. 5



CHAMBER PRESSURE

FIG. 6



Ar PARTIAL PRESSURE

FIG. 7

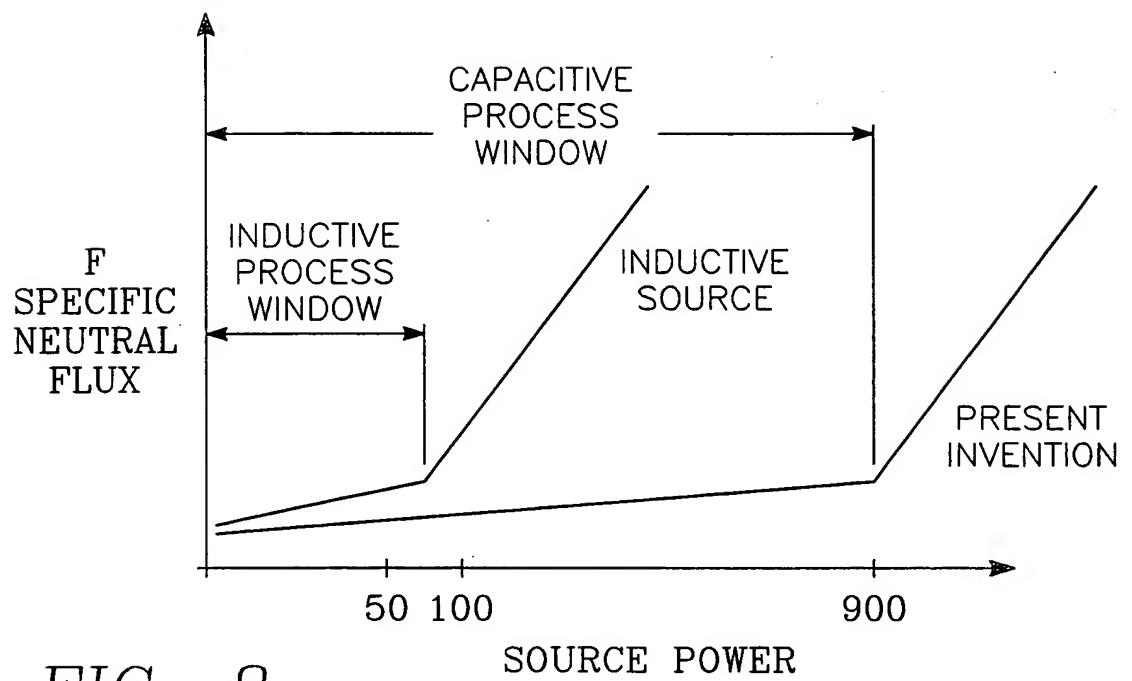


FIG. 8

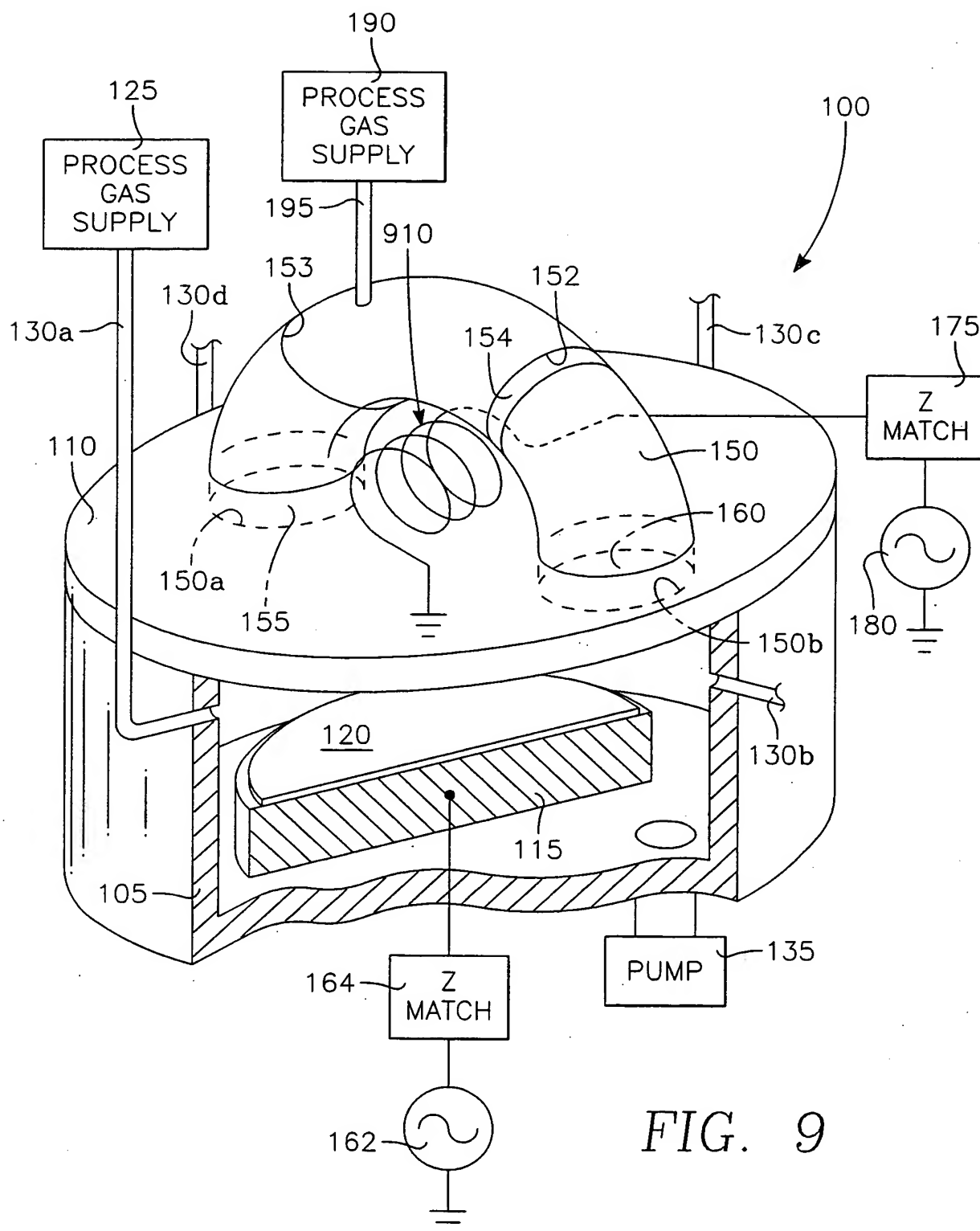
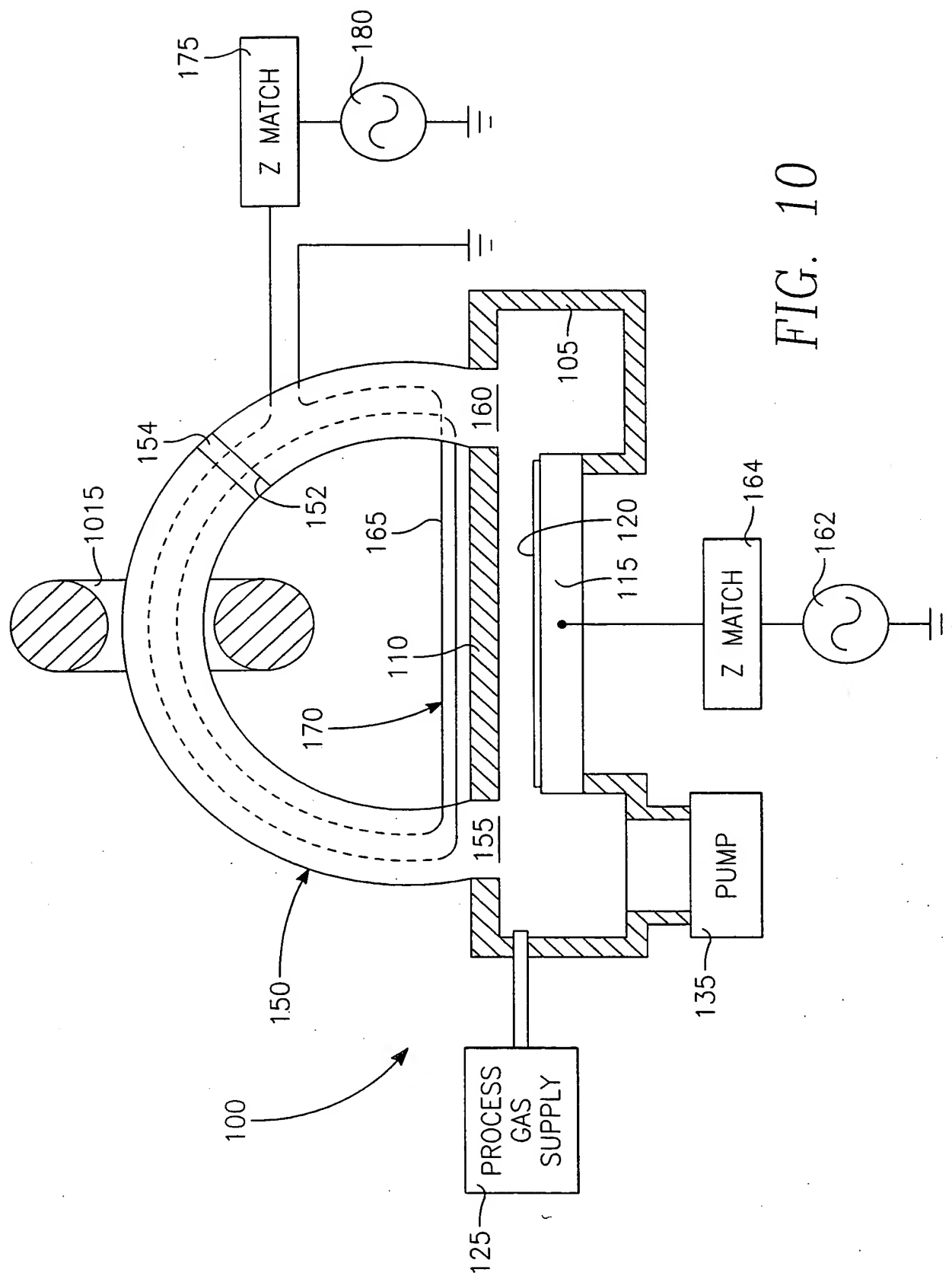


FIG. 9



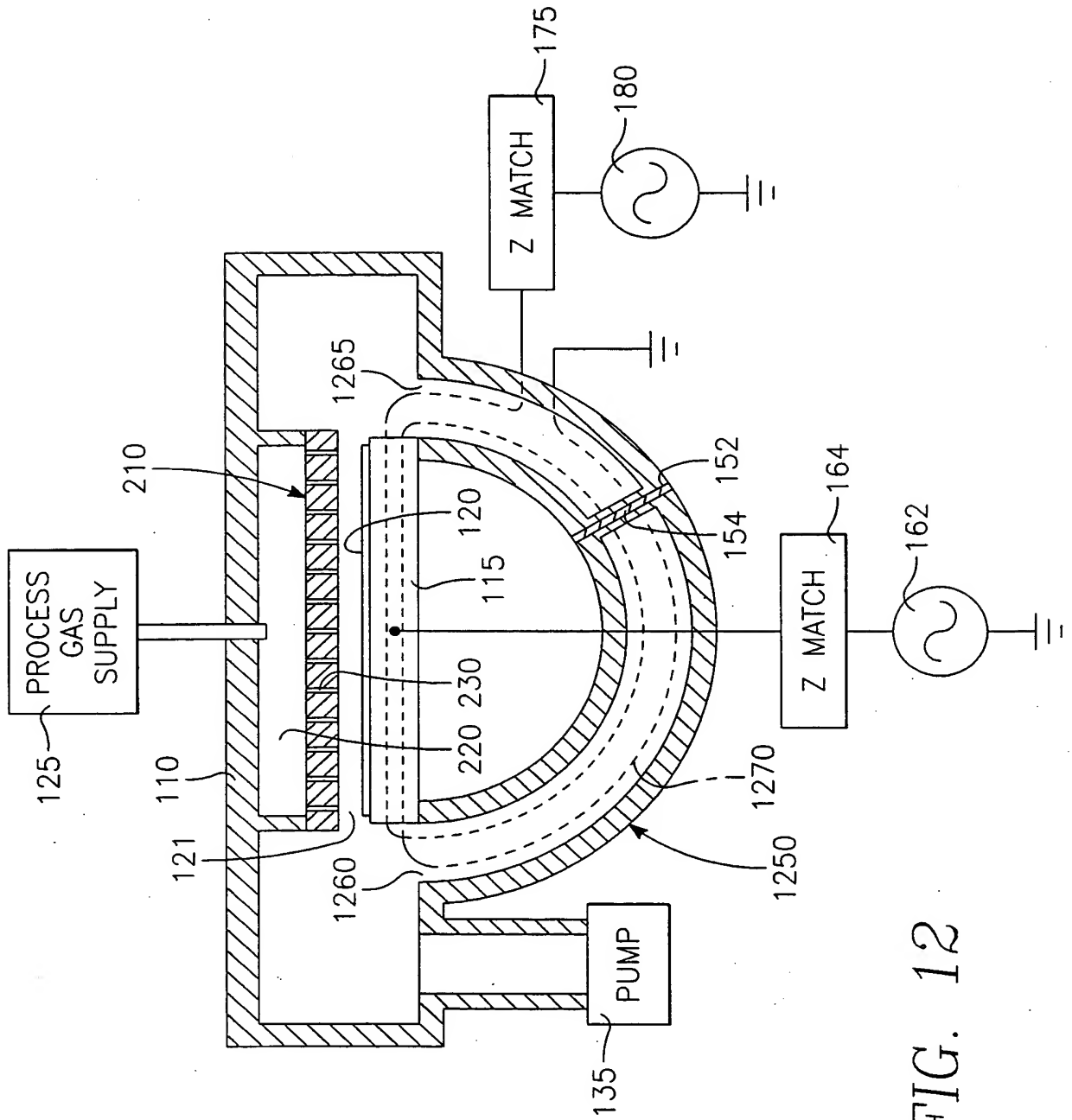


FIG. 12

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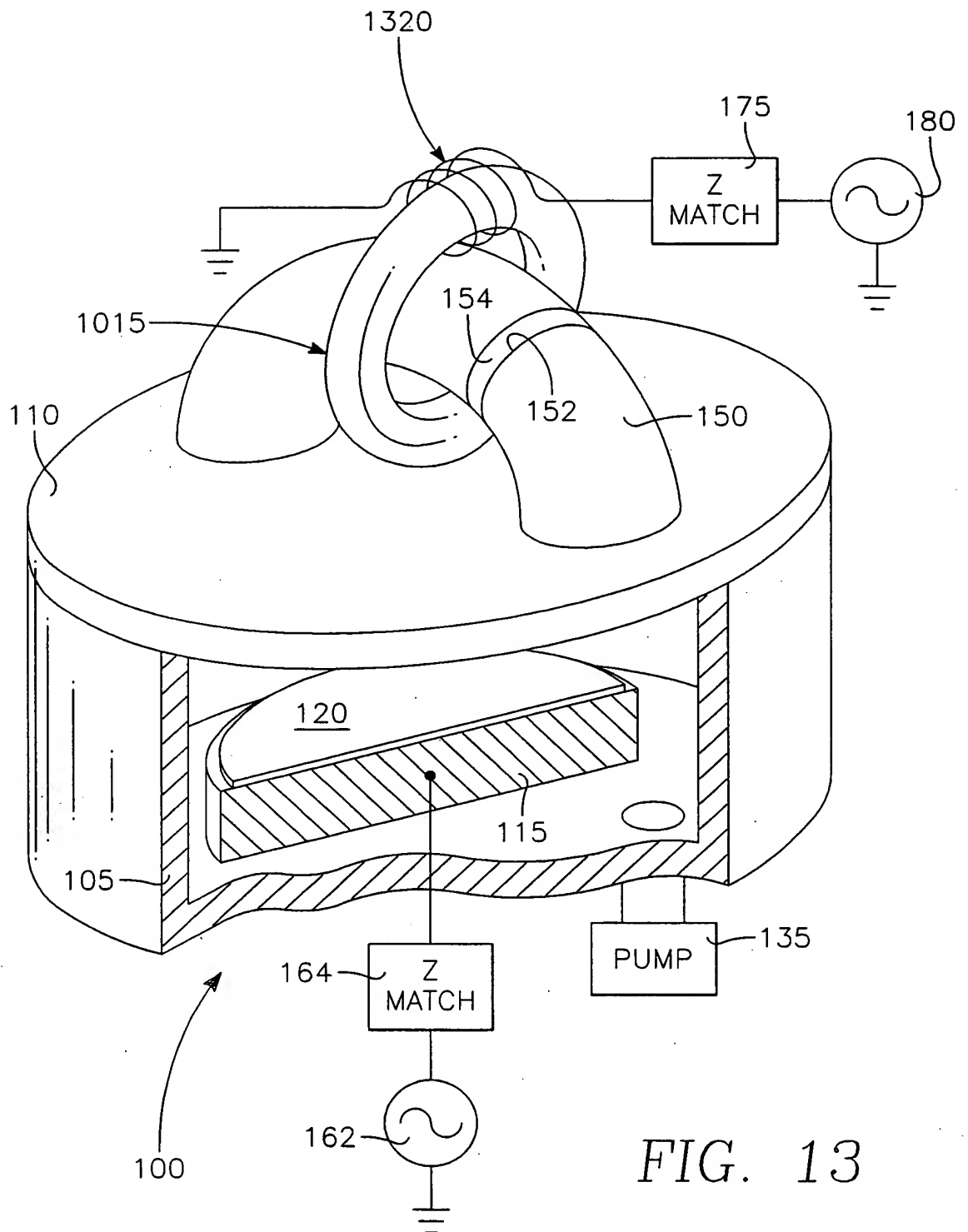
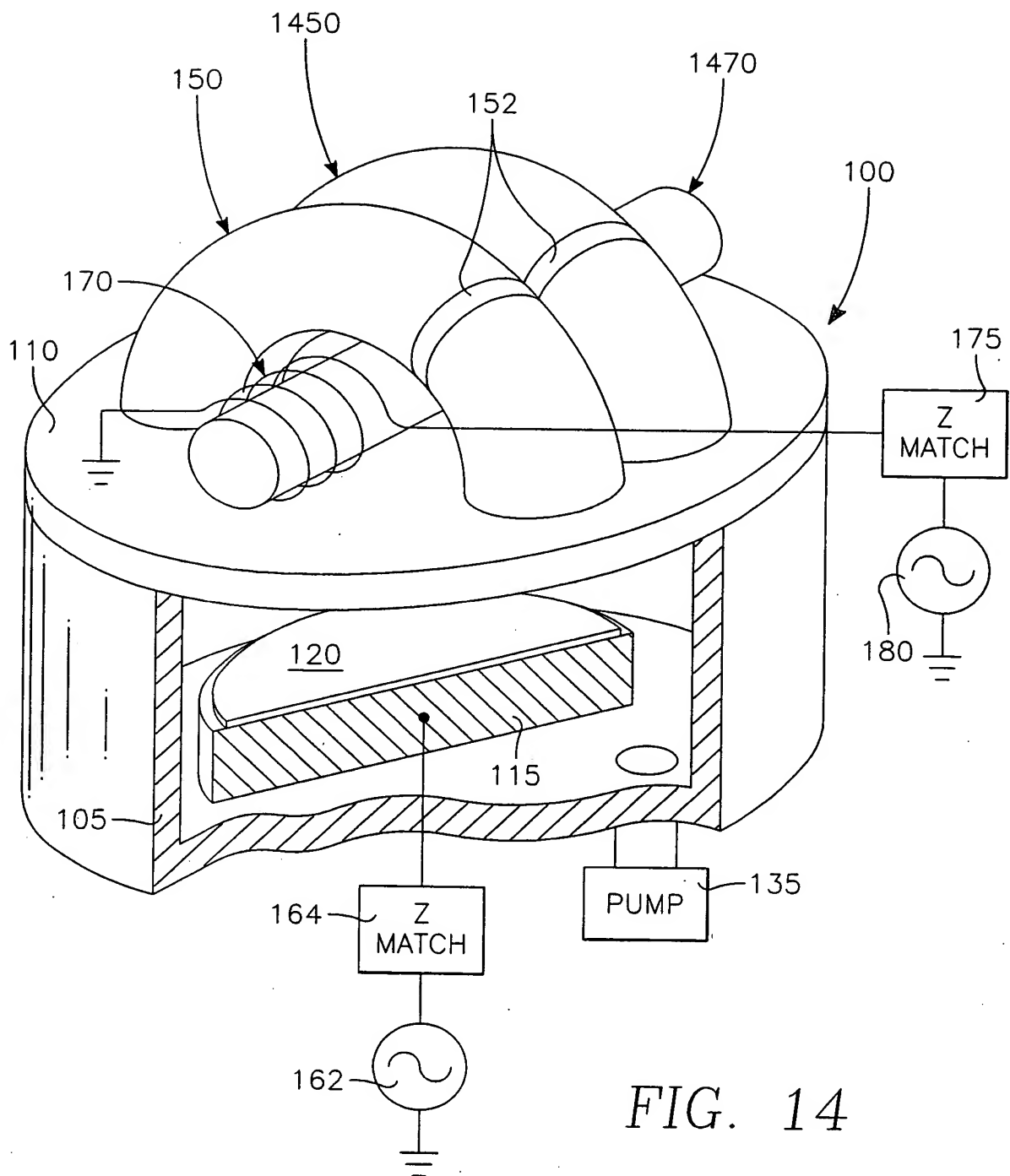


FIG. 13



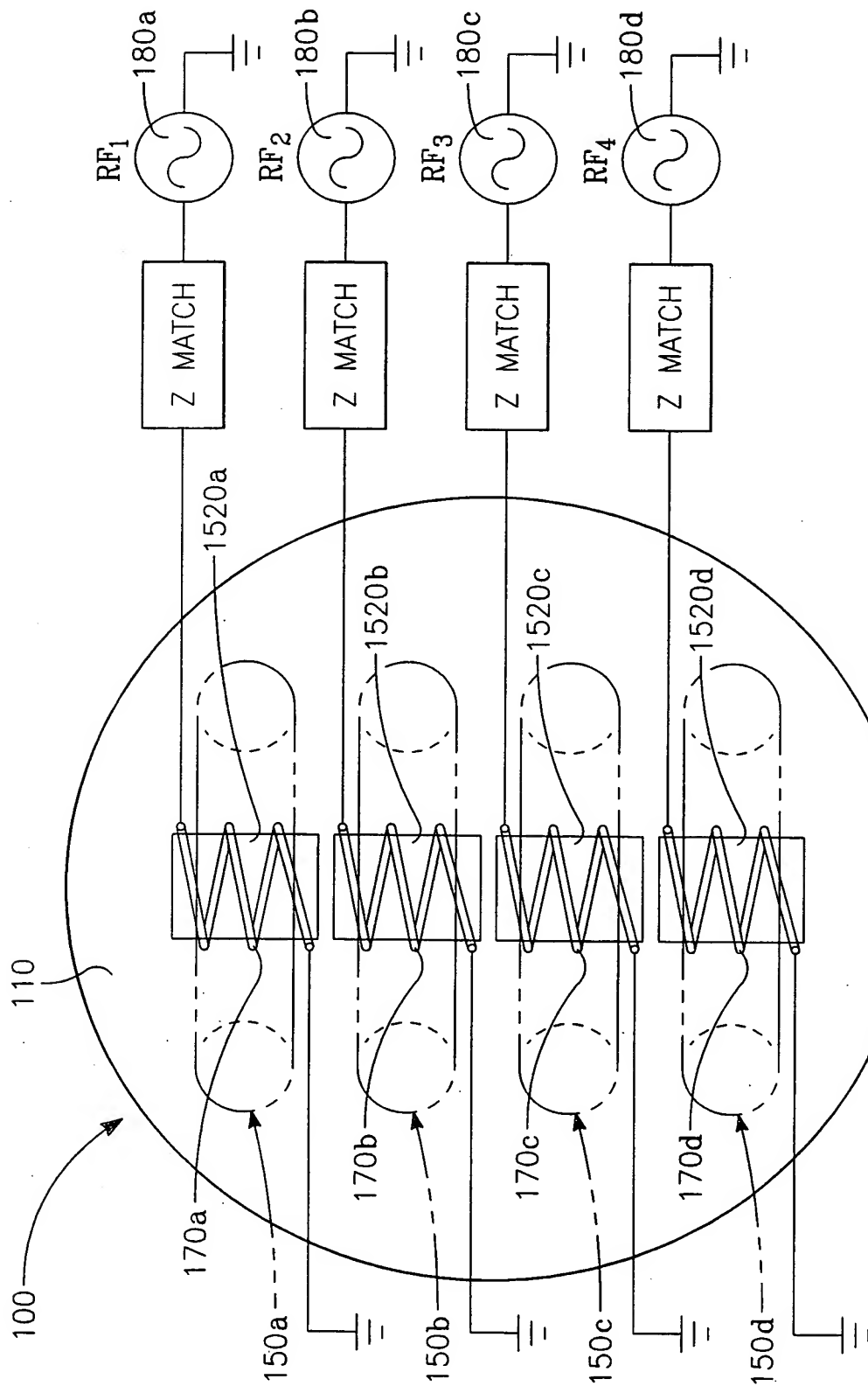


FIG. 15

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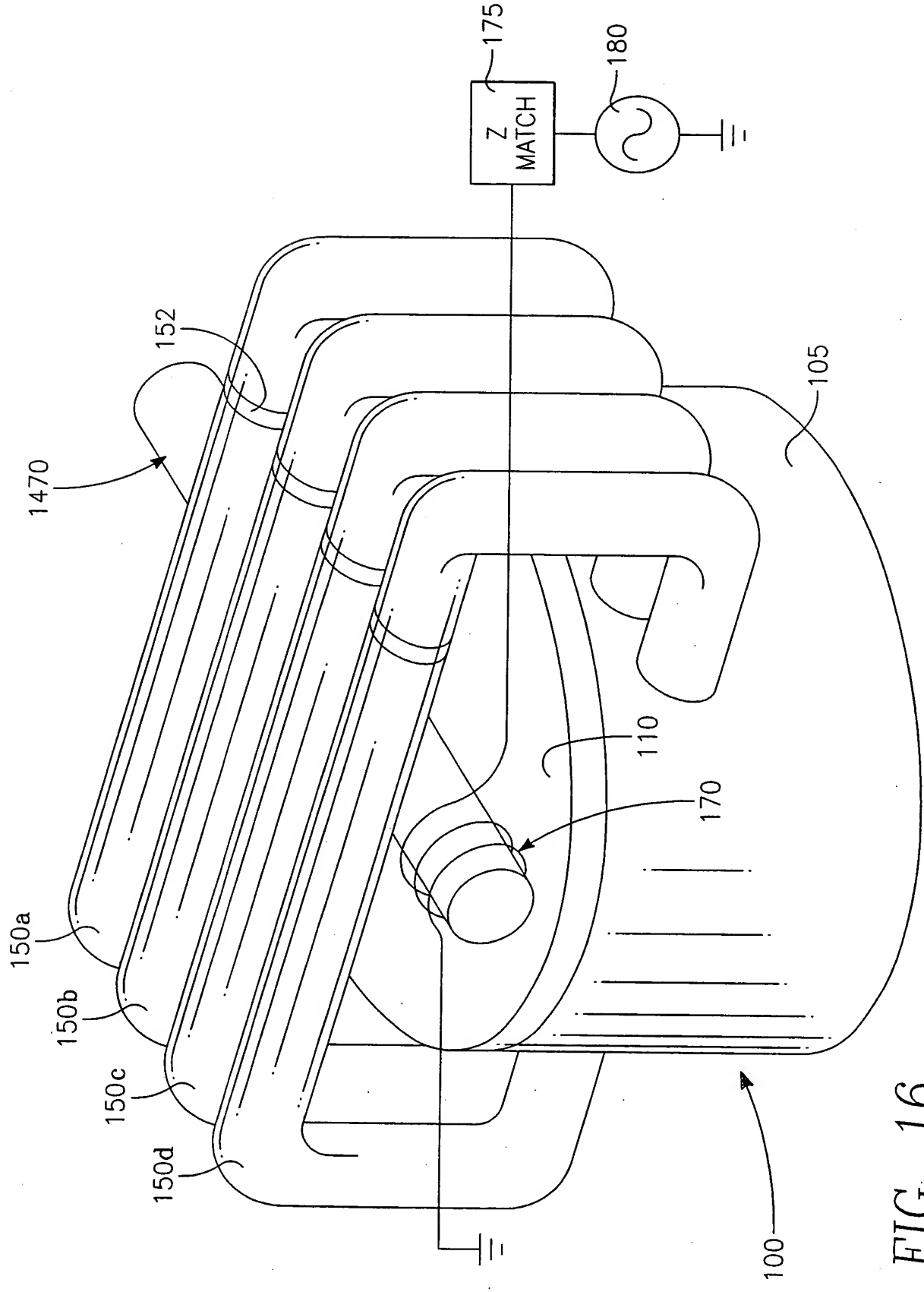


FIG. 16

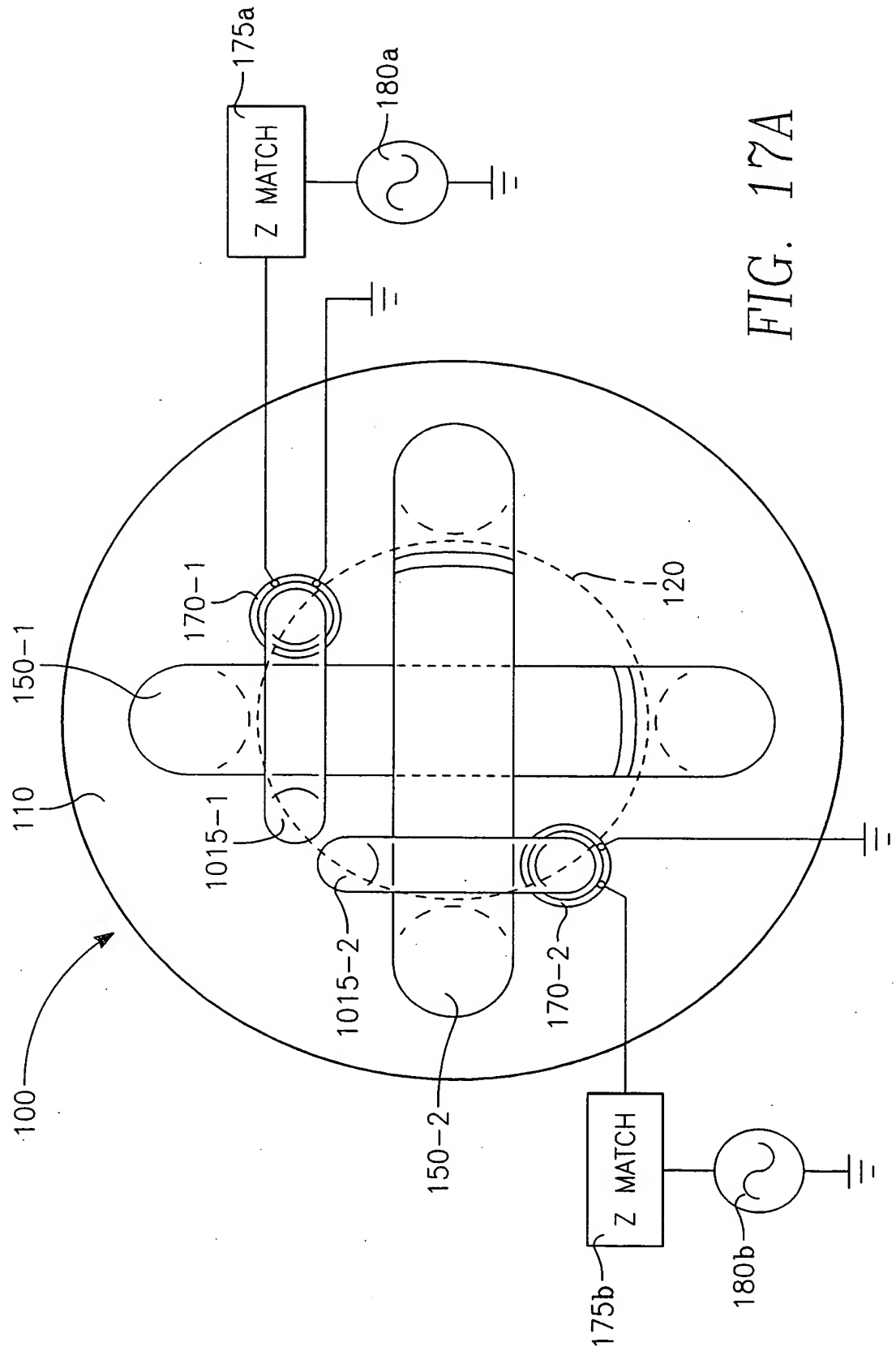


FIG. 17A

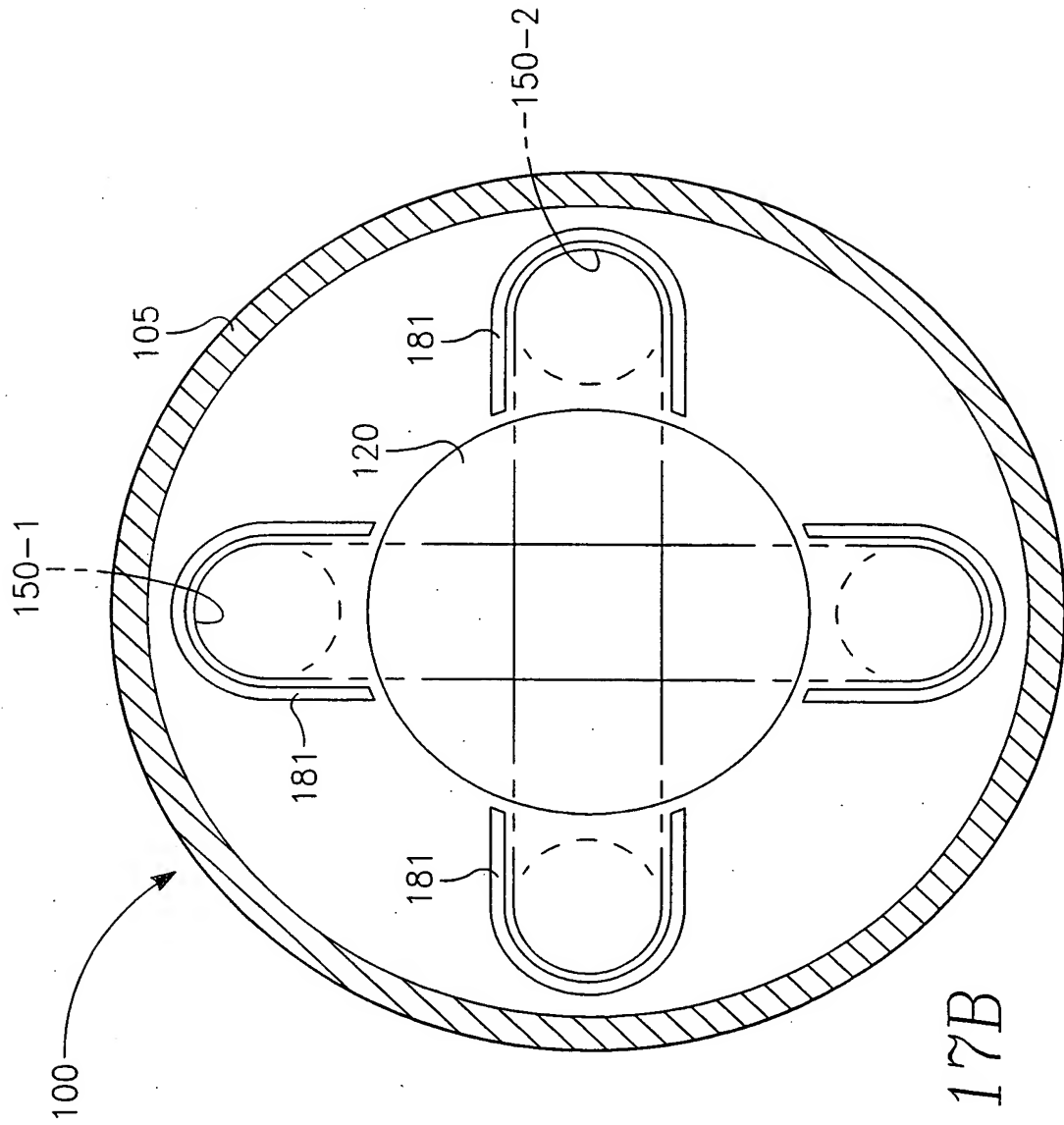
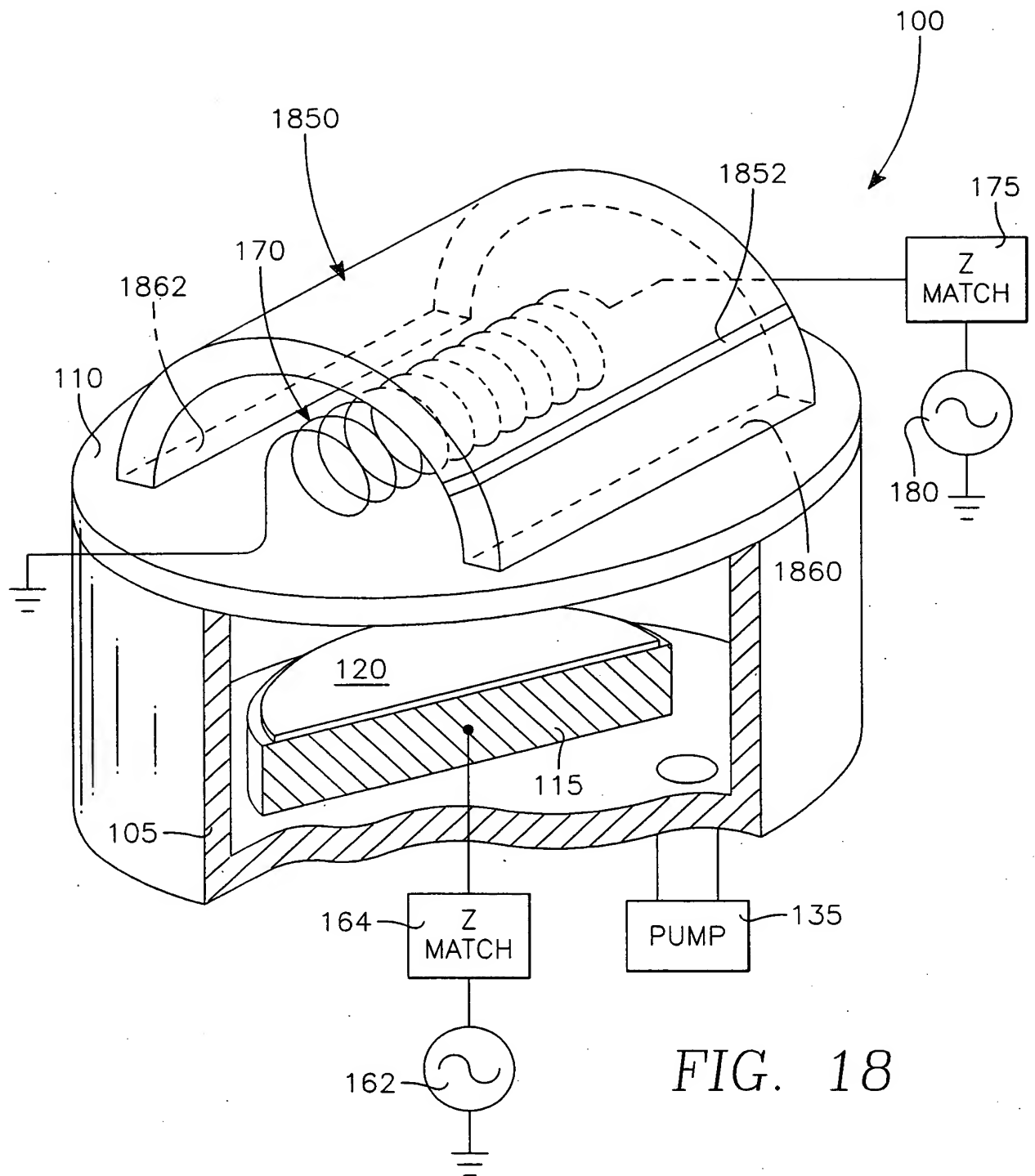
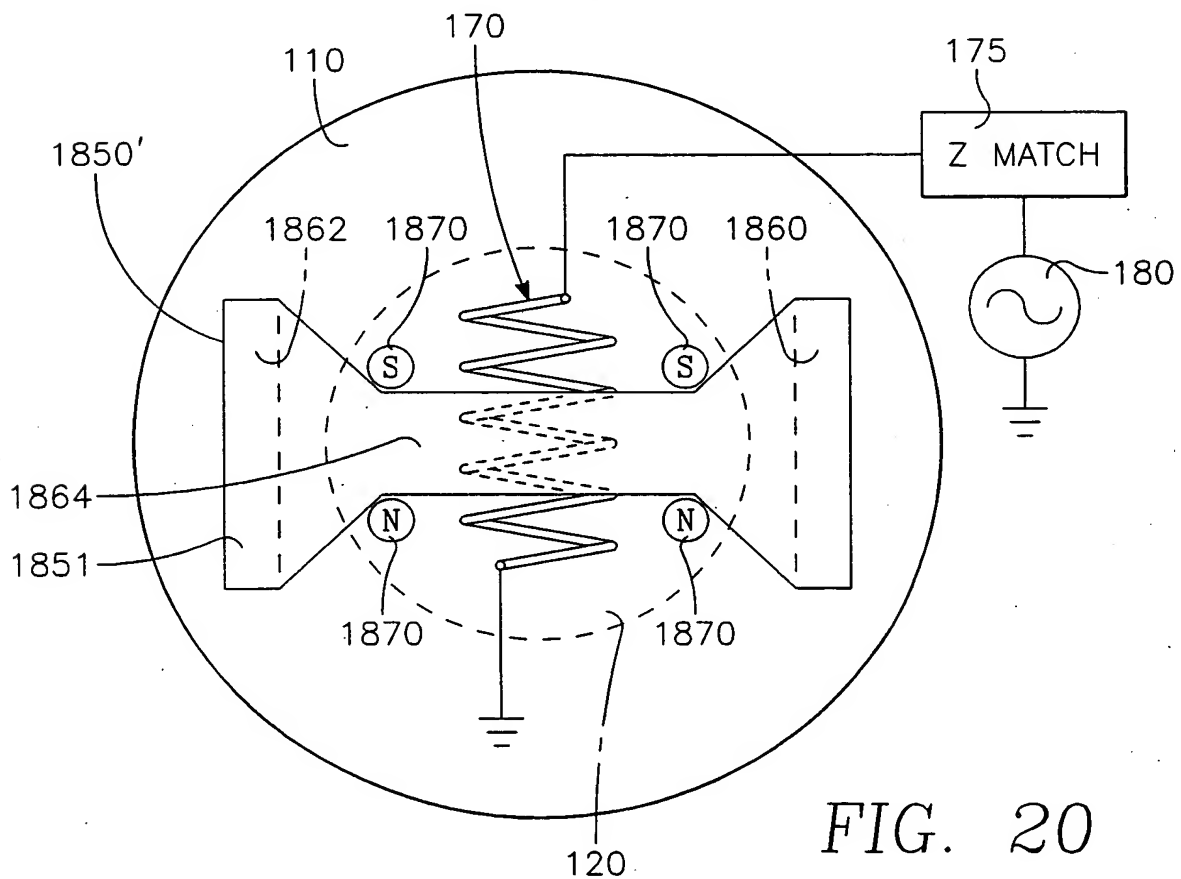
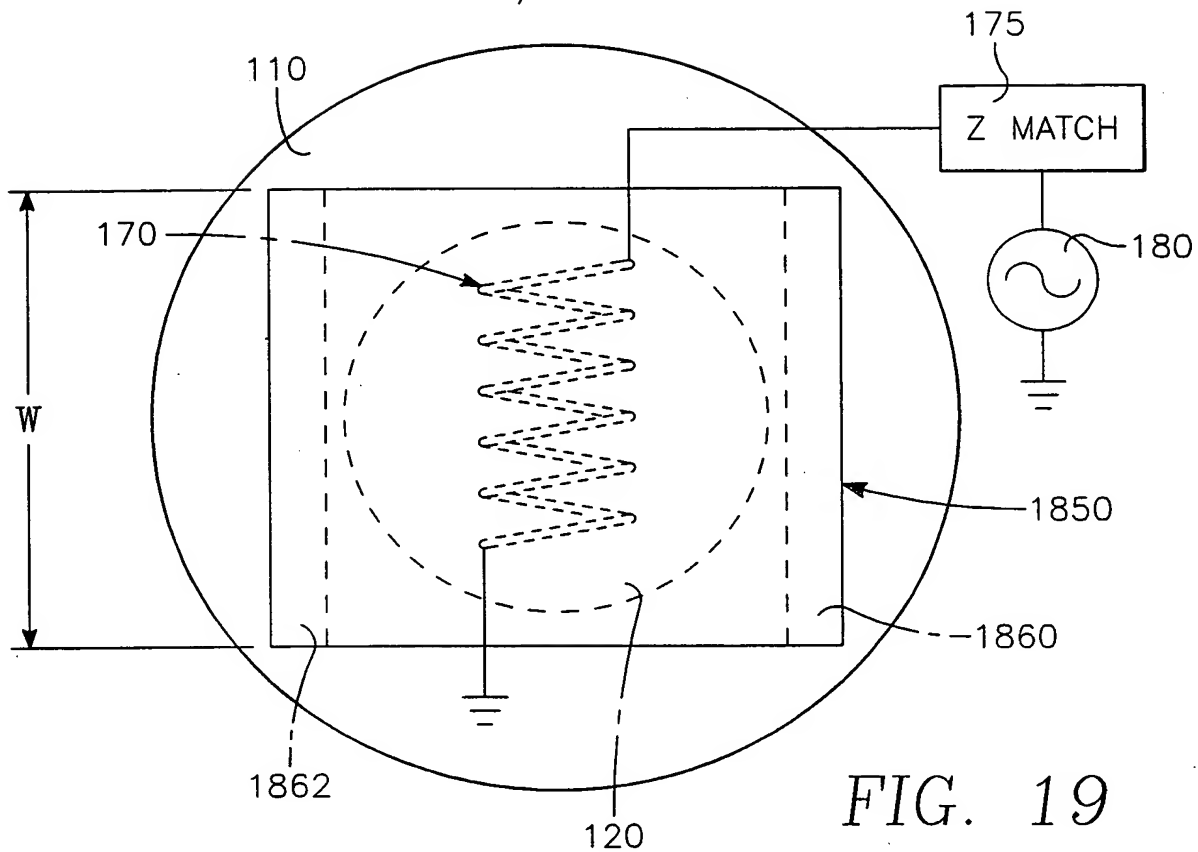


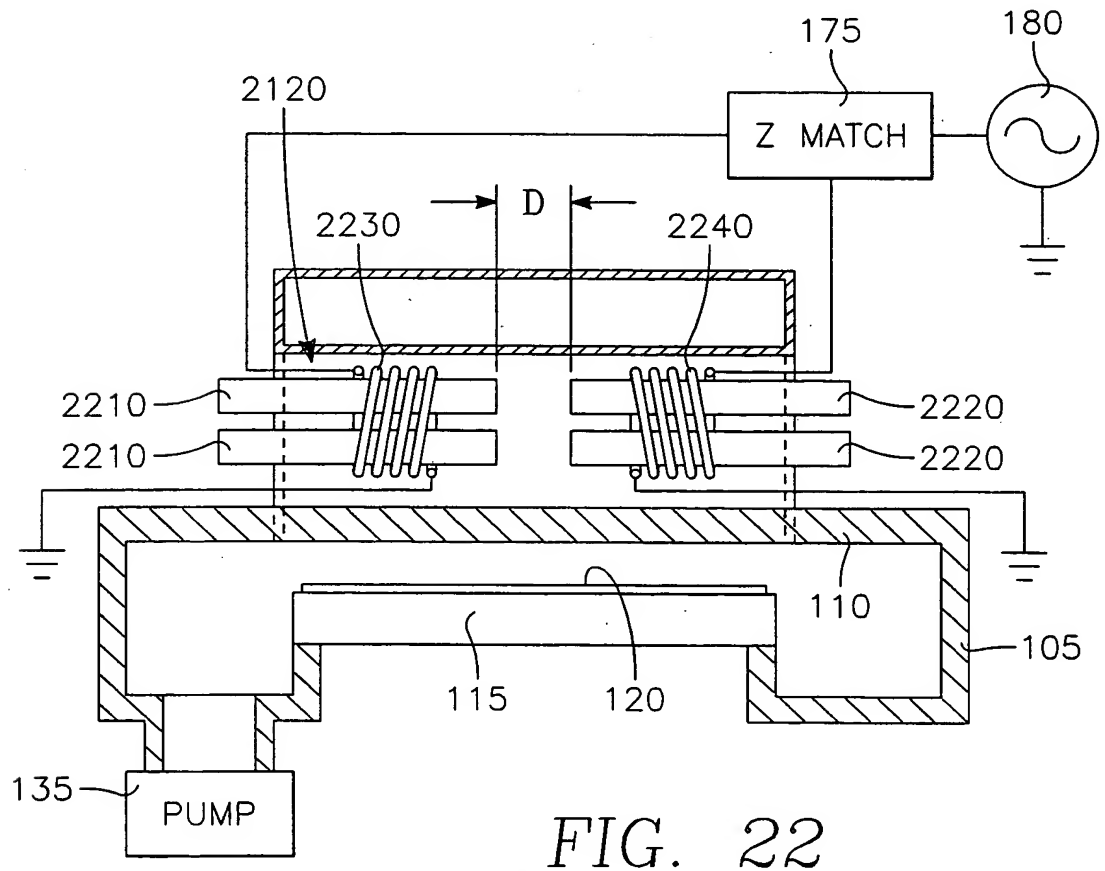
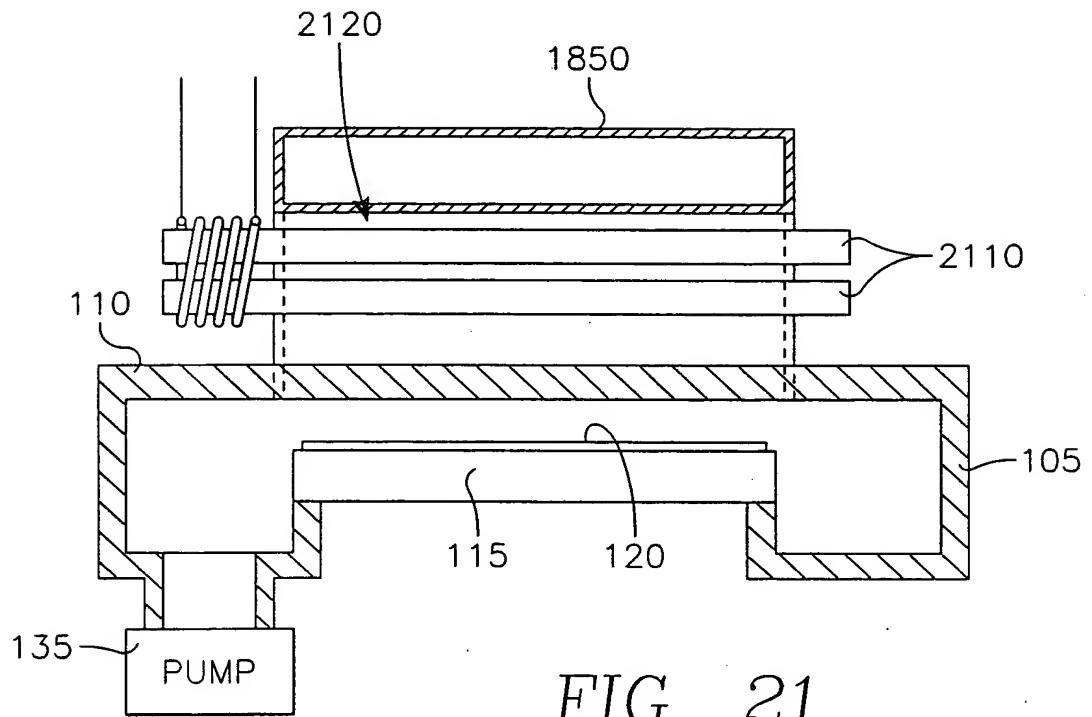
FIG. 17B



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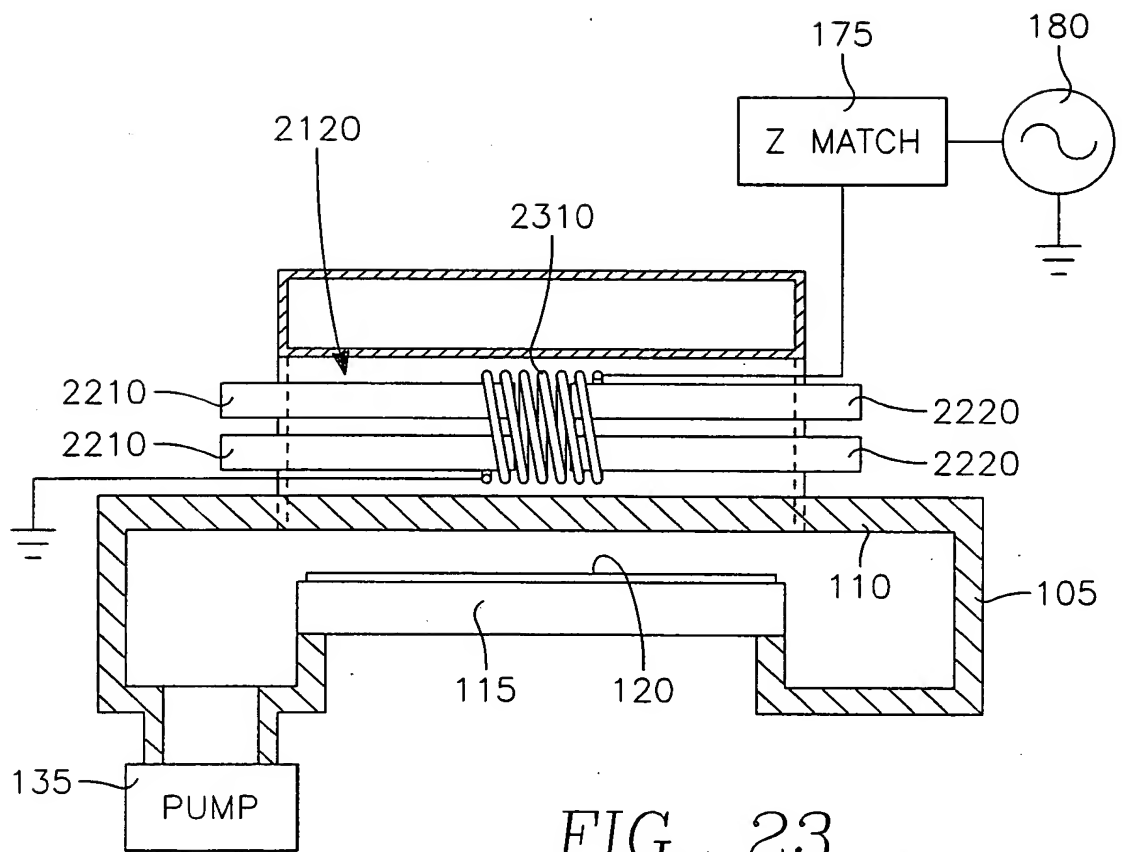


FIG. 23

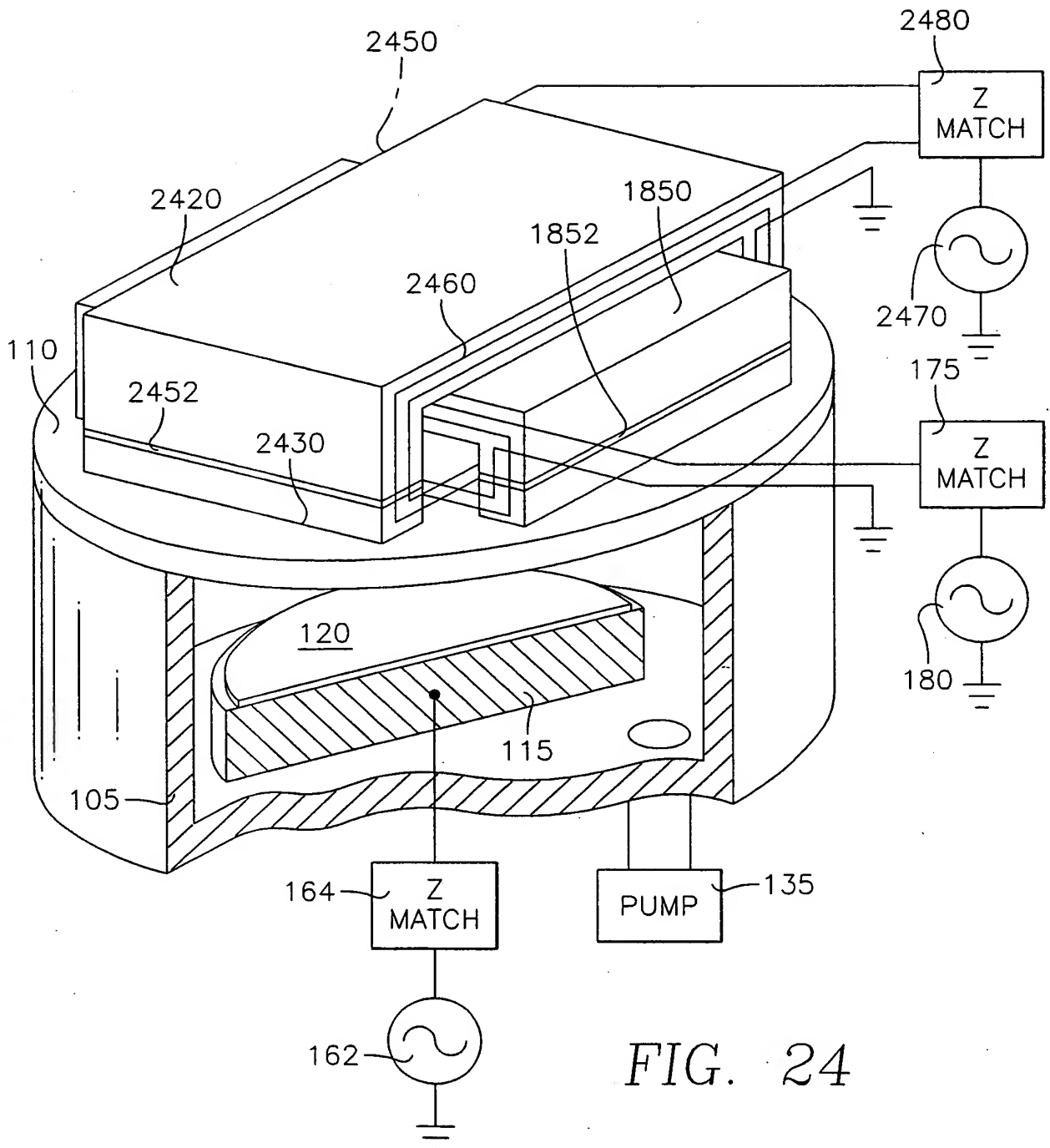


FIG. 24

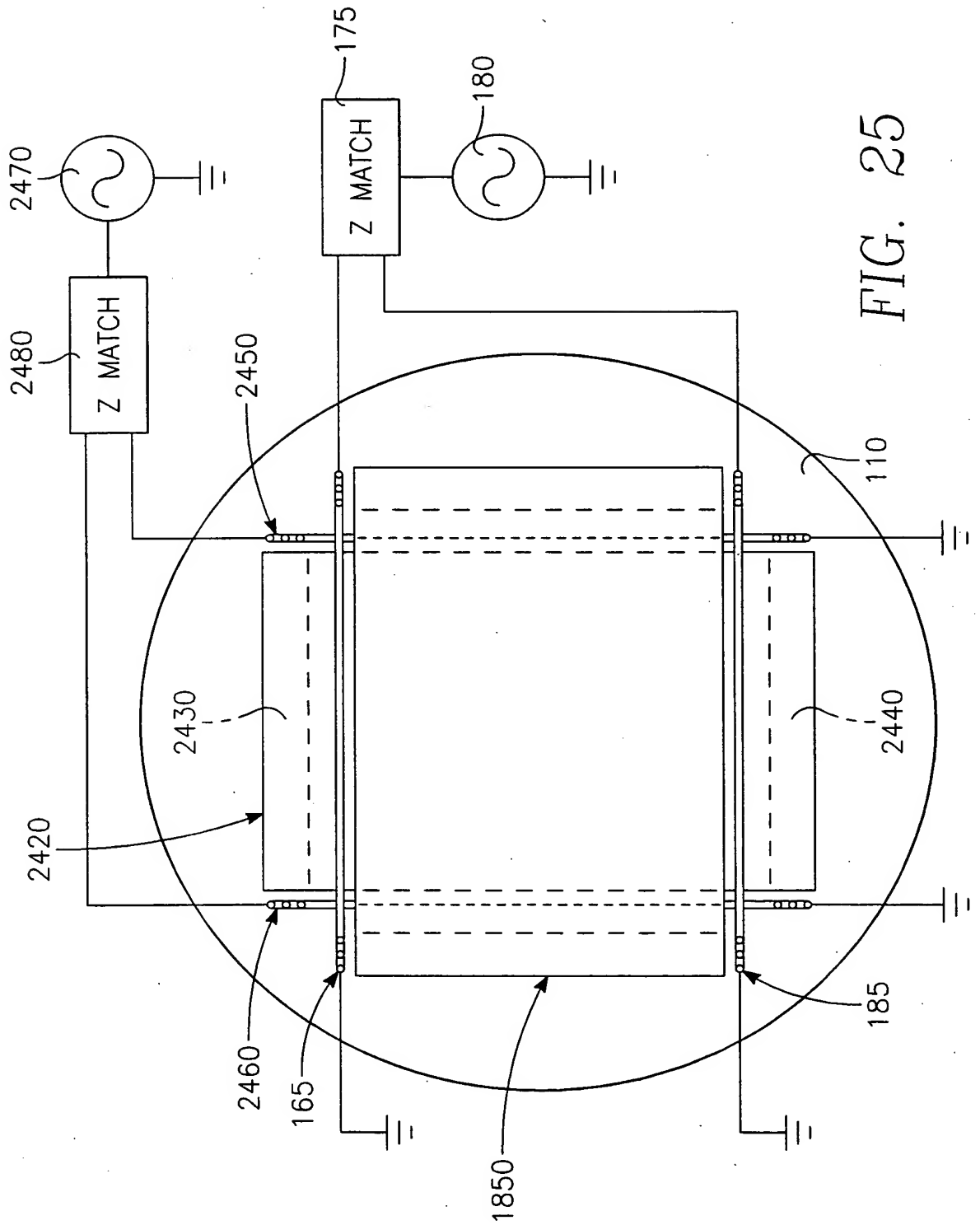


FIG. 25

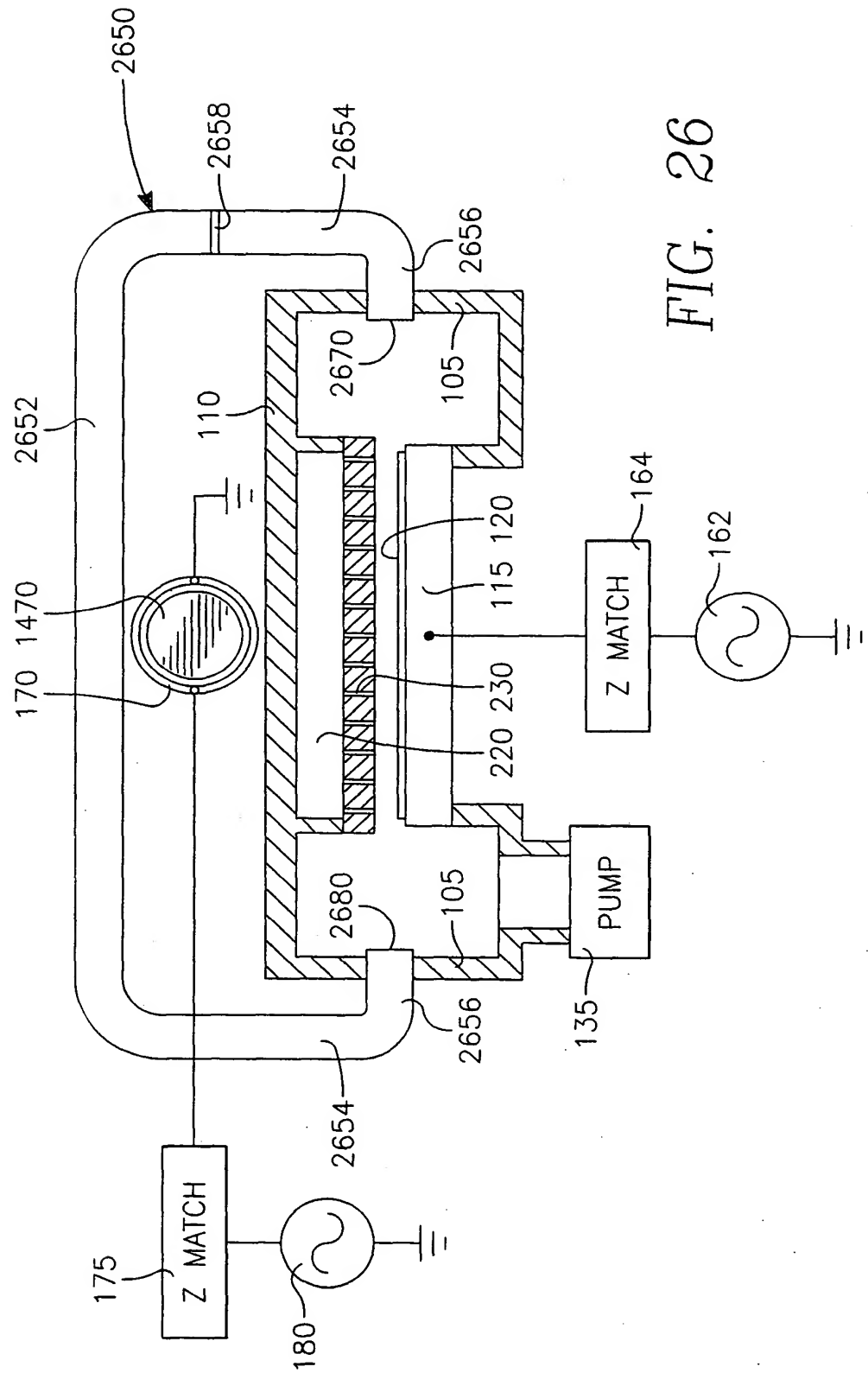


FIG. 26

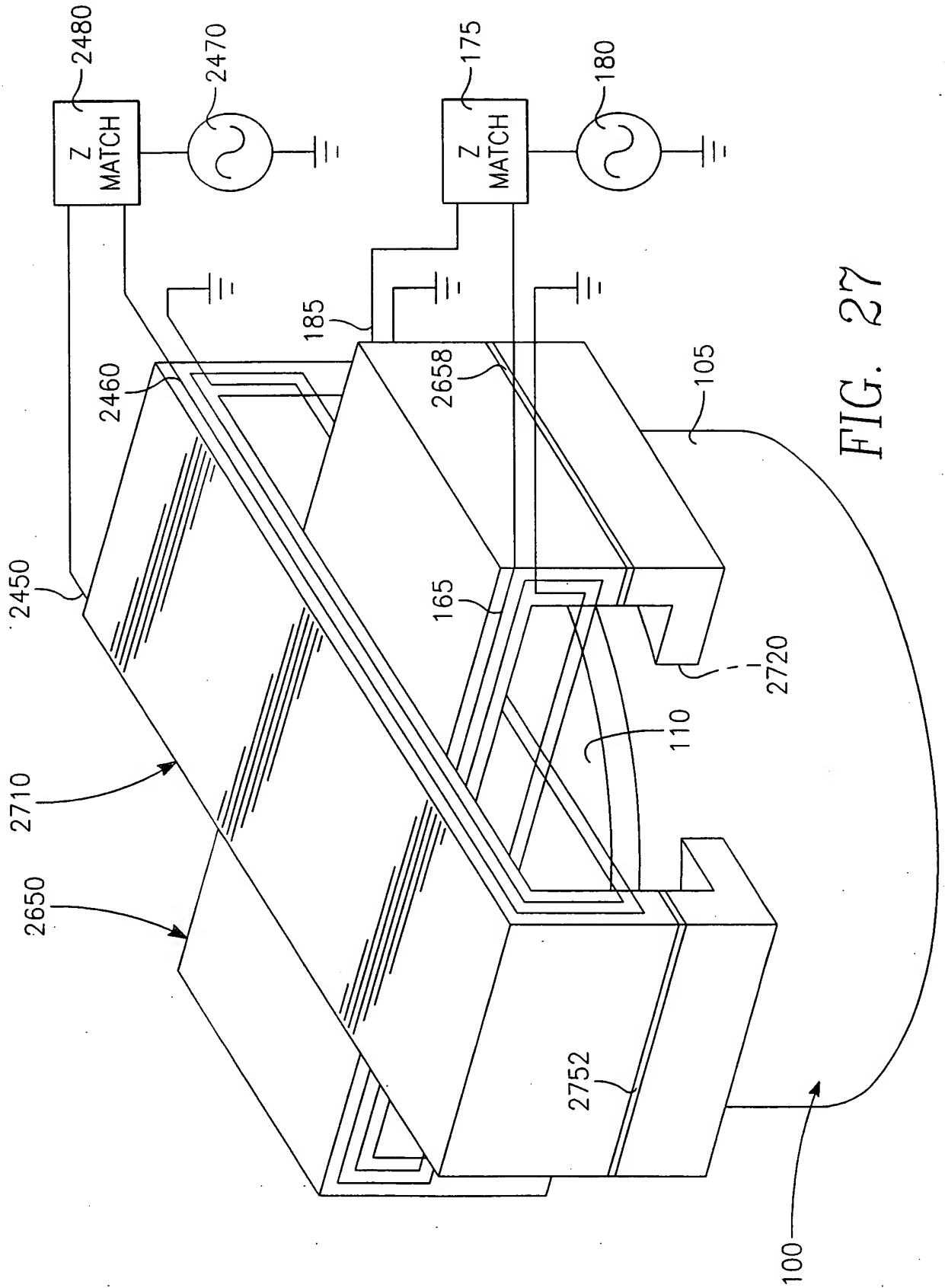
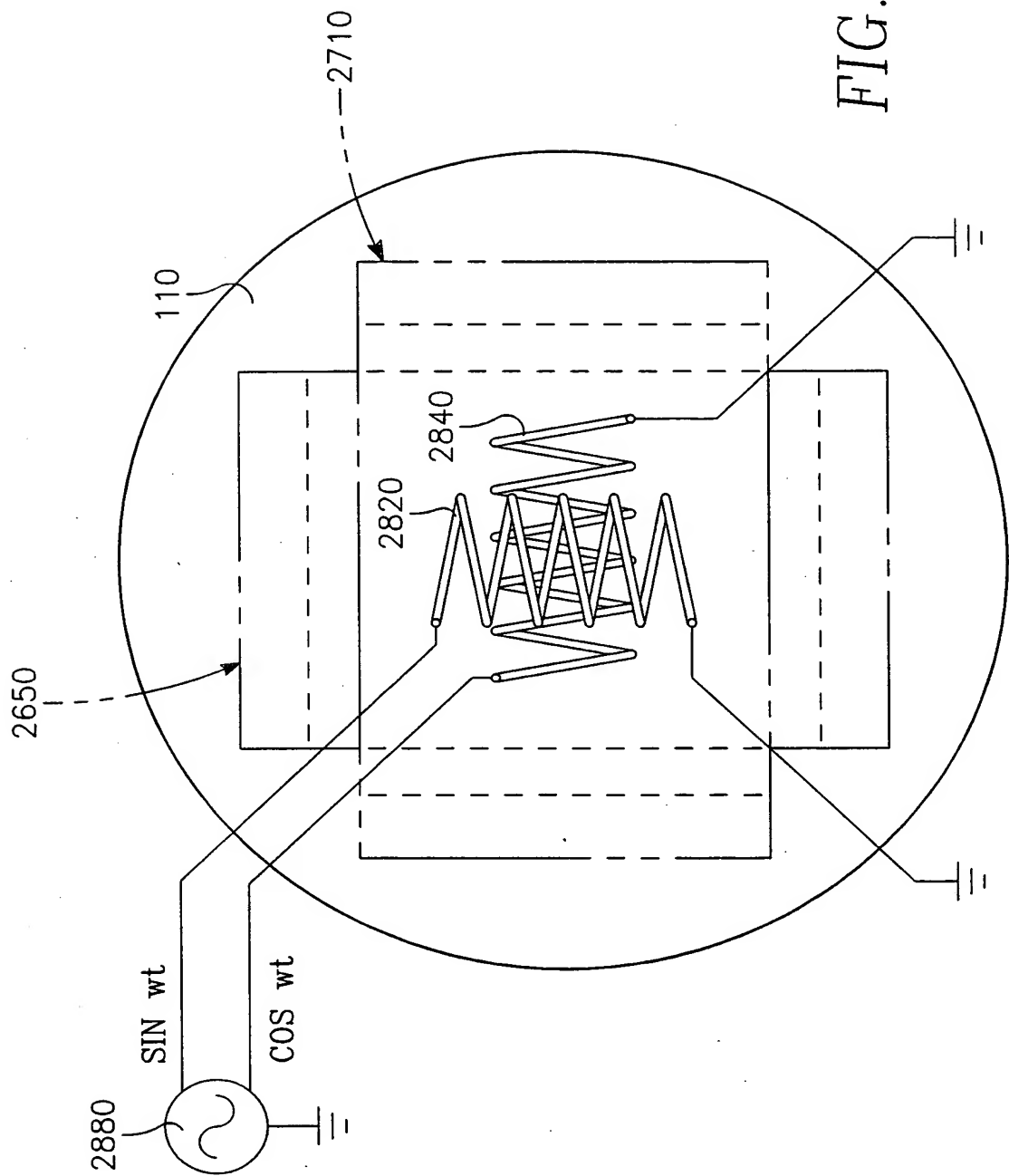


FIG. 27



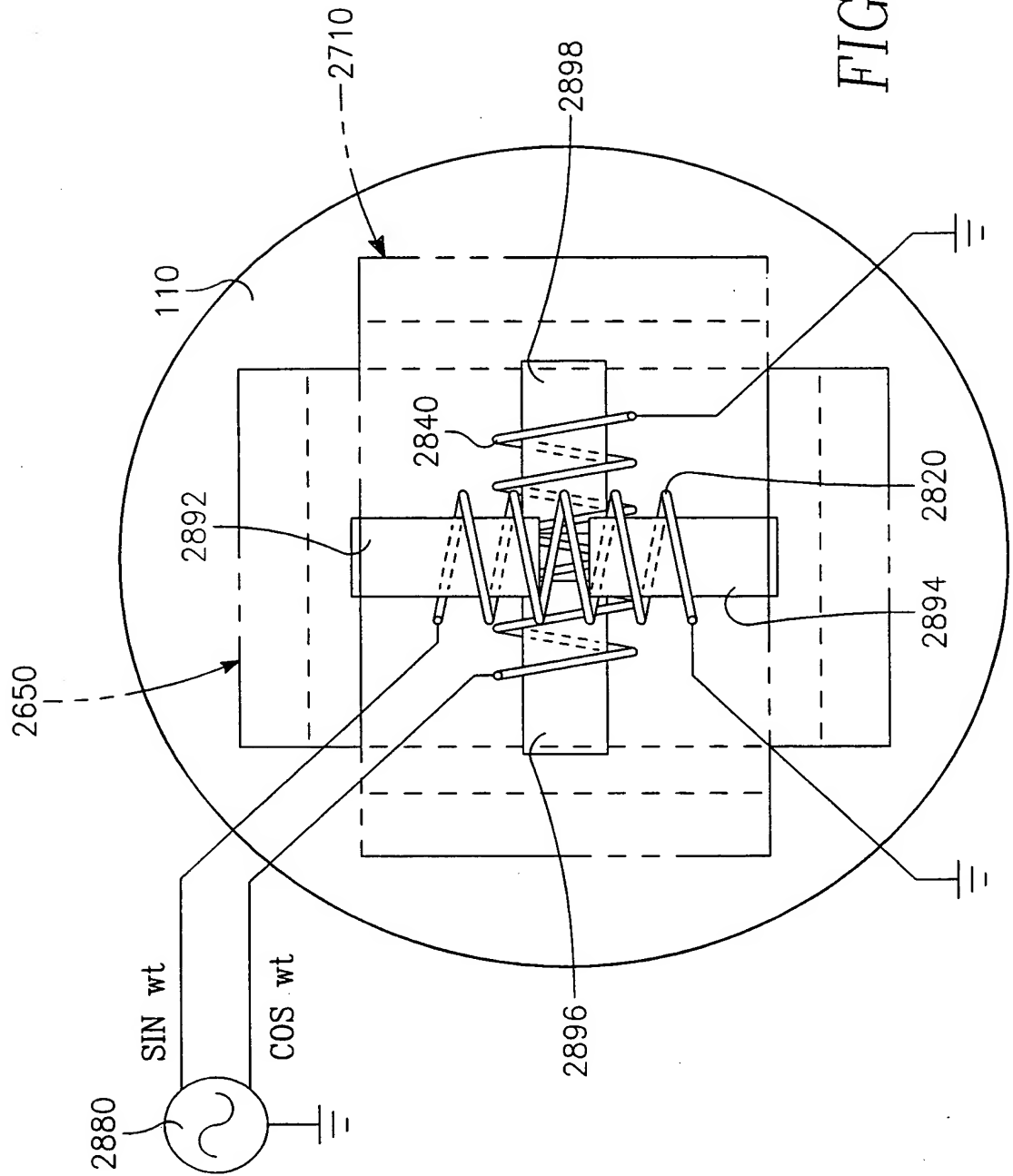
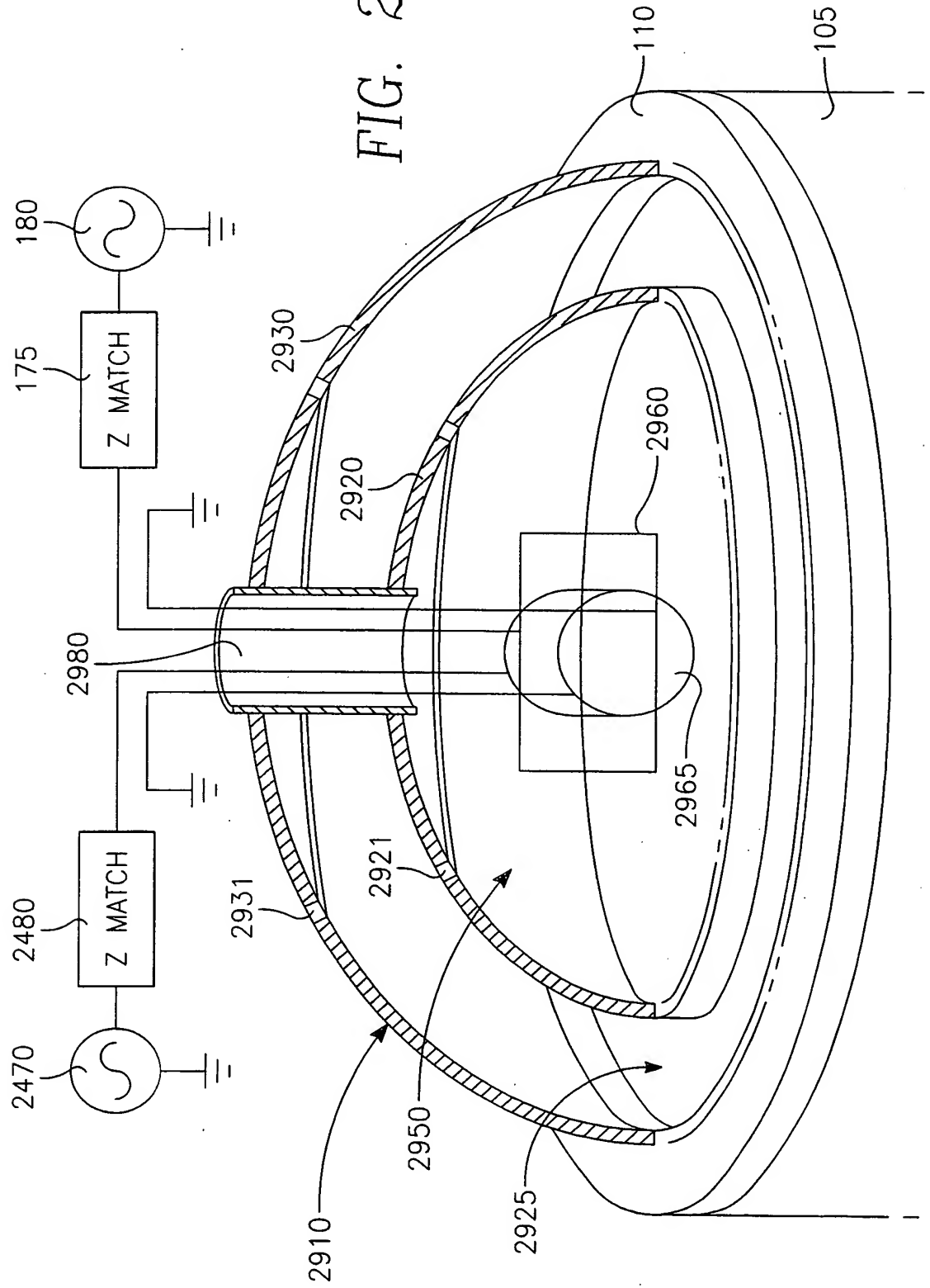


FIG. 29



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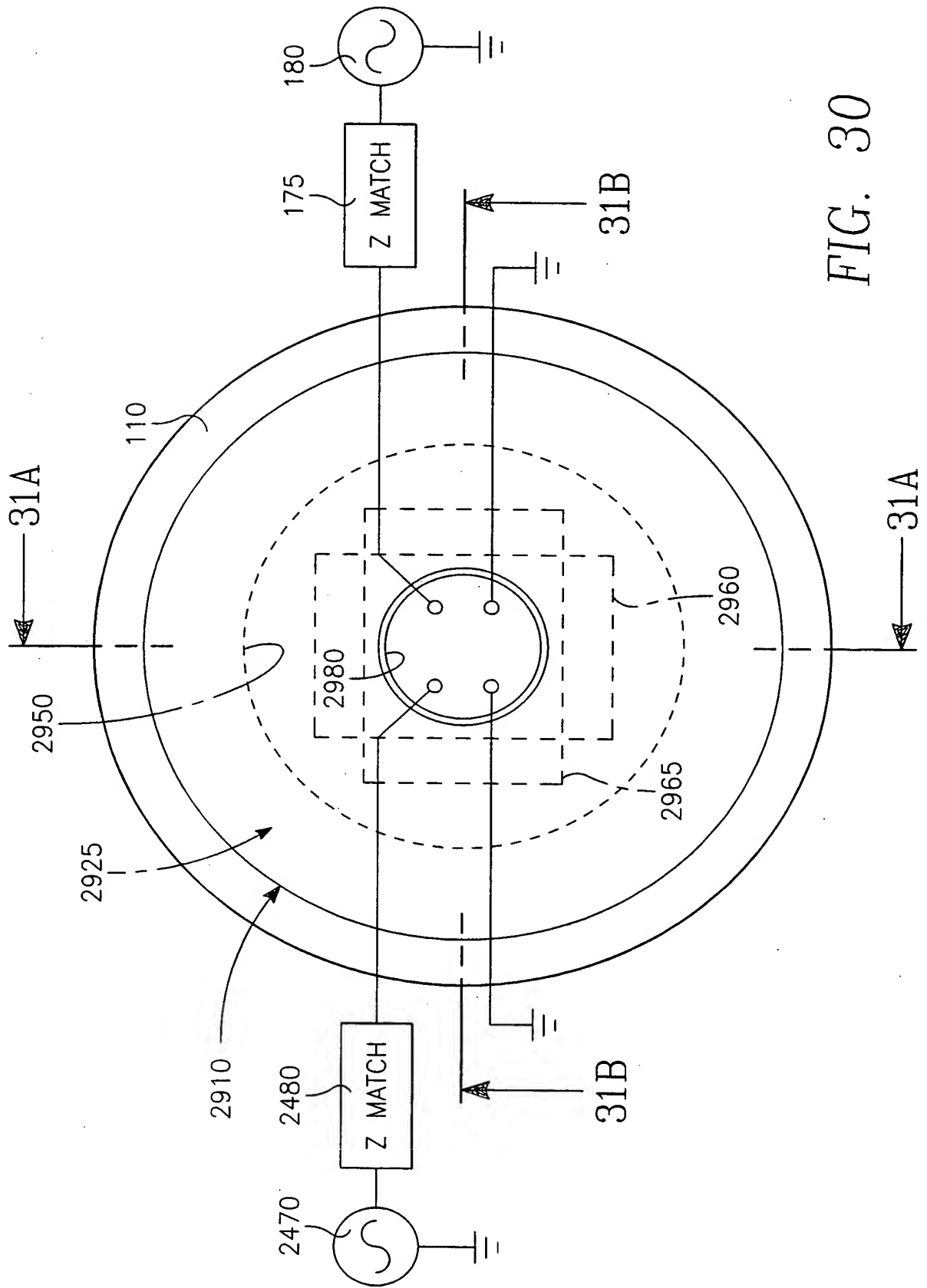


FIG. 30

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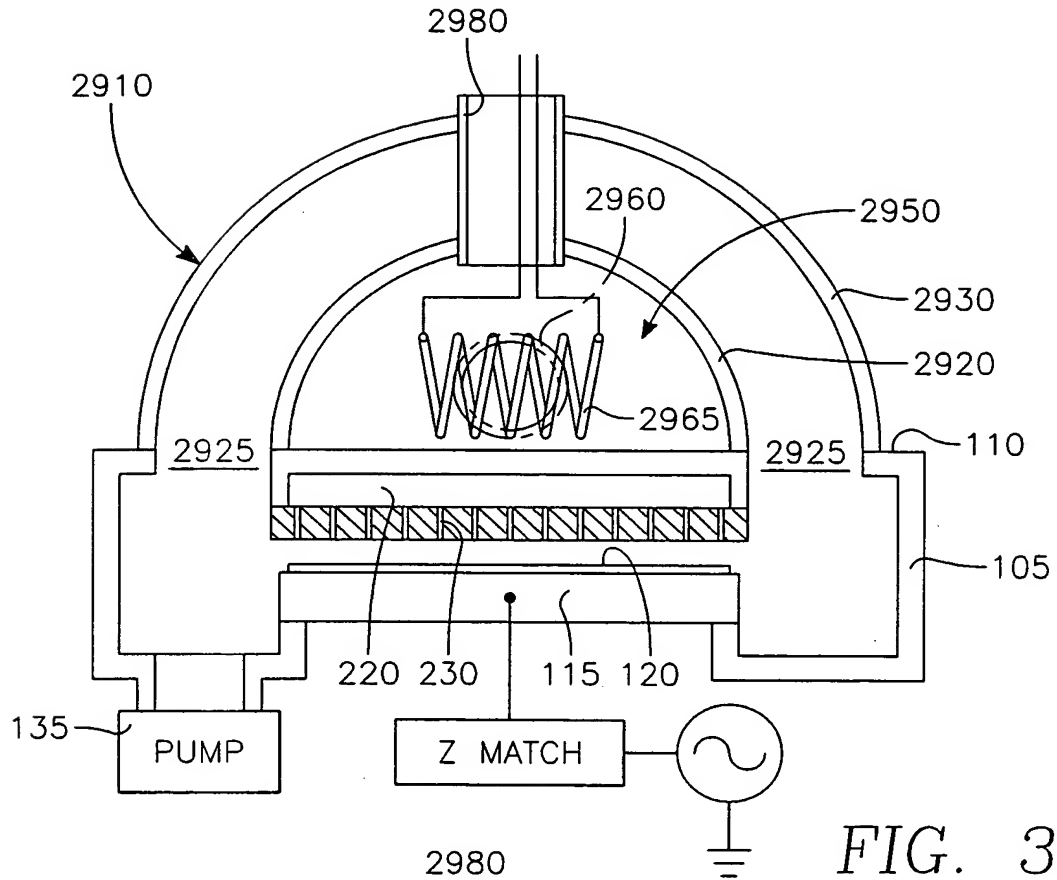


FIG. 31A

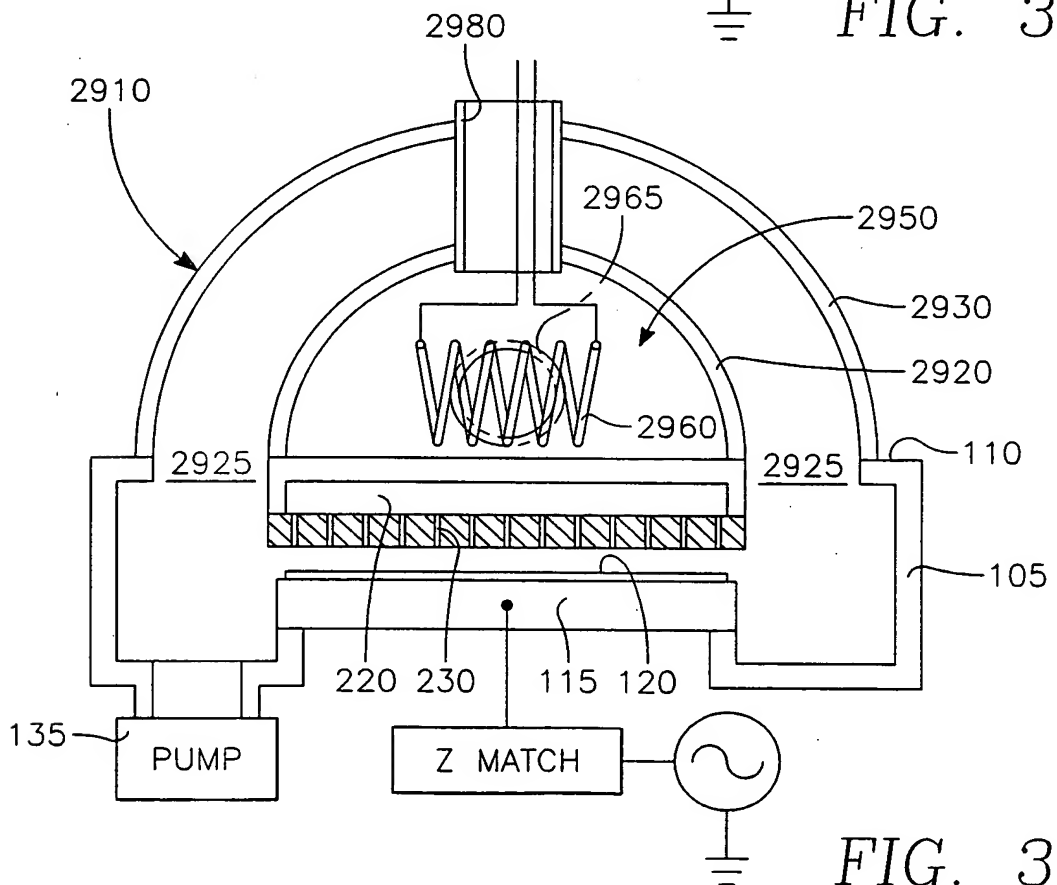


FIG. 31B

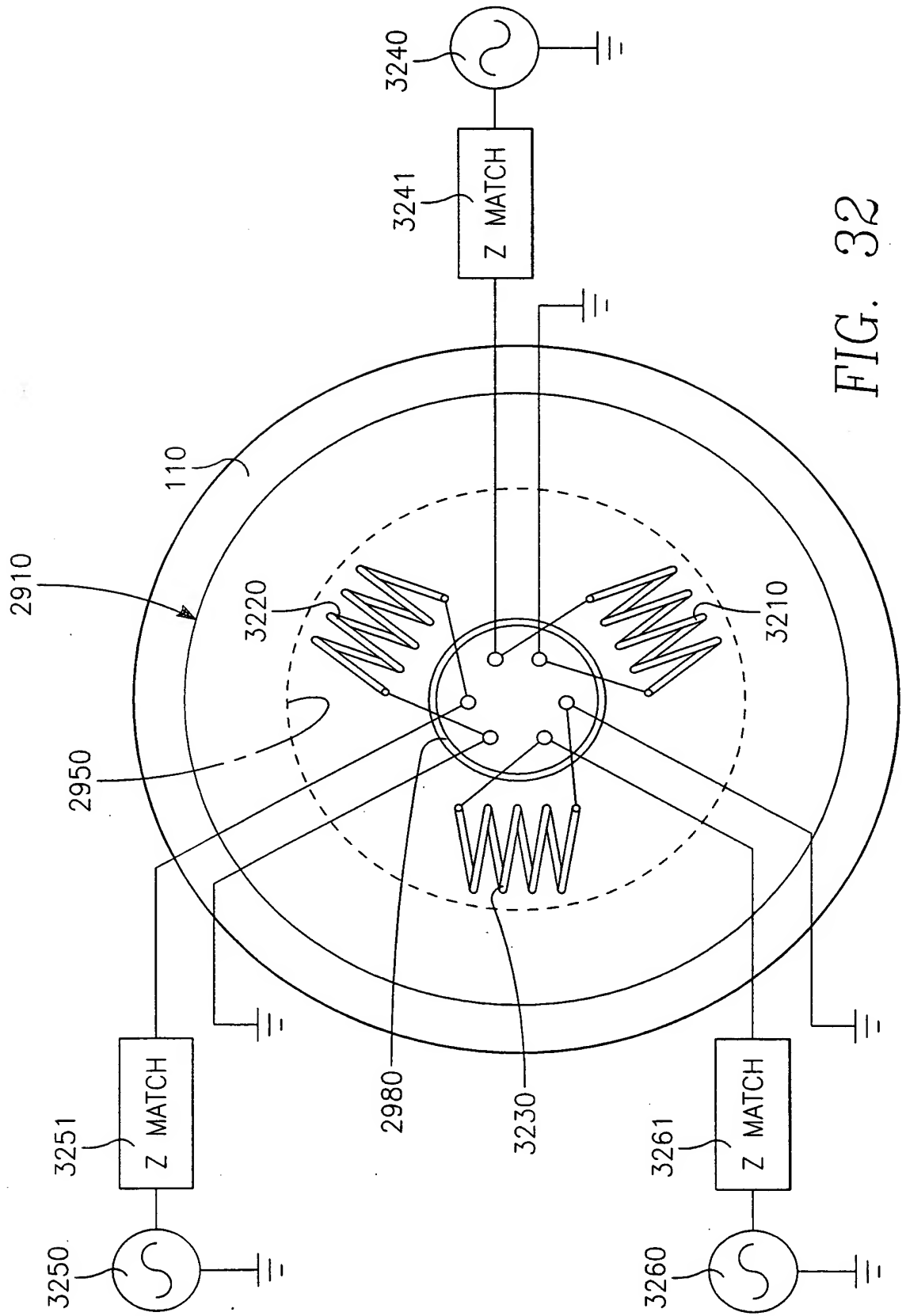


FIG. 32

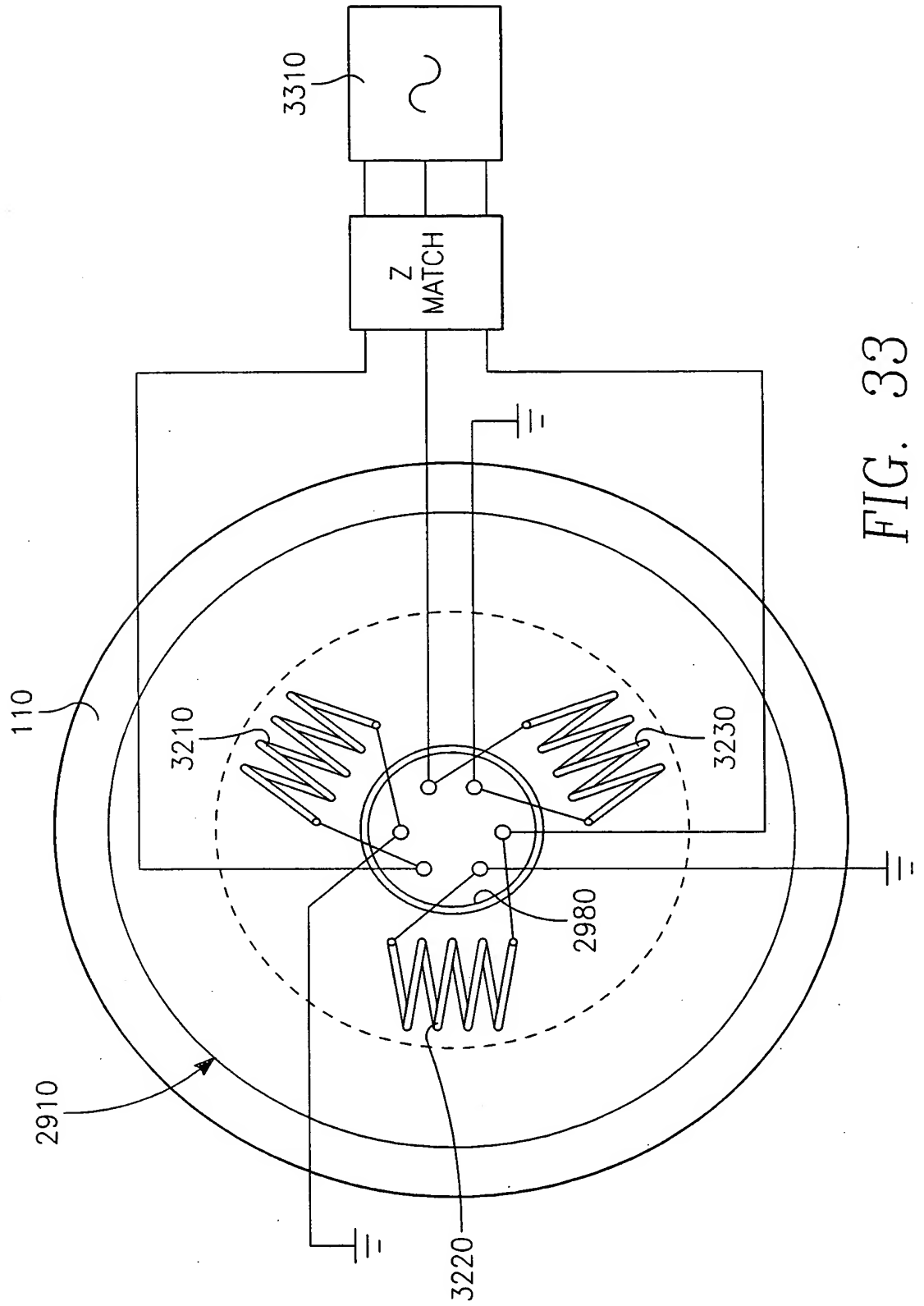


FIG. 33

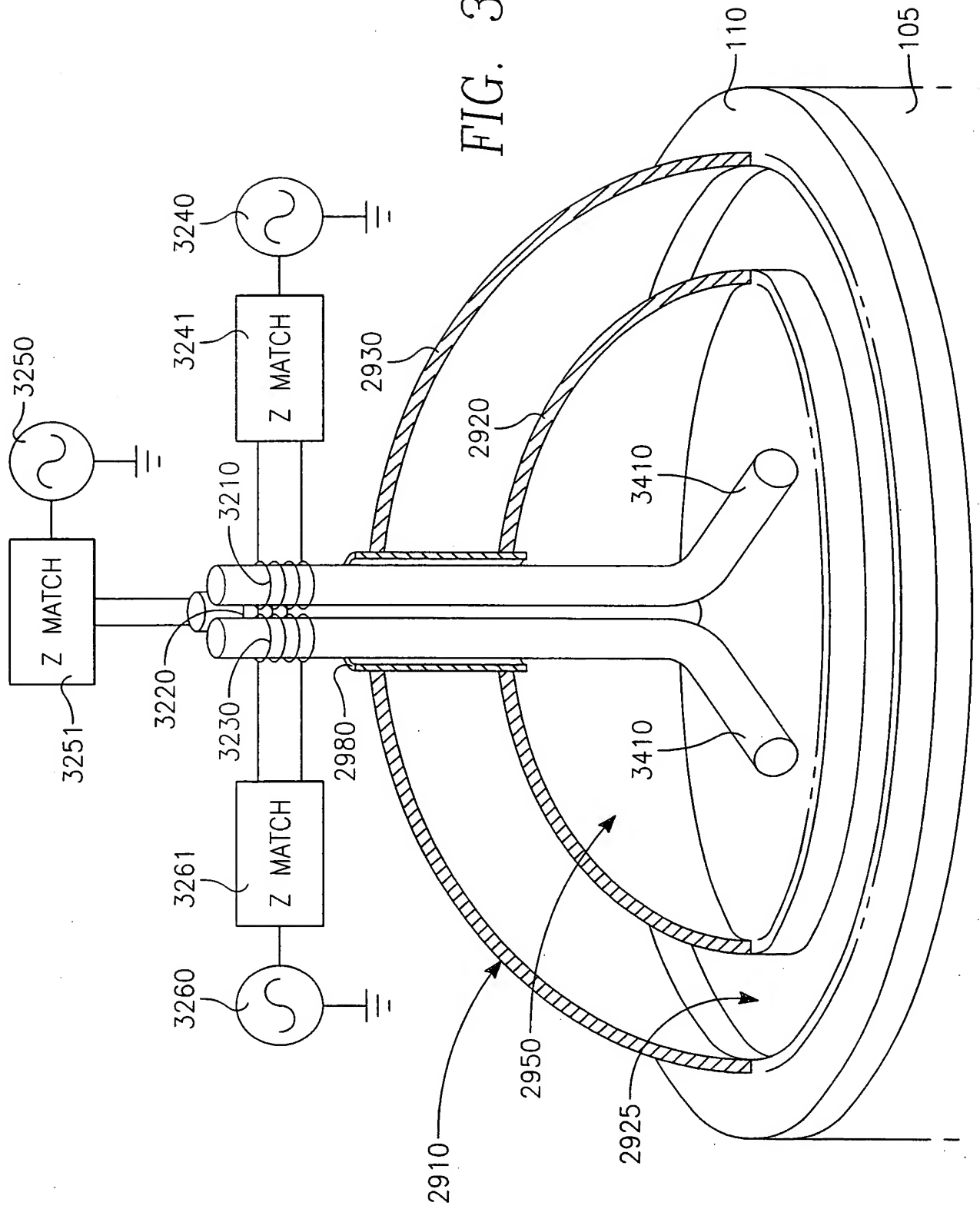


FIG. 34

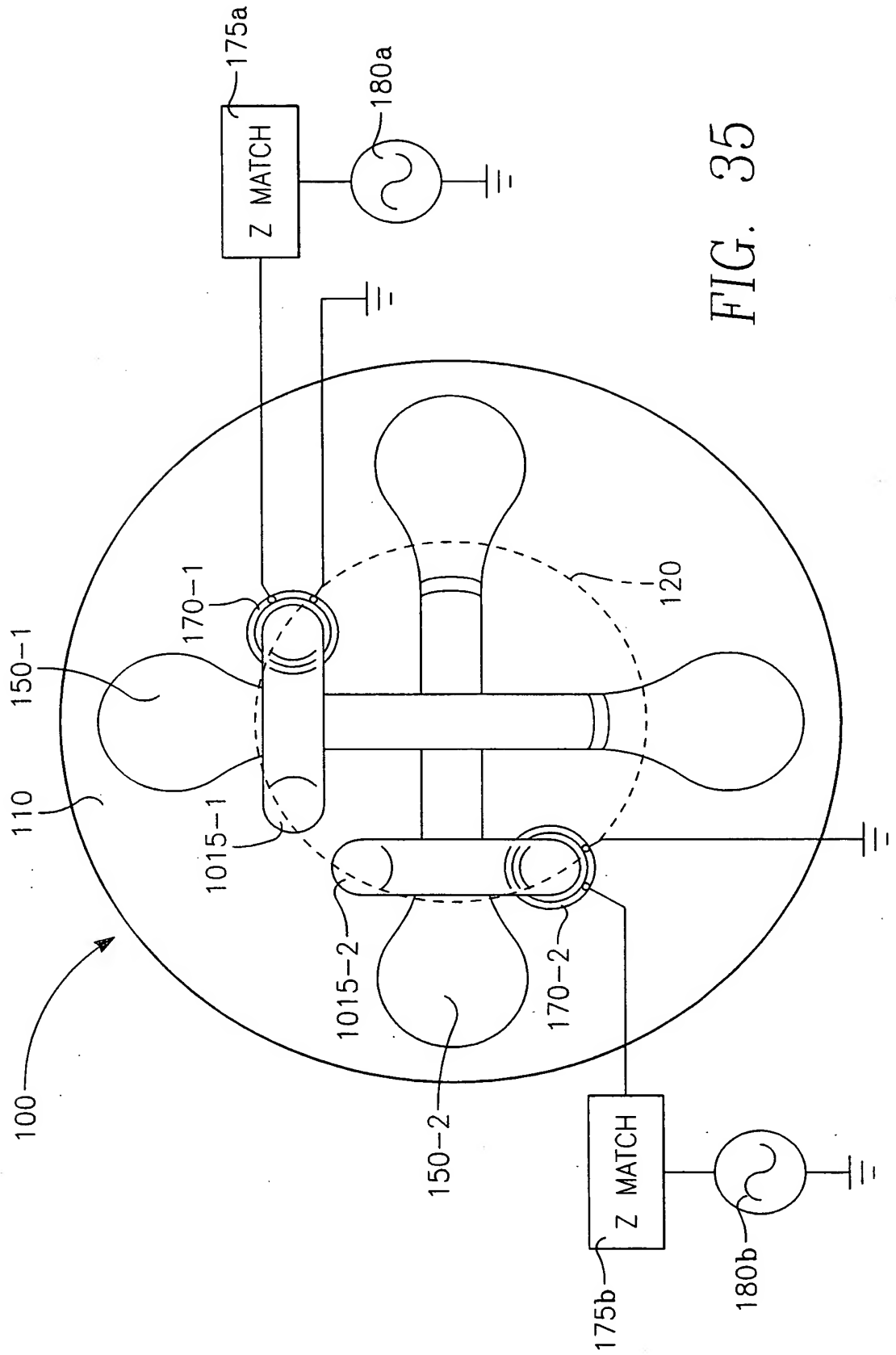
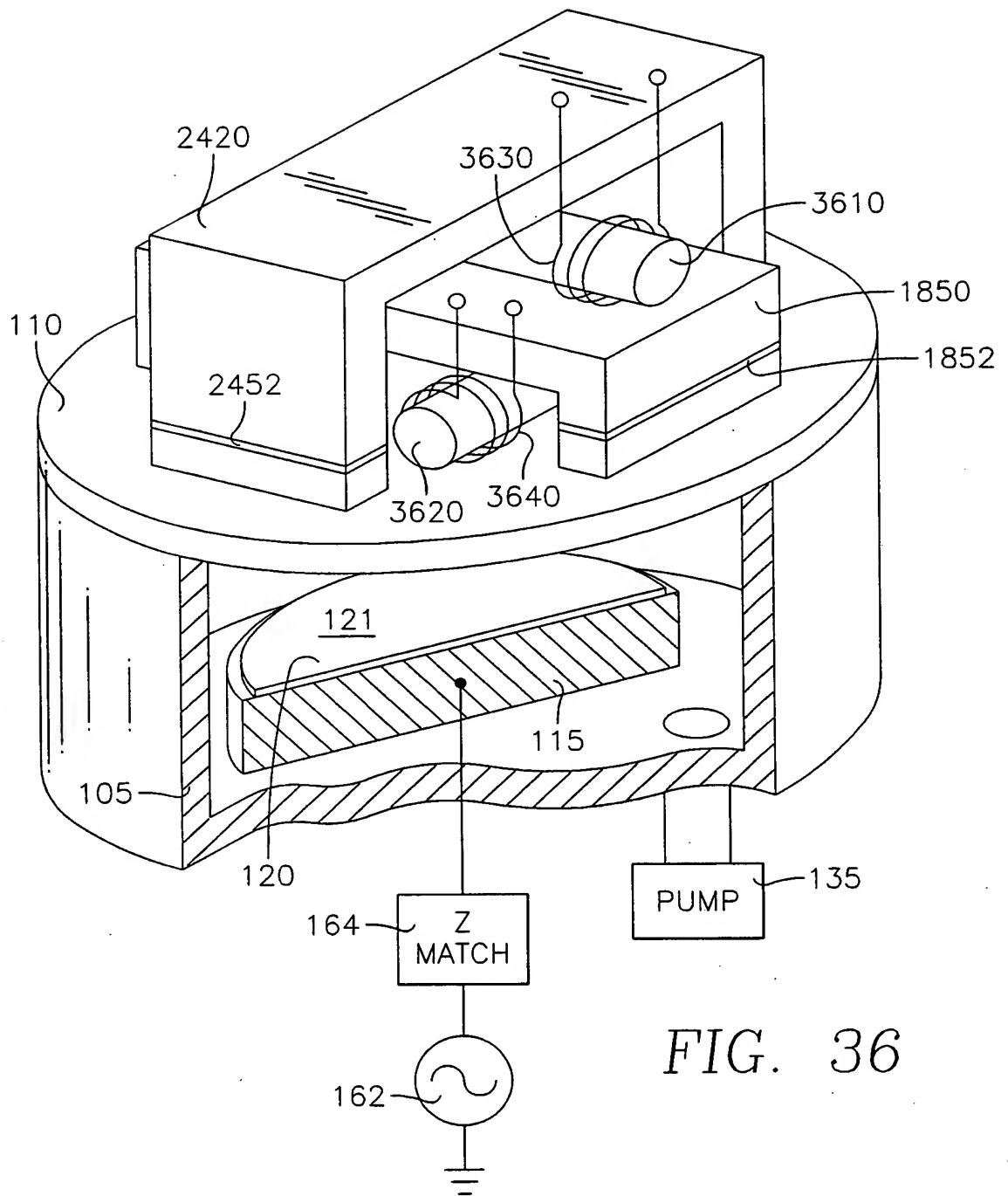


FIG. 35



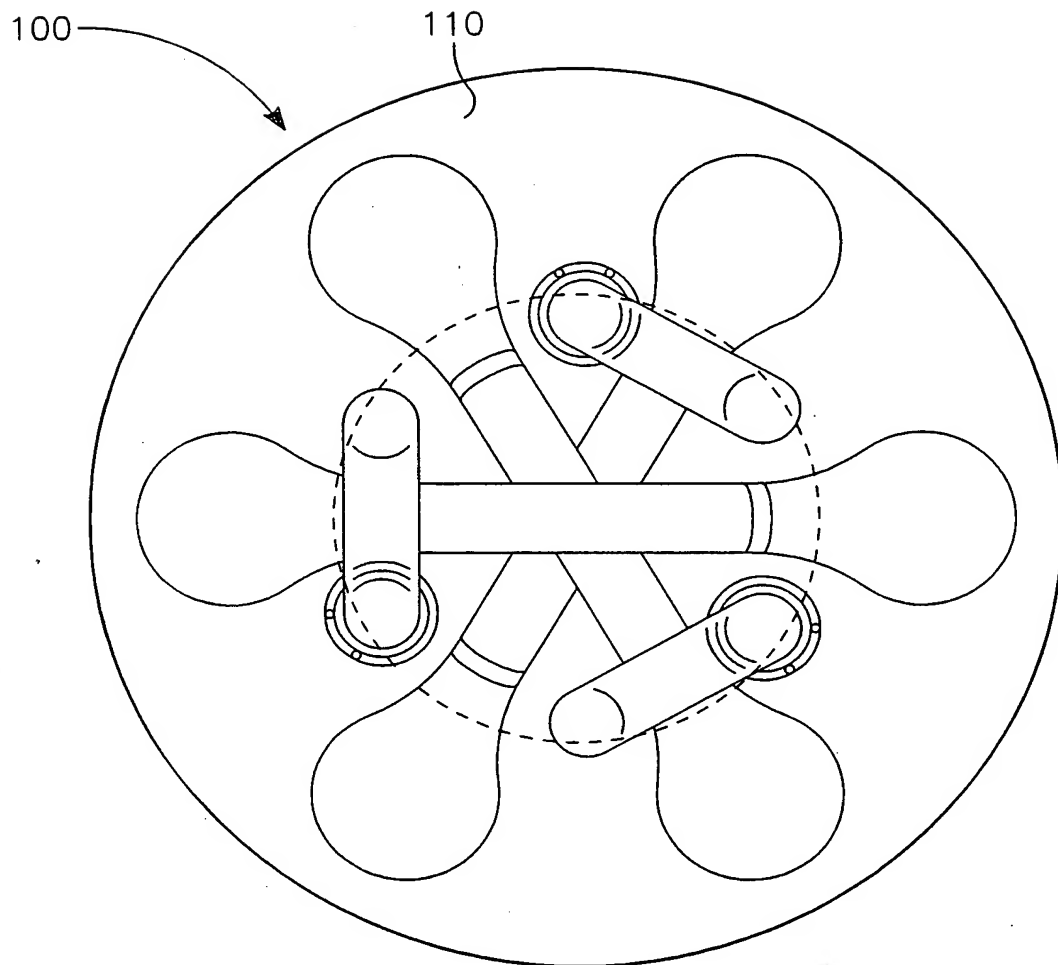


FIG. 37

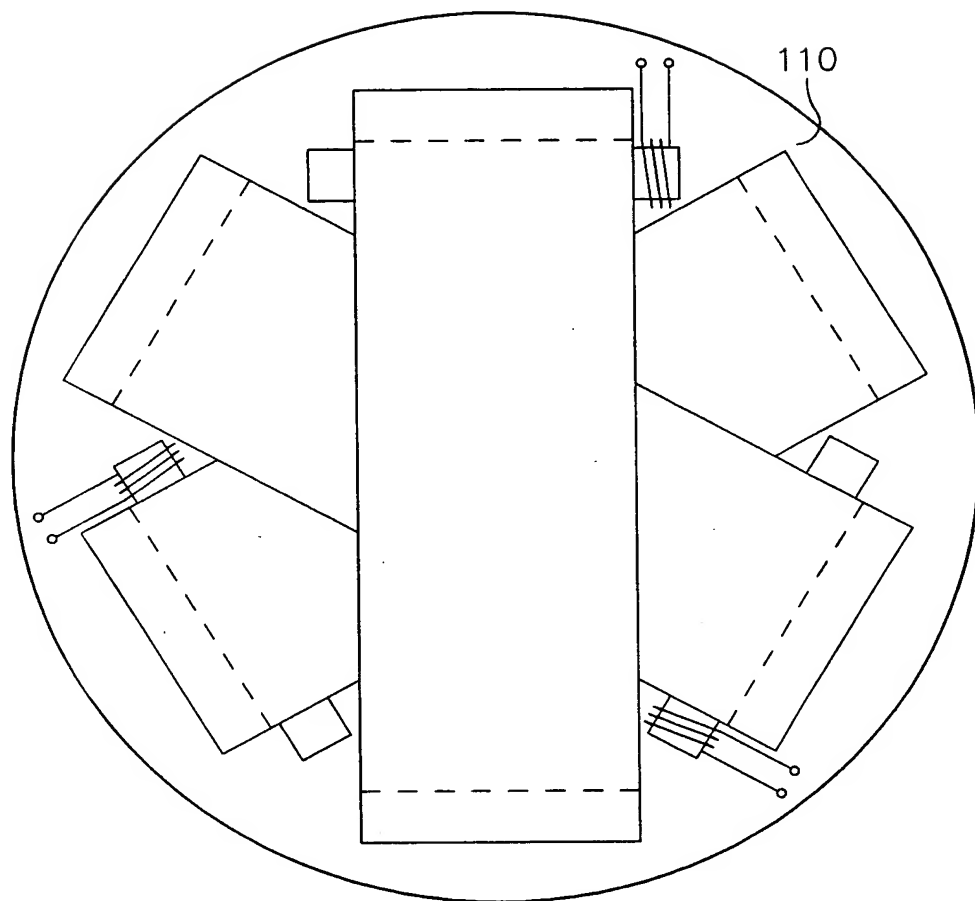


FIG. 38

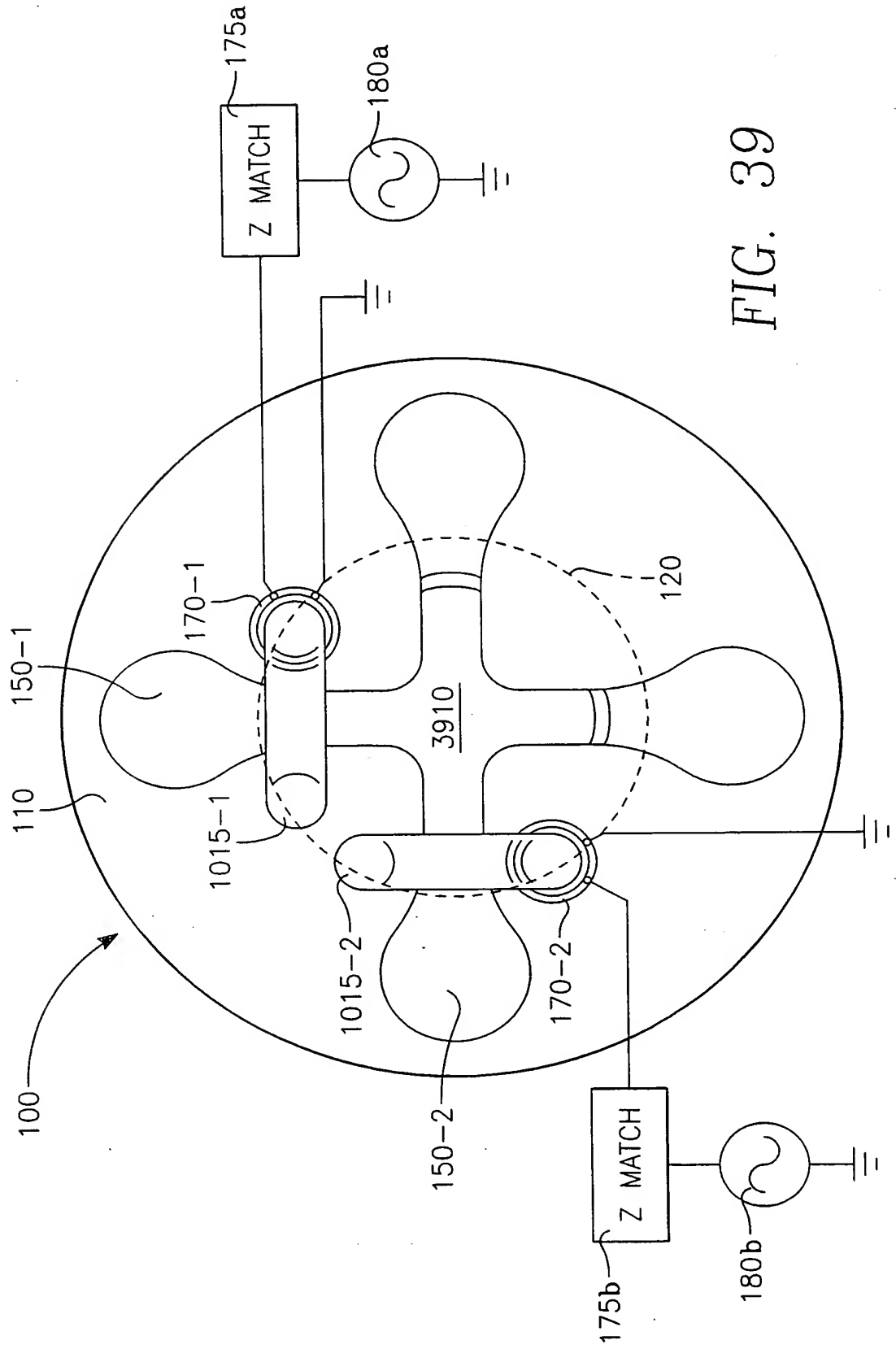


FIG. 39

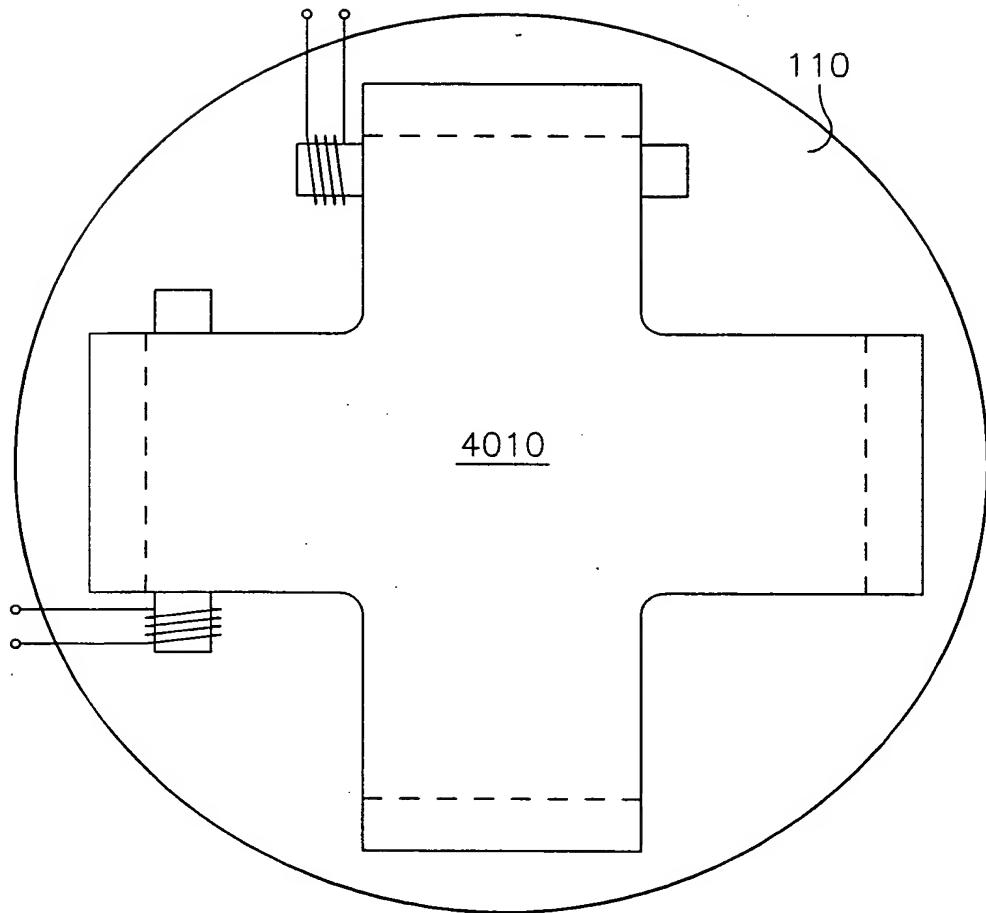


FIG. 40

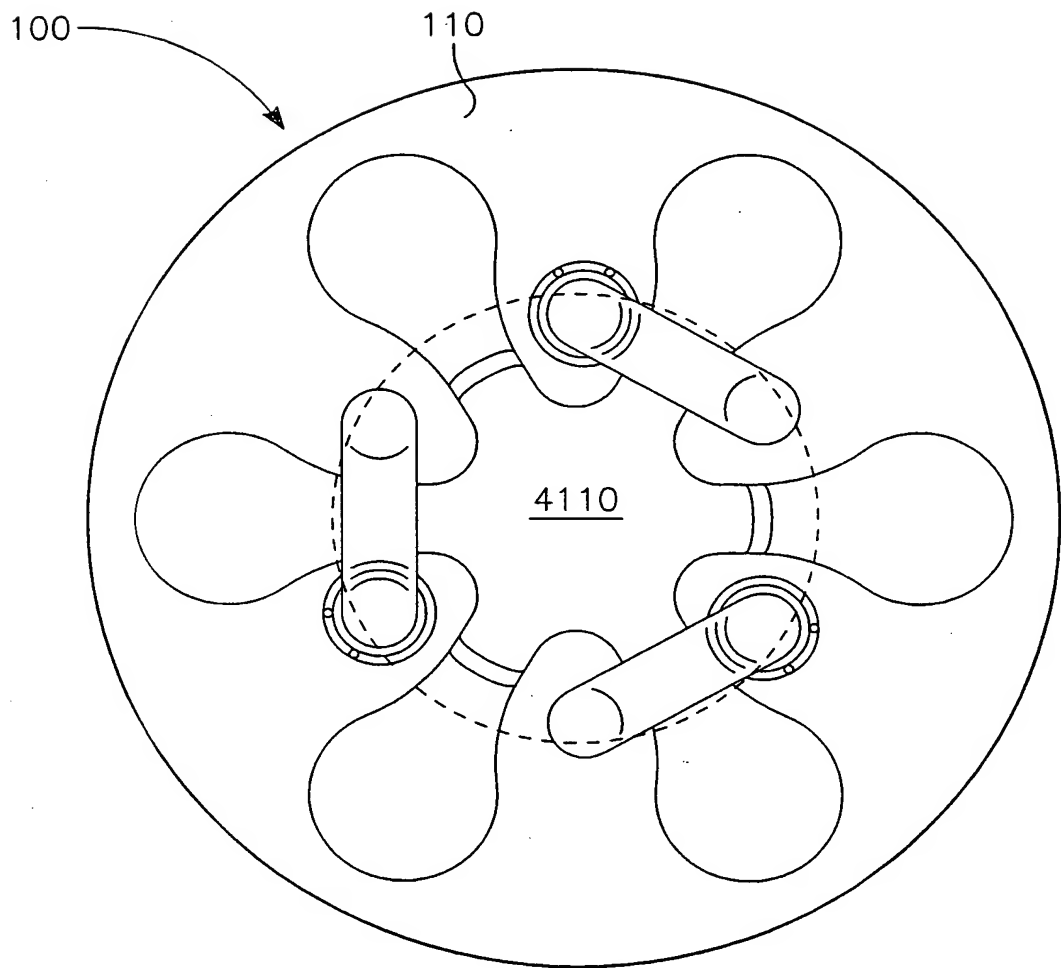


FIG. 41

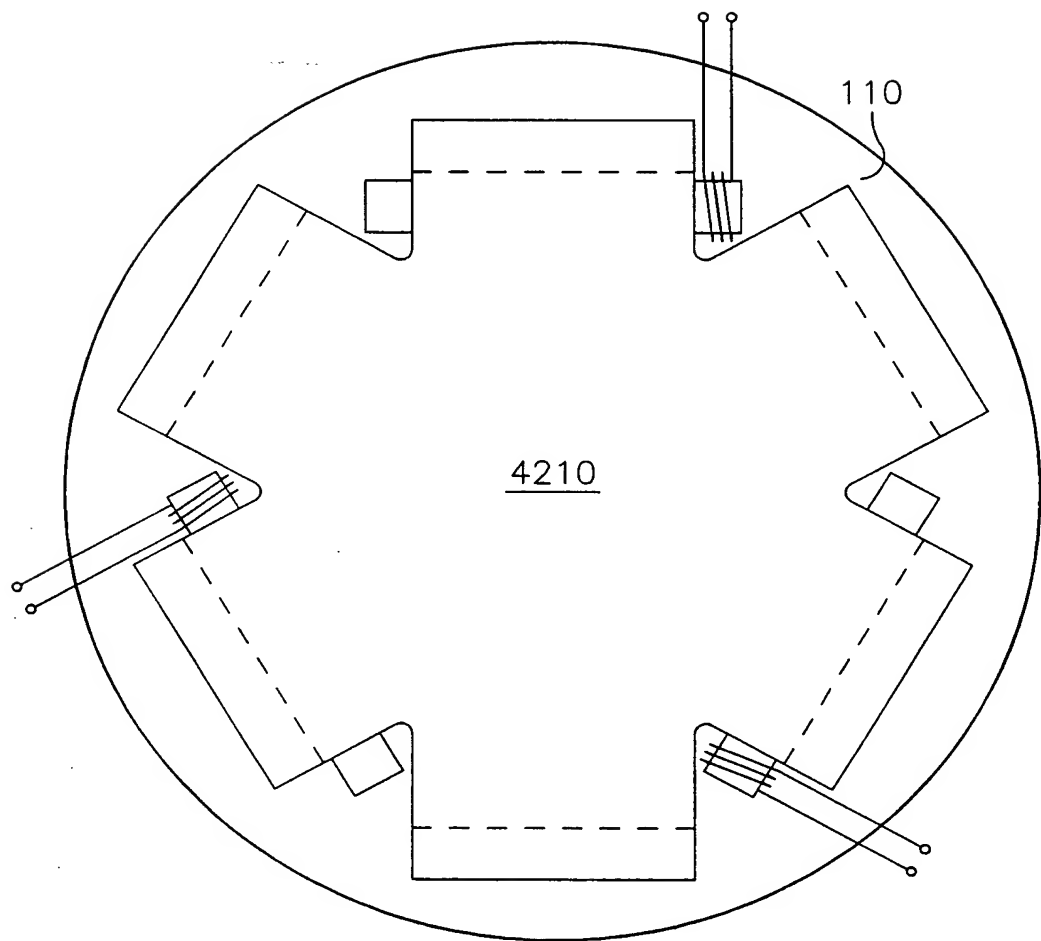


FIG. 42

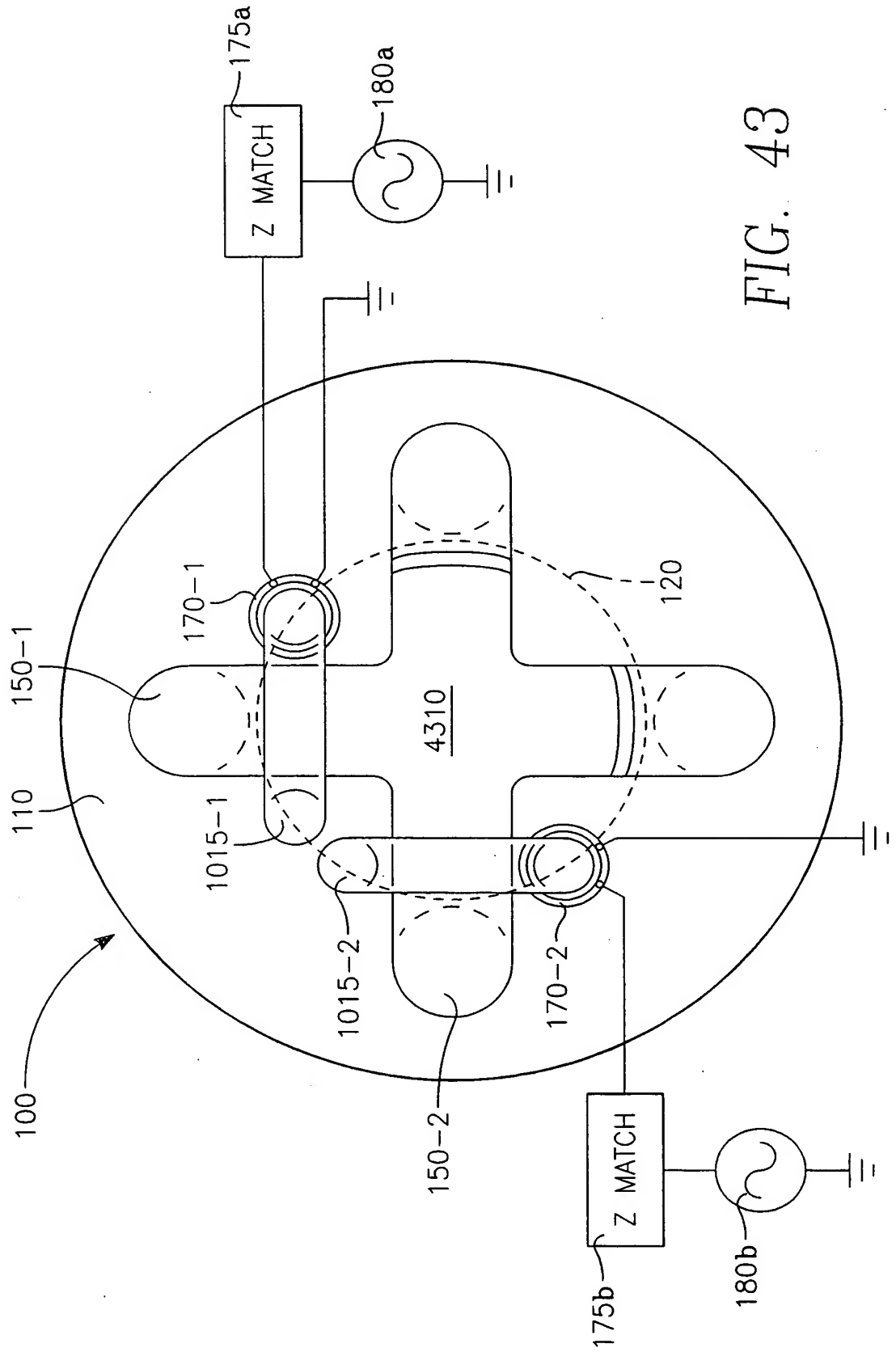


FIG. 43

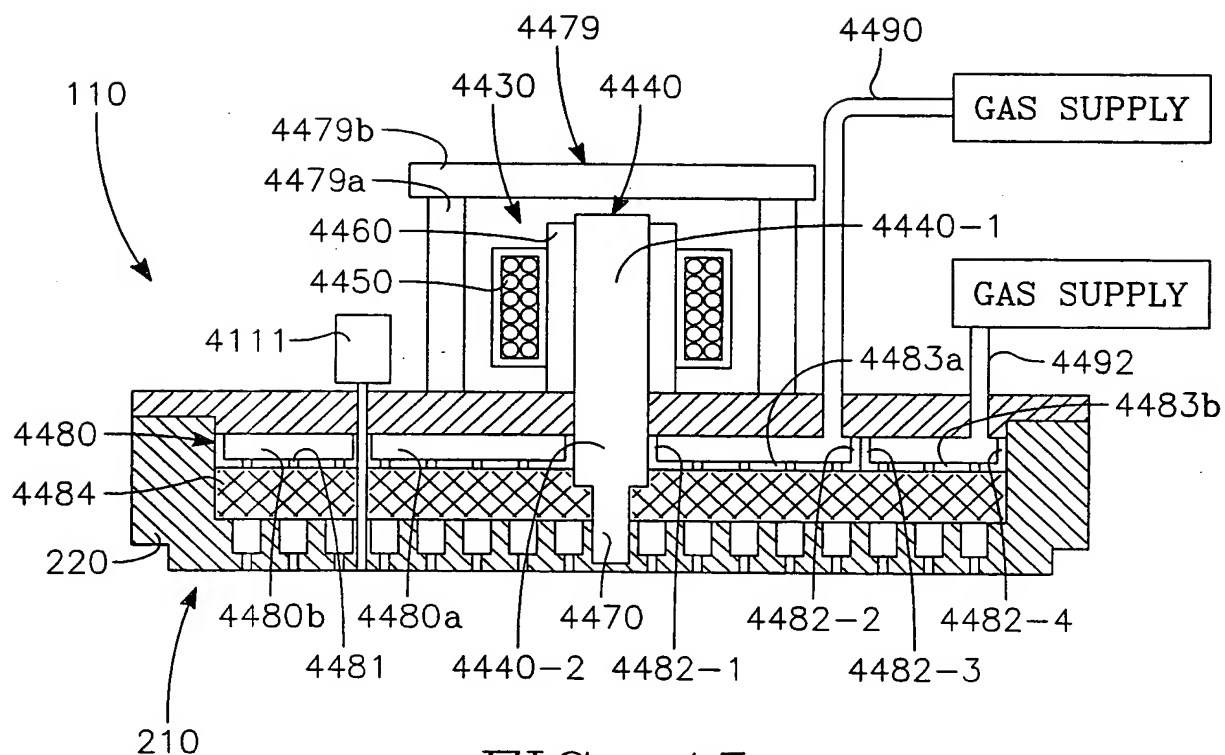


FIG. 45

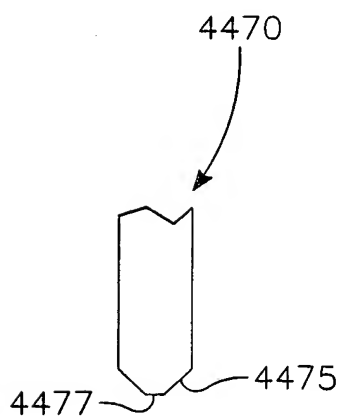


FIG. 46

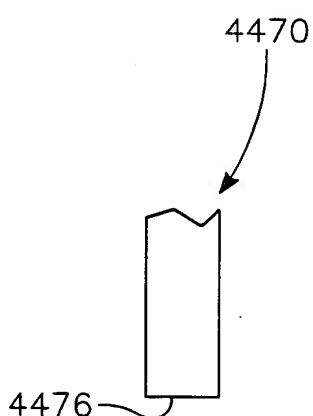


FIG. 47

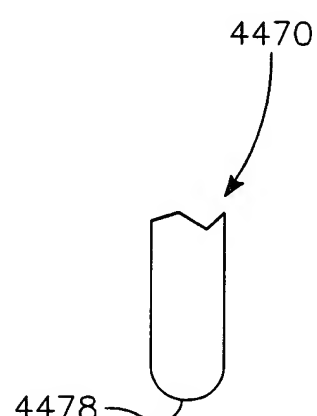


FIG. 48

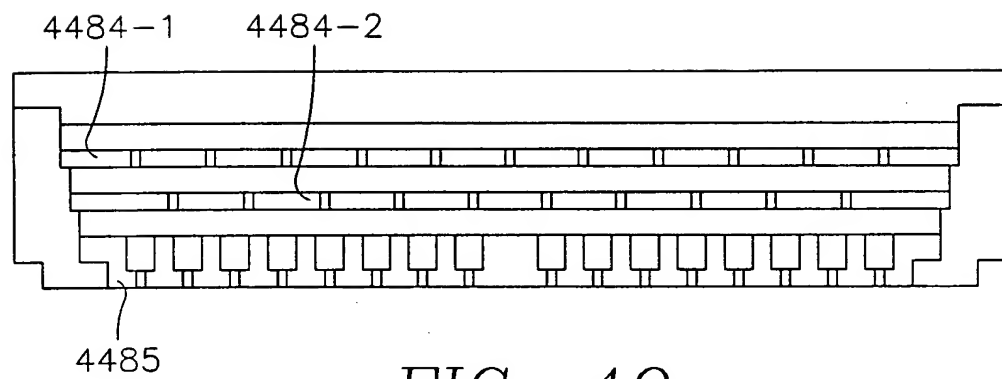


FIG. 49

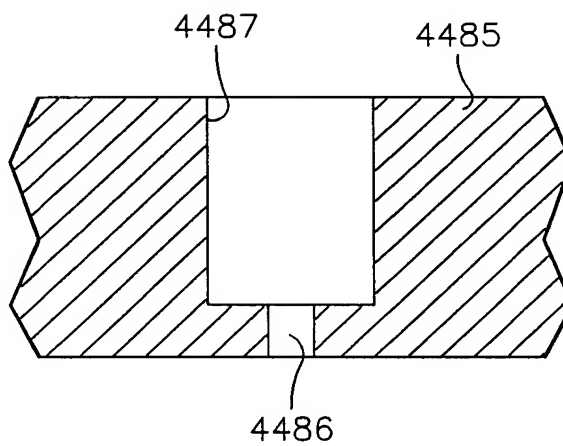


FIG. 50

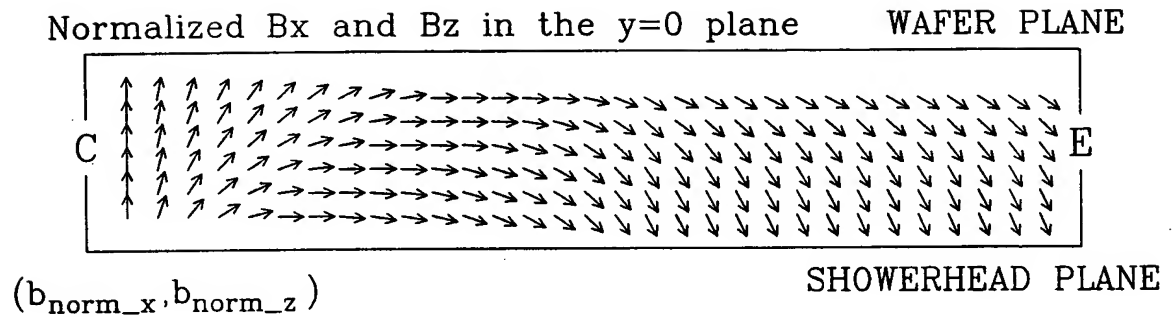


FIG. 51

□ Br measured=7 gauss at wafer plane, lin. off-center (peak)

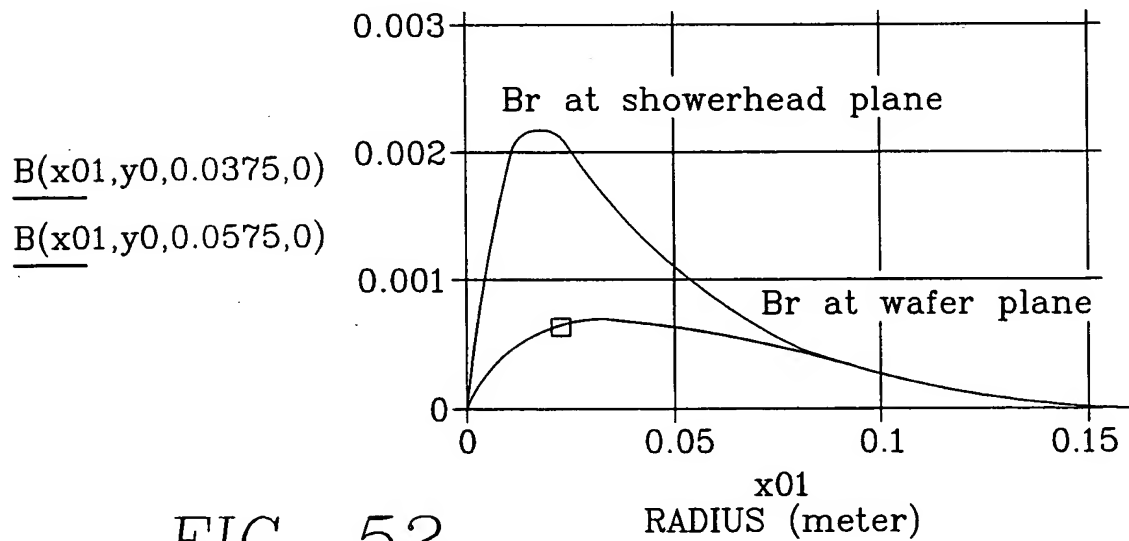


FIG. 52

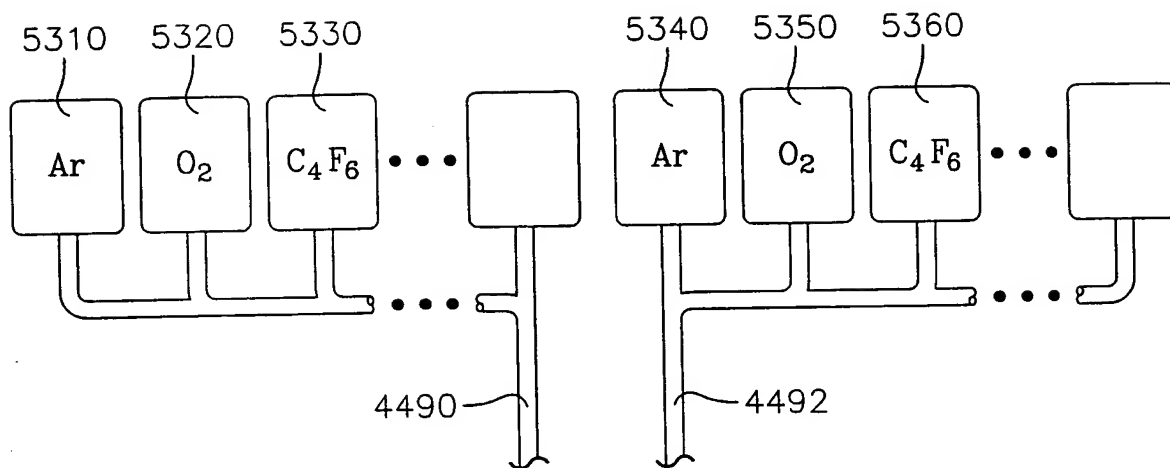


FIG. 53

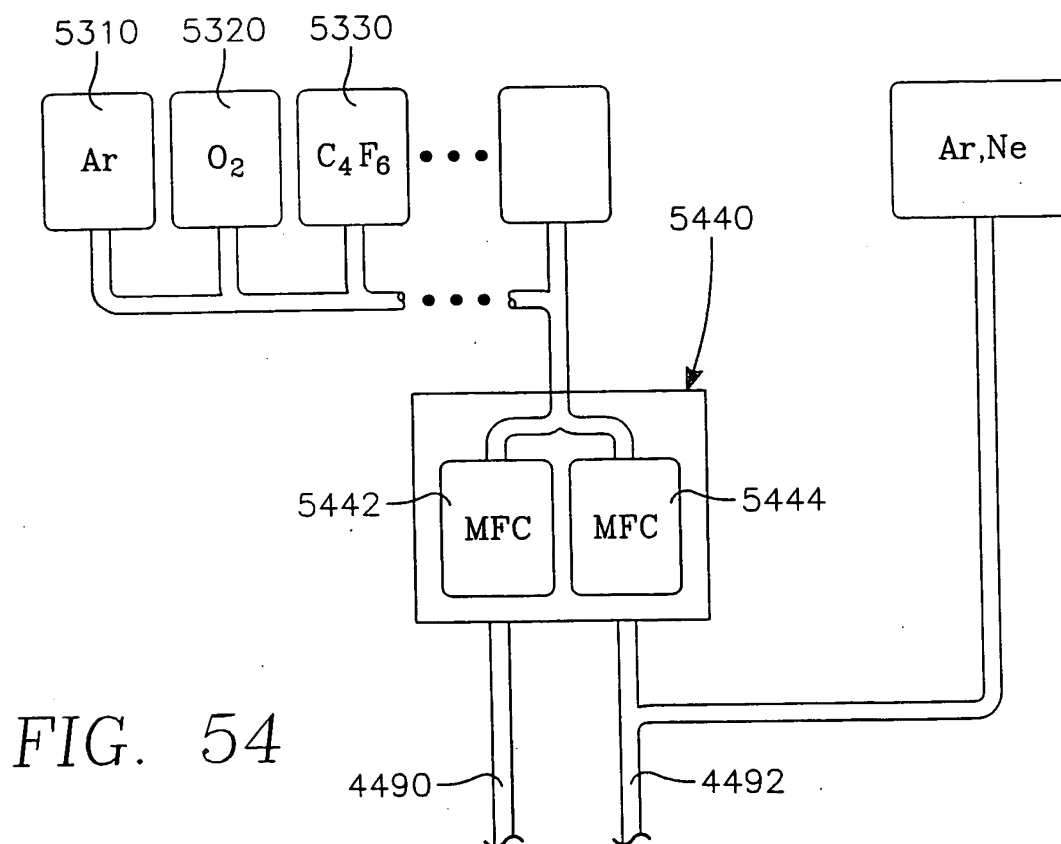


FIG. 54

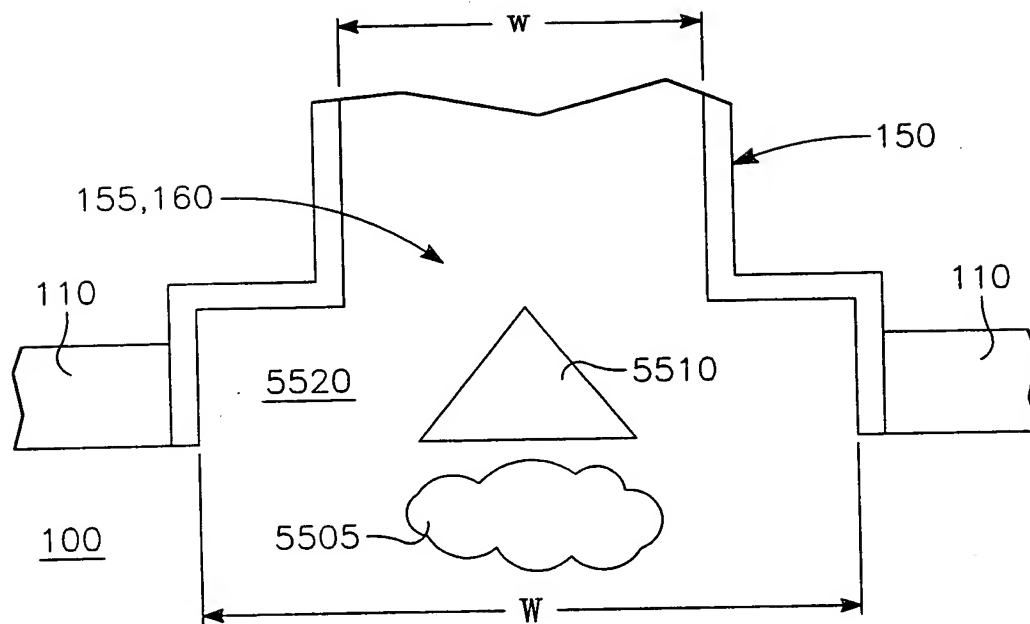


FIG. 55A

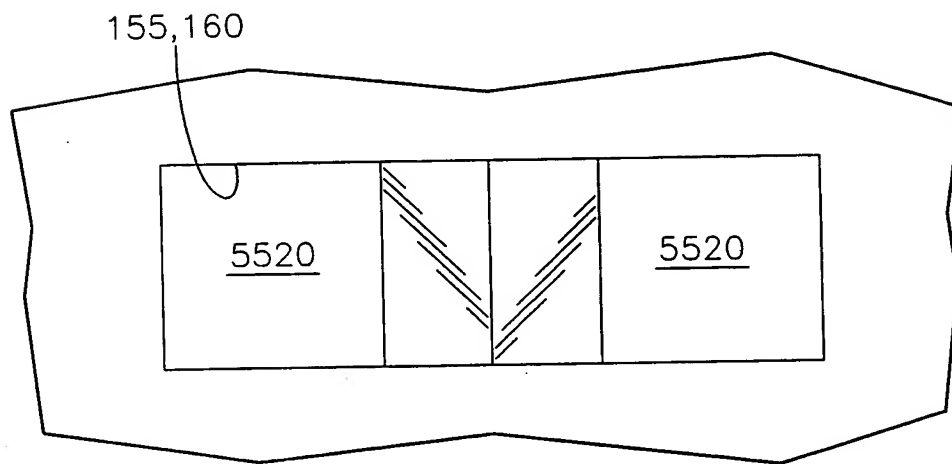


FIG. 55B

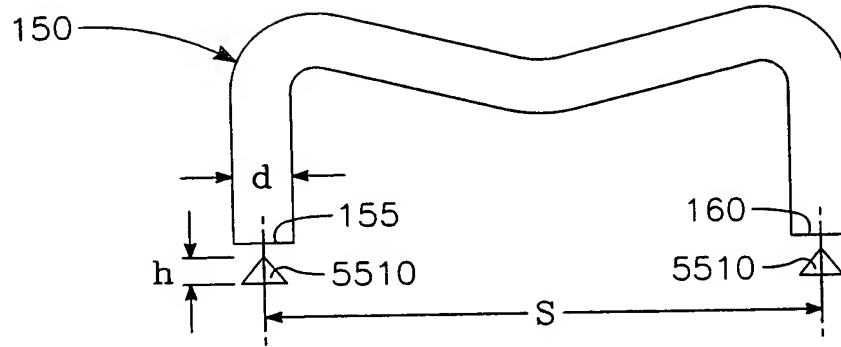


FIG. 56A

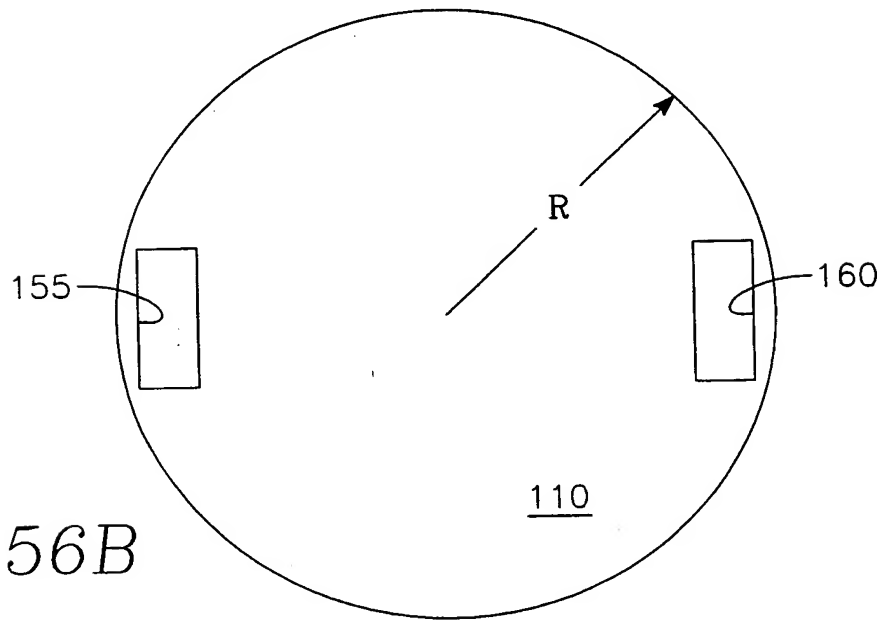


FIG. 56B

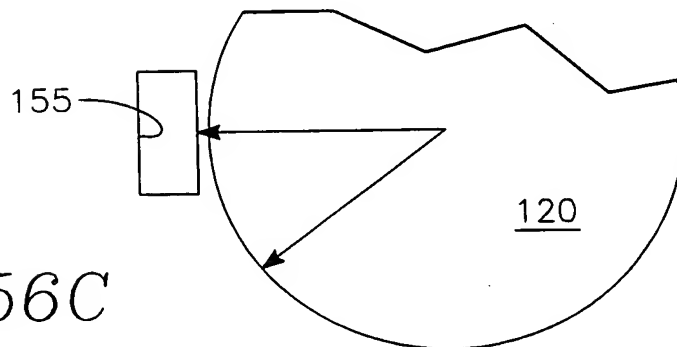


FIG. 56C

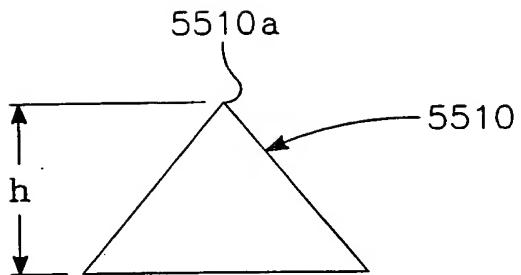


FIG. 57

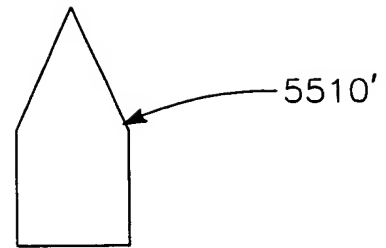


FIG. 58

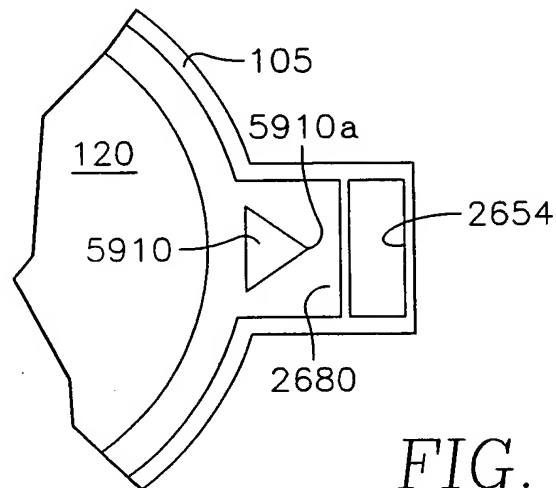


FIG. 59A

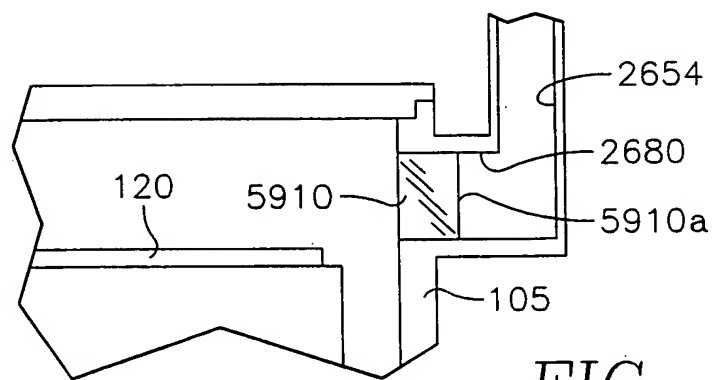


FIG. 59B

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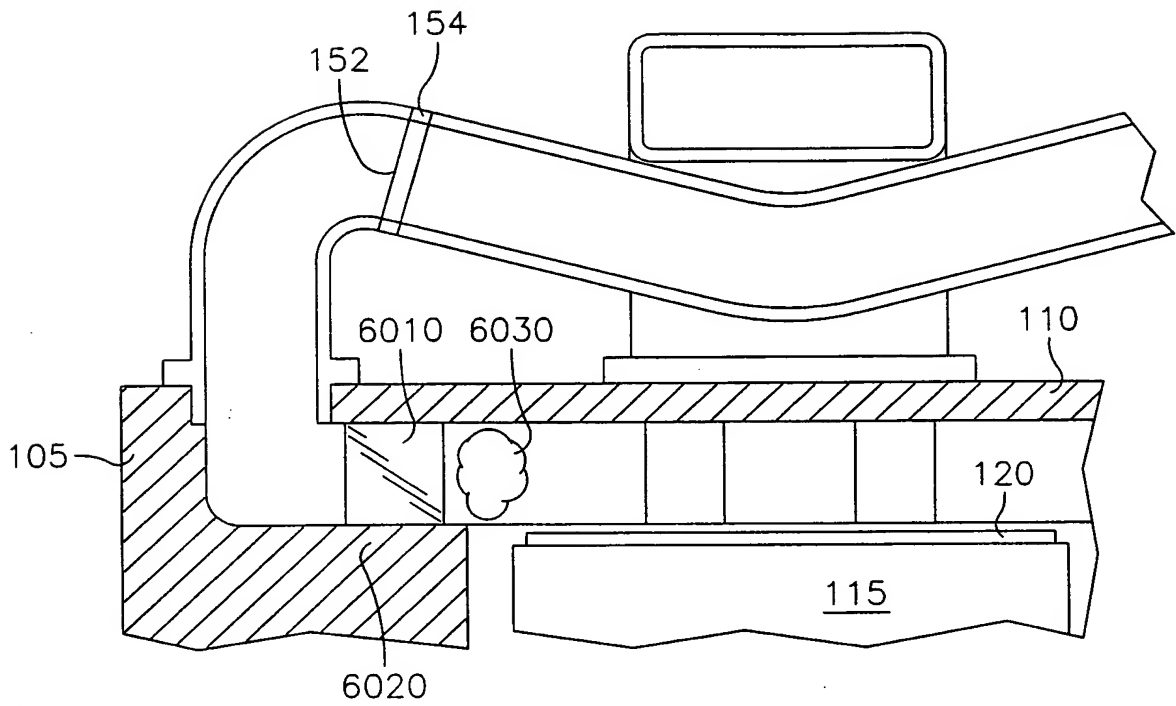


FIG. 60

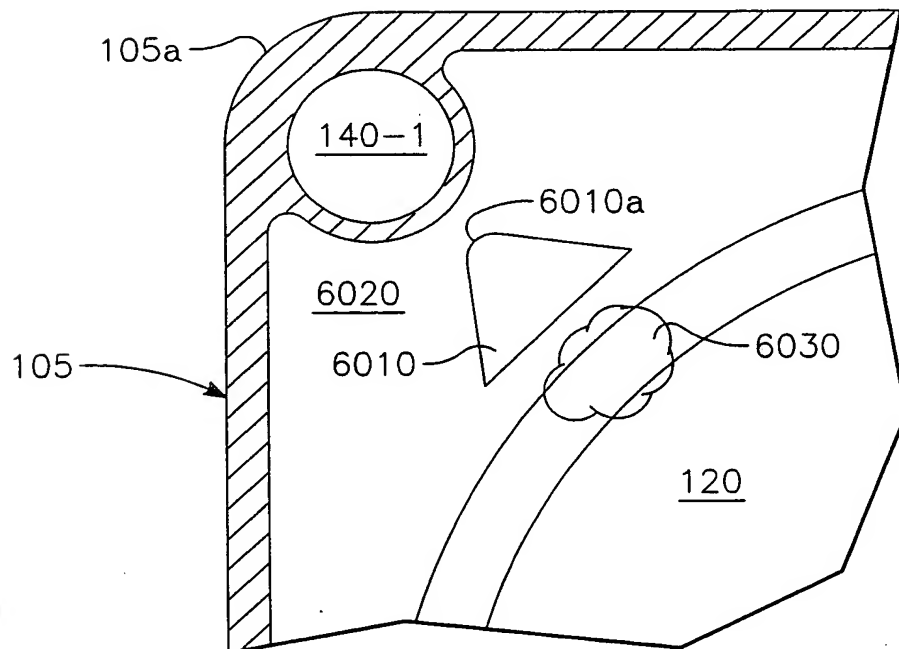


FIG. 61

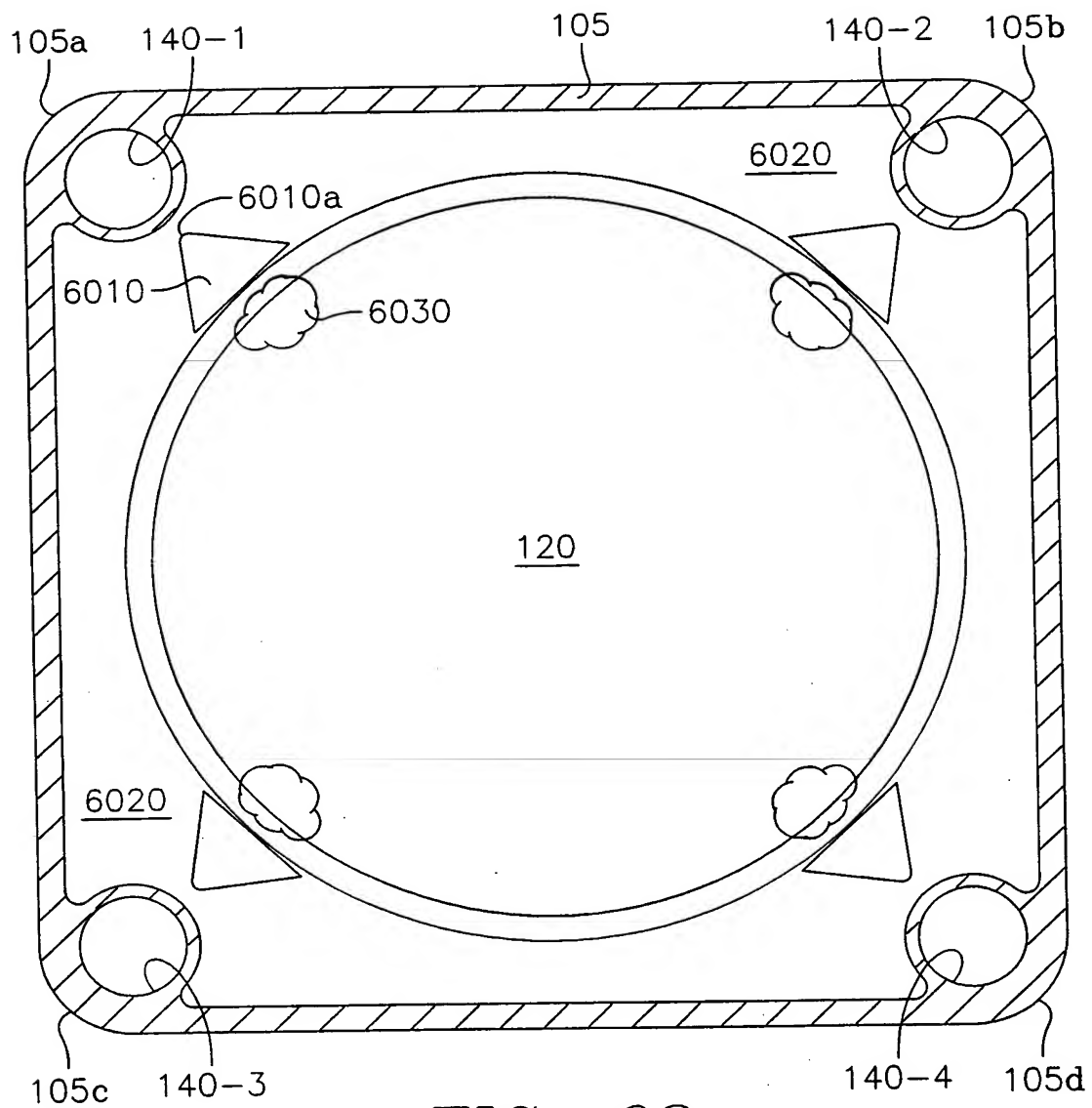


FIG. 62

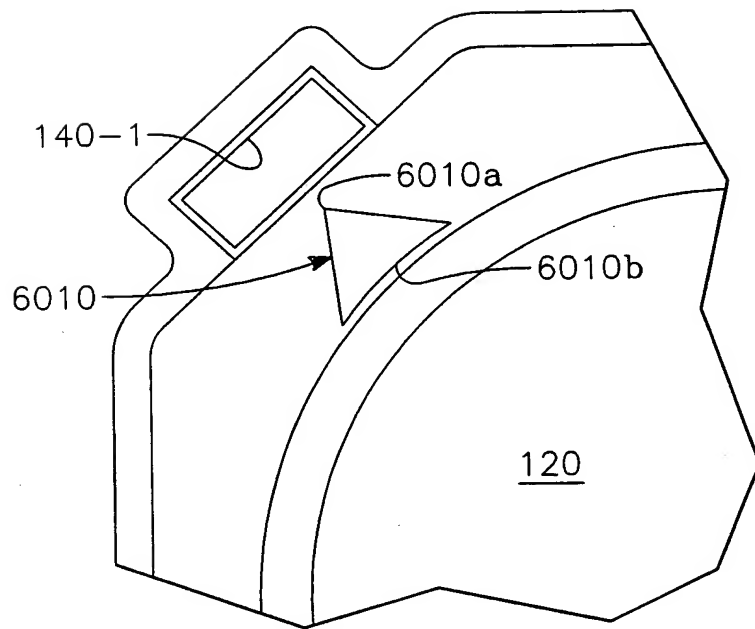


FIG. 63

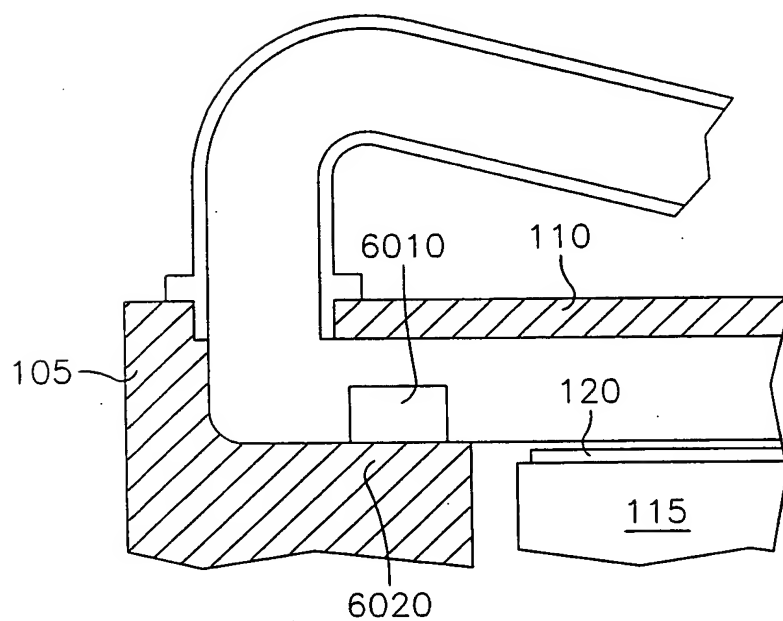


FIG. 64

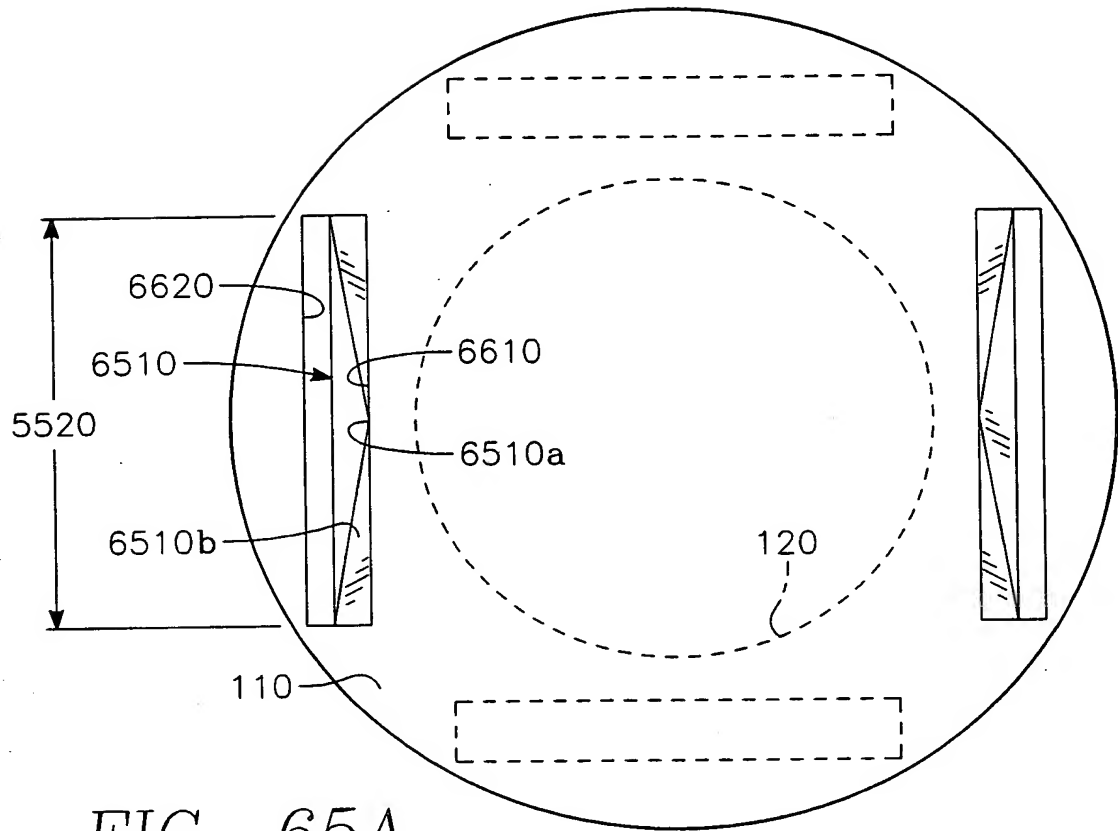


FIG. 65A

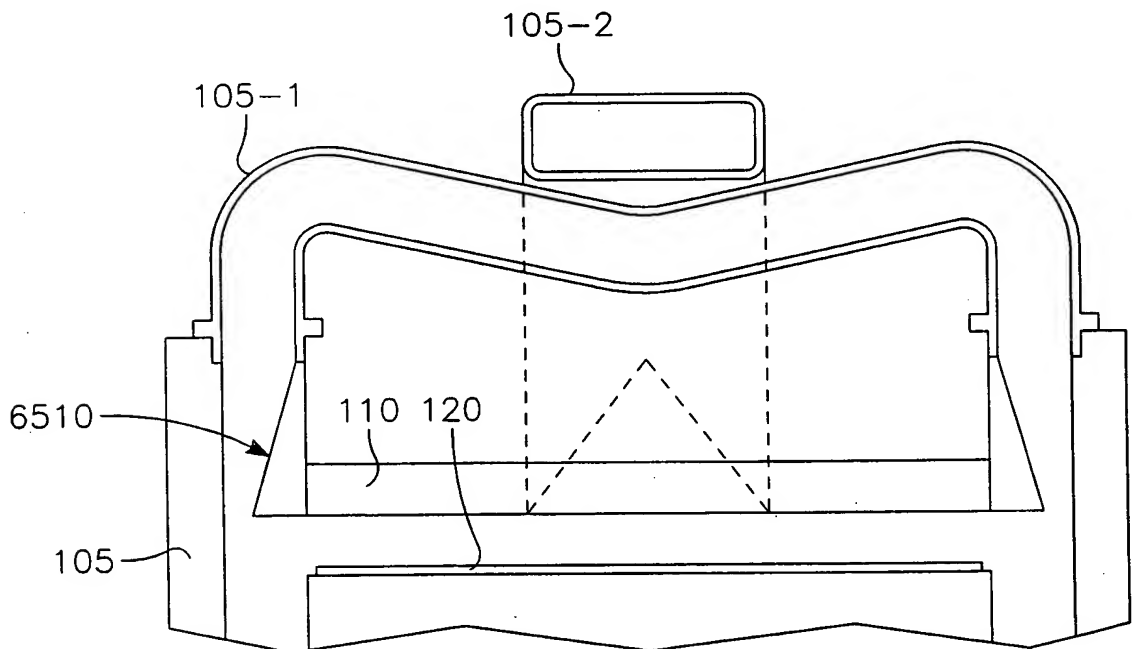


FIG. 65B

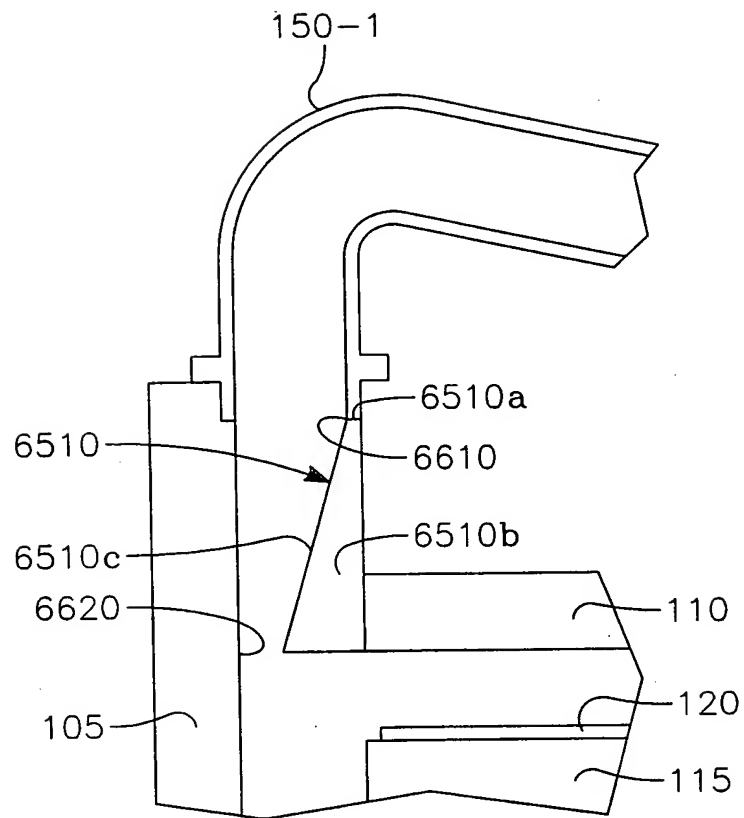


FIG. 66

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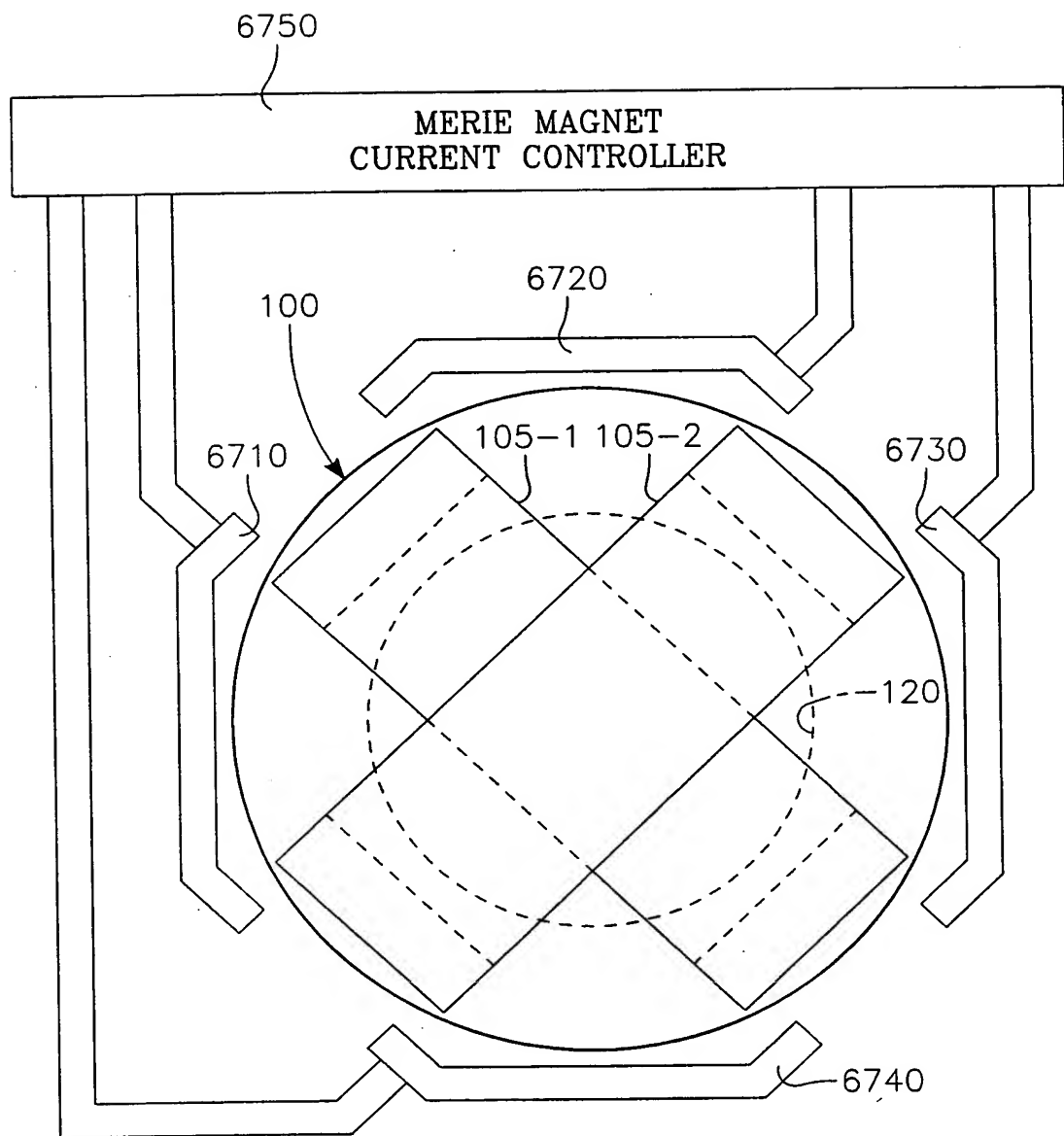


FIG. 67

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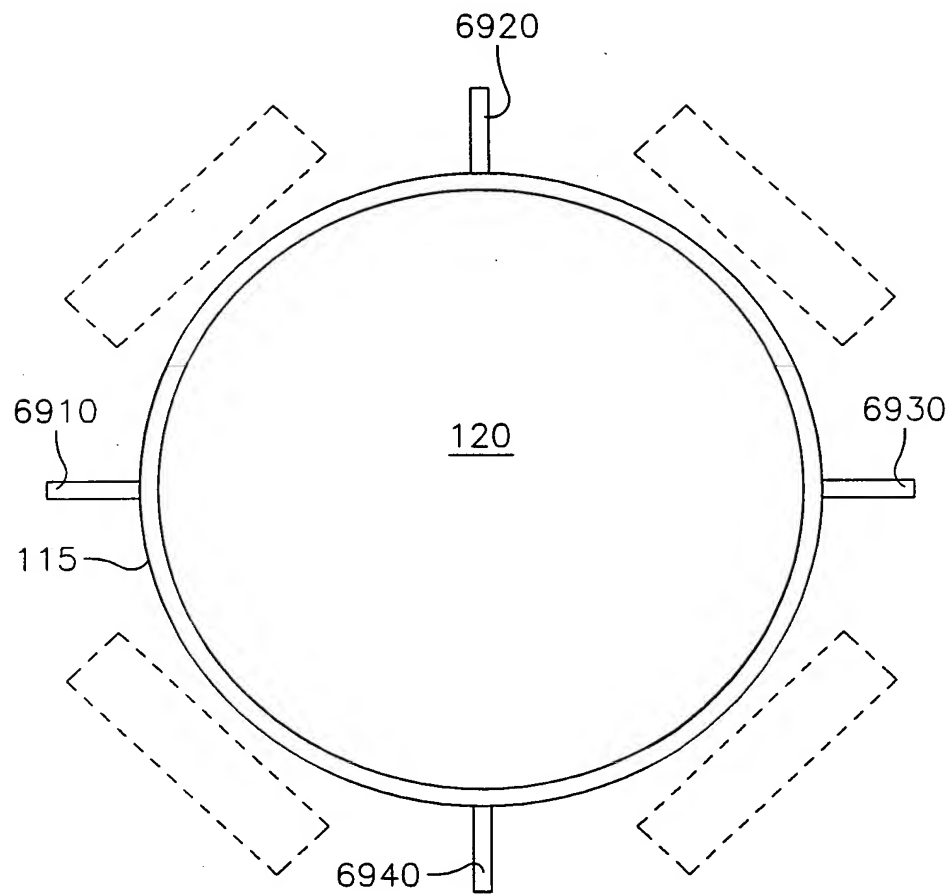


FIG. 68

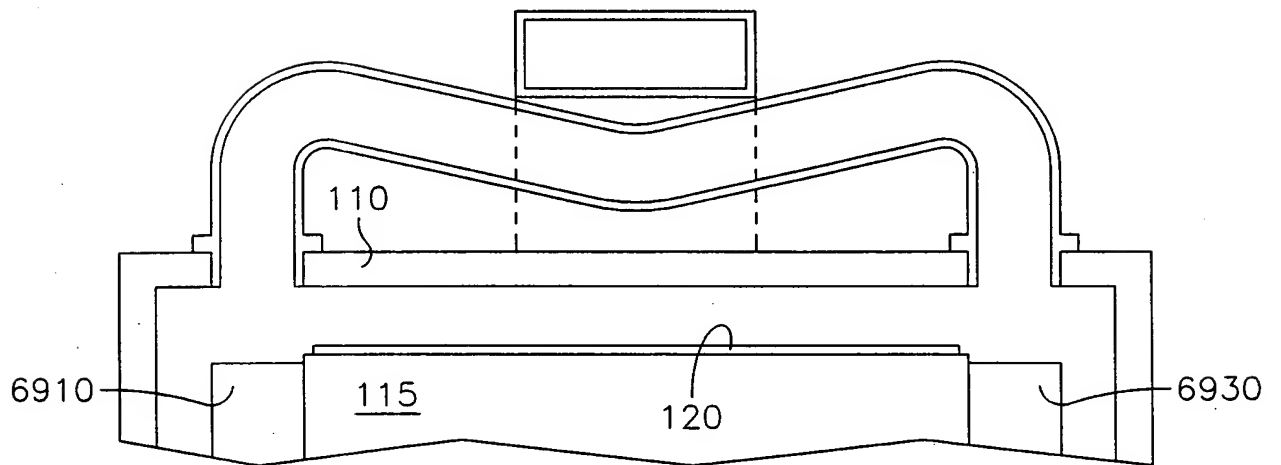
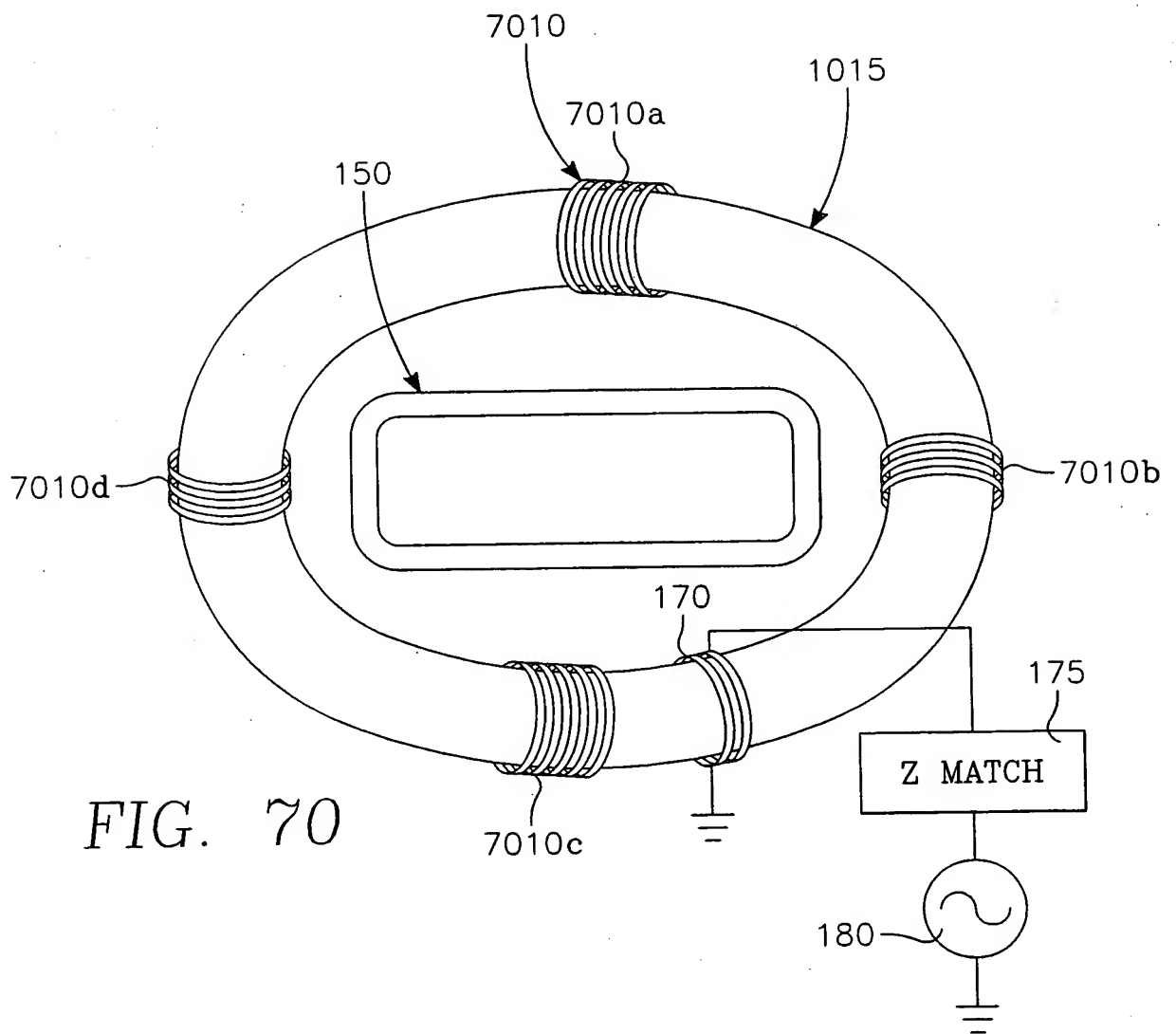
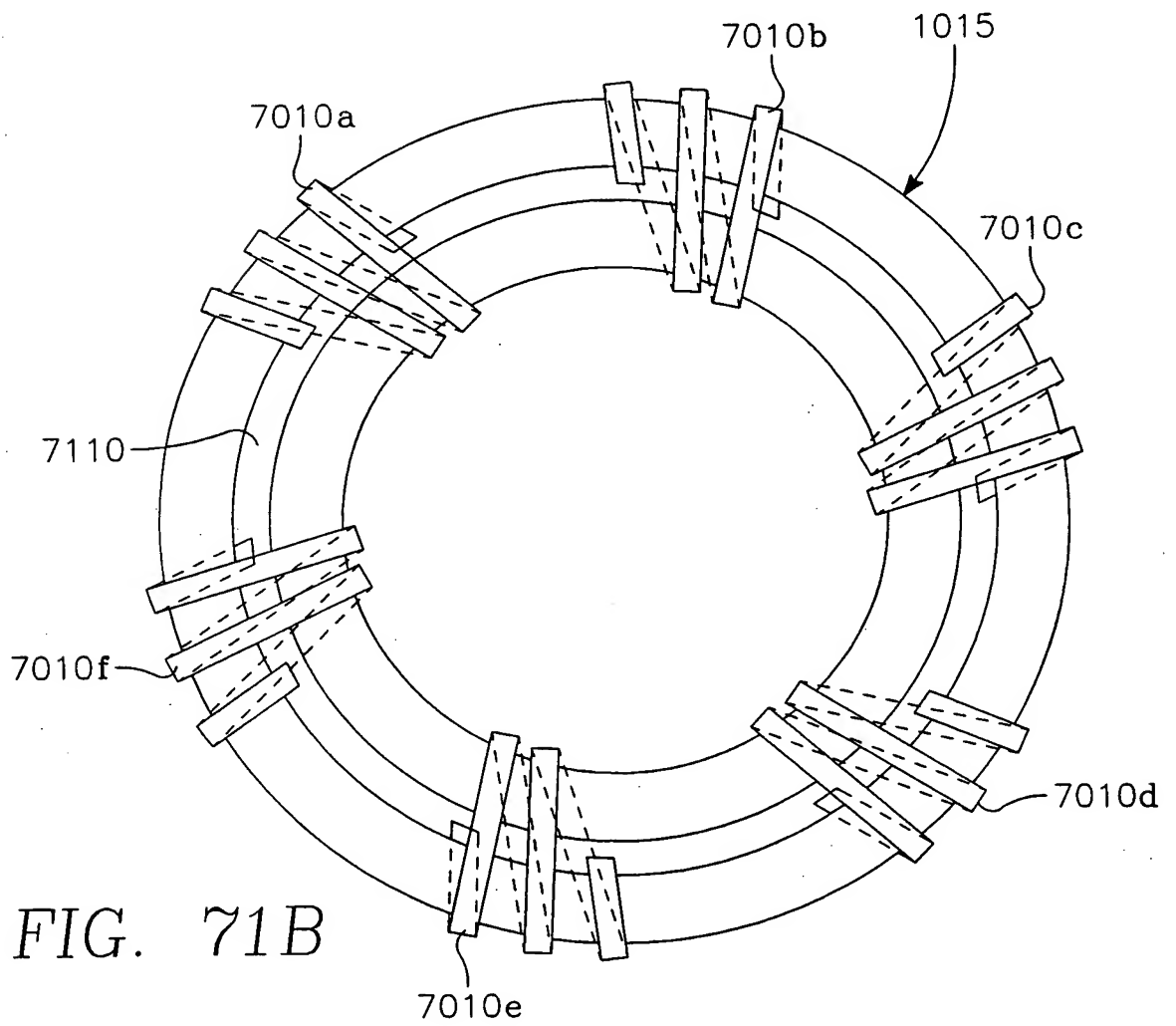
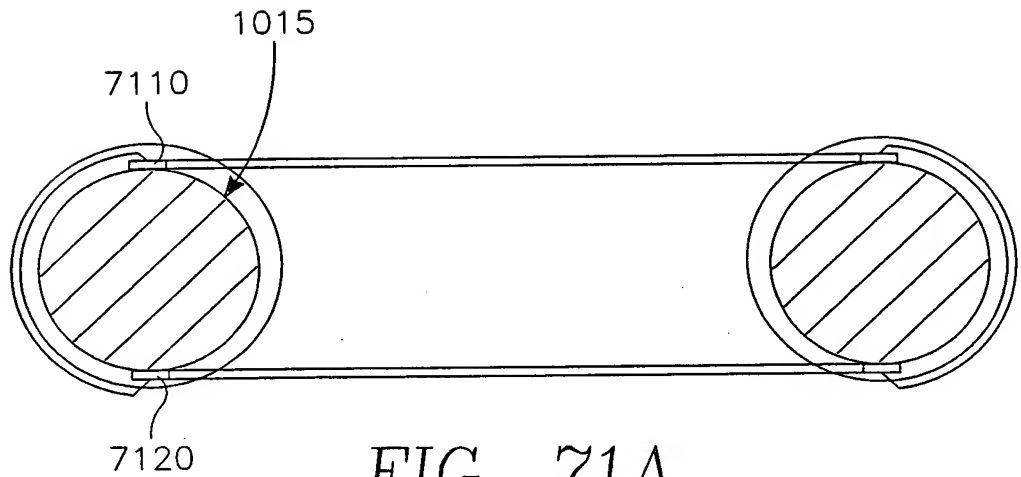


FIG. 69





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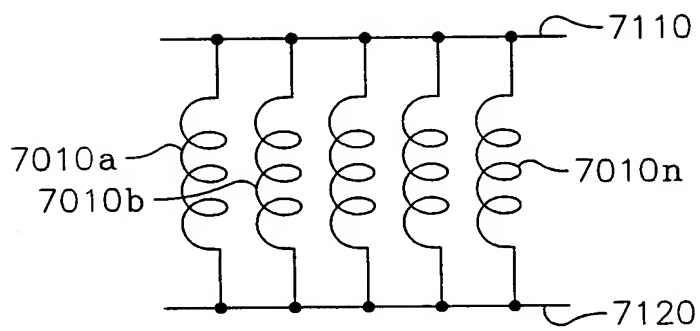


FIG. 72

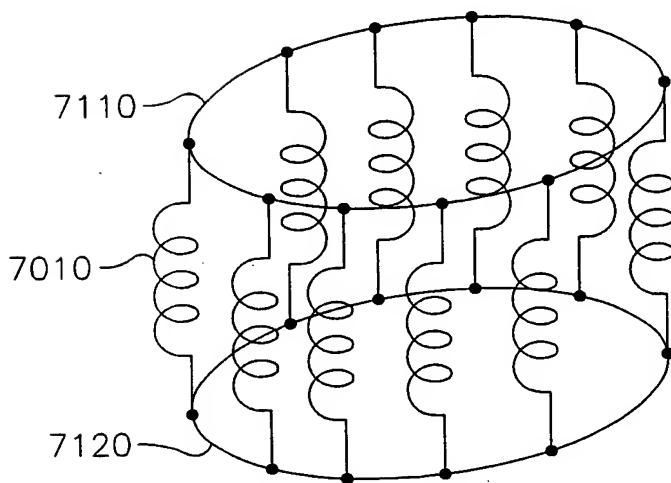


FIG. 73

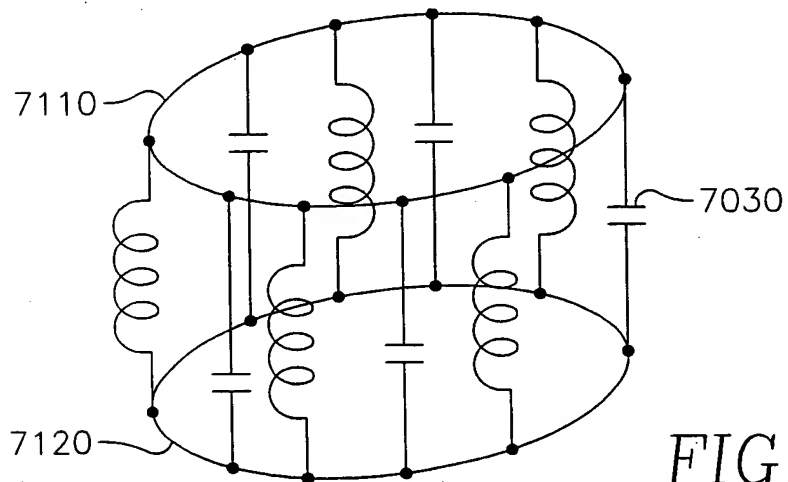


FIG. 74

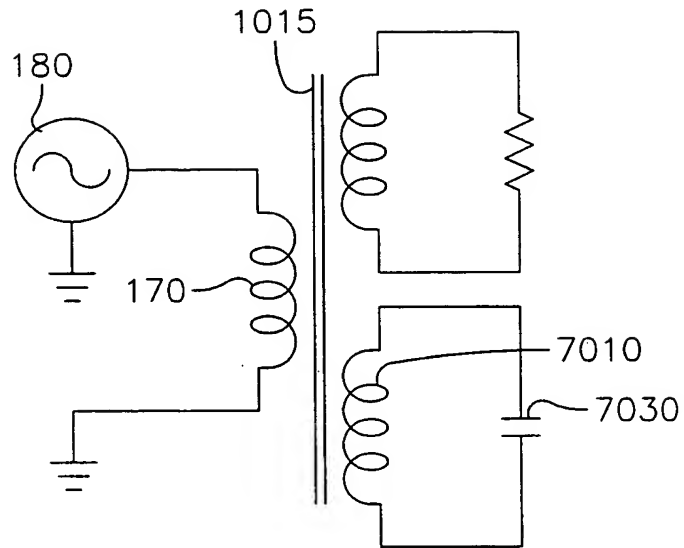


FIG. 75

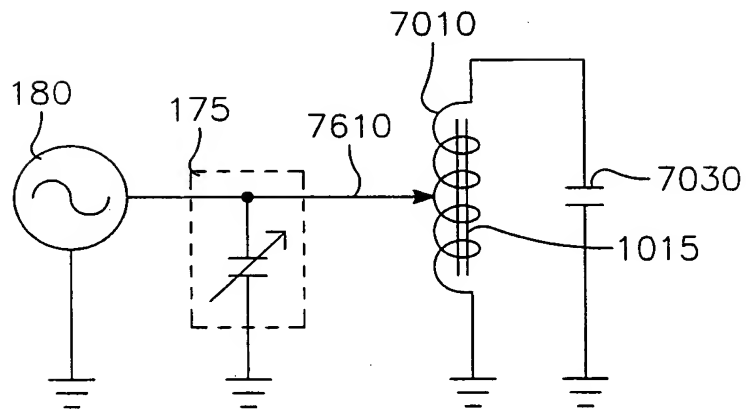


FIG. 76

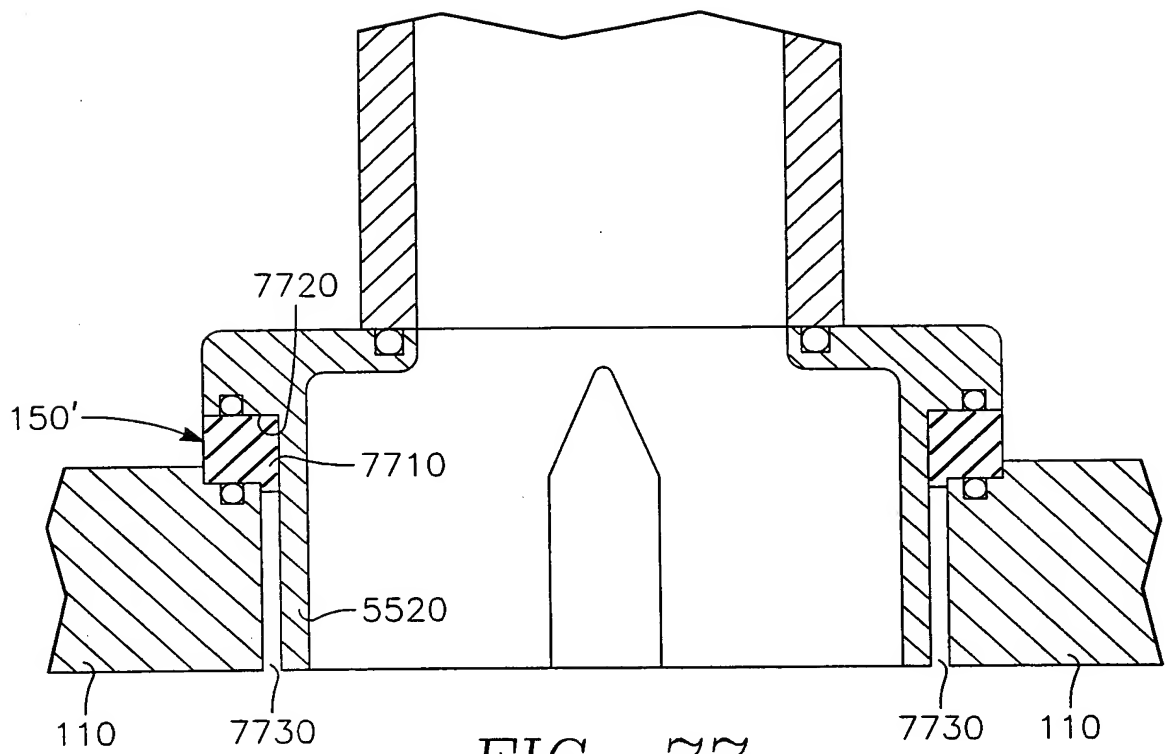


FIG. 77

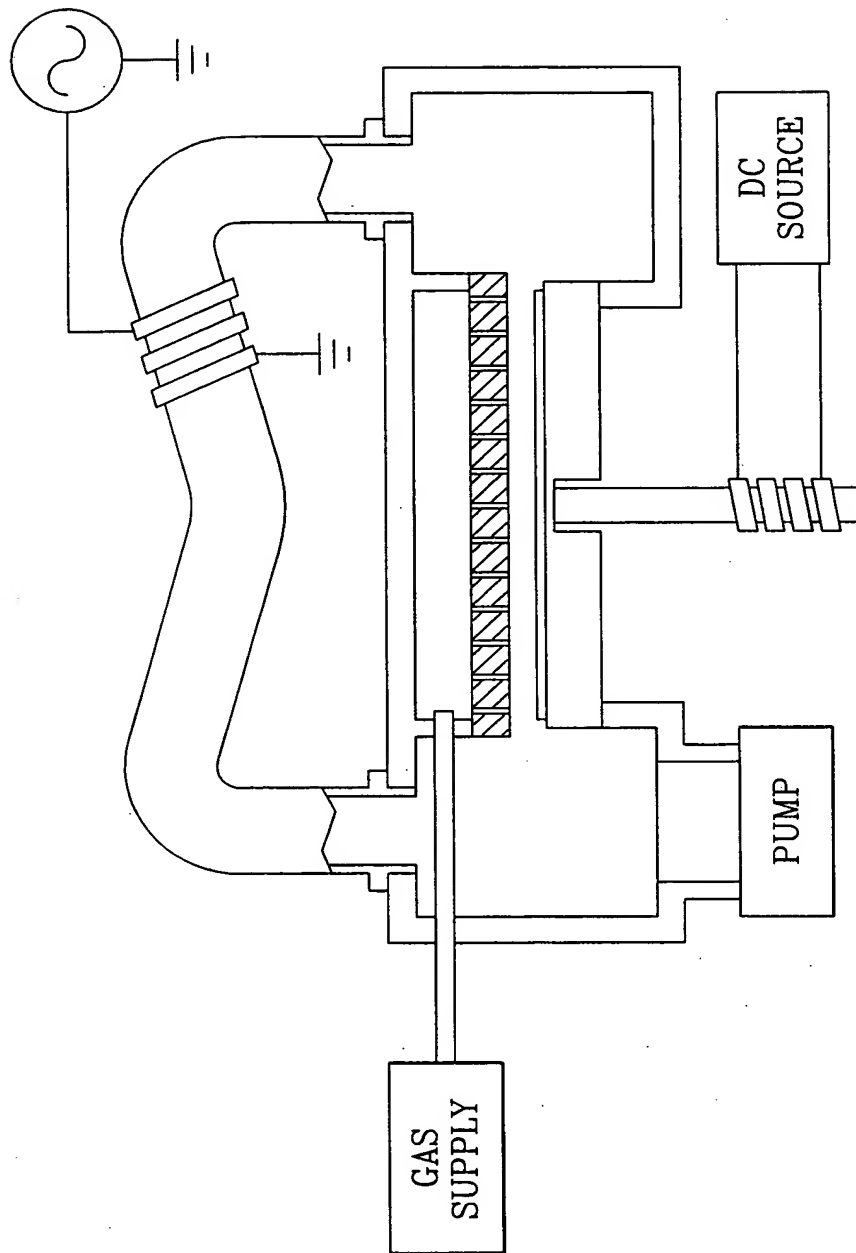


FIG. 78

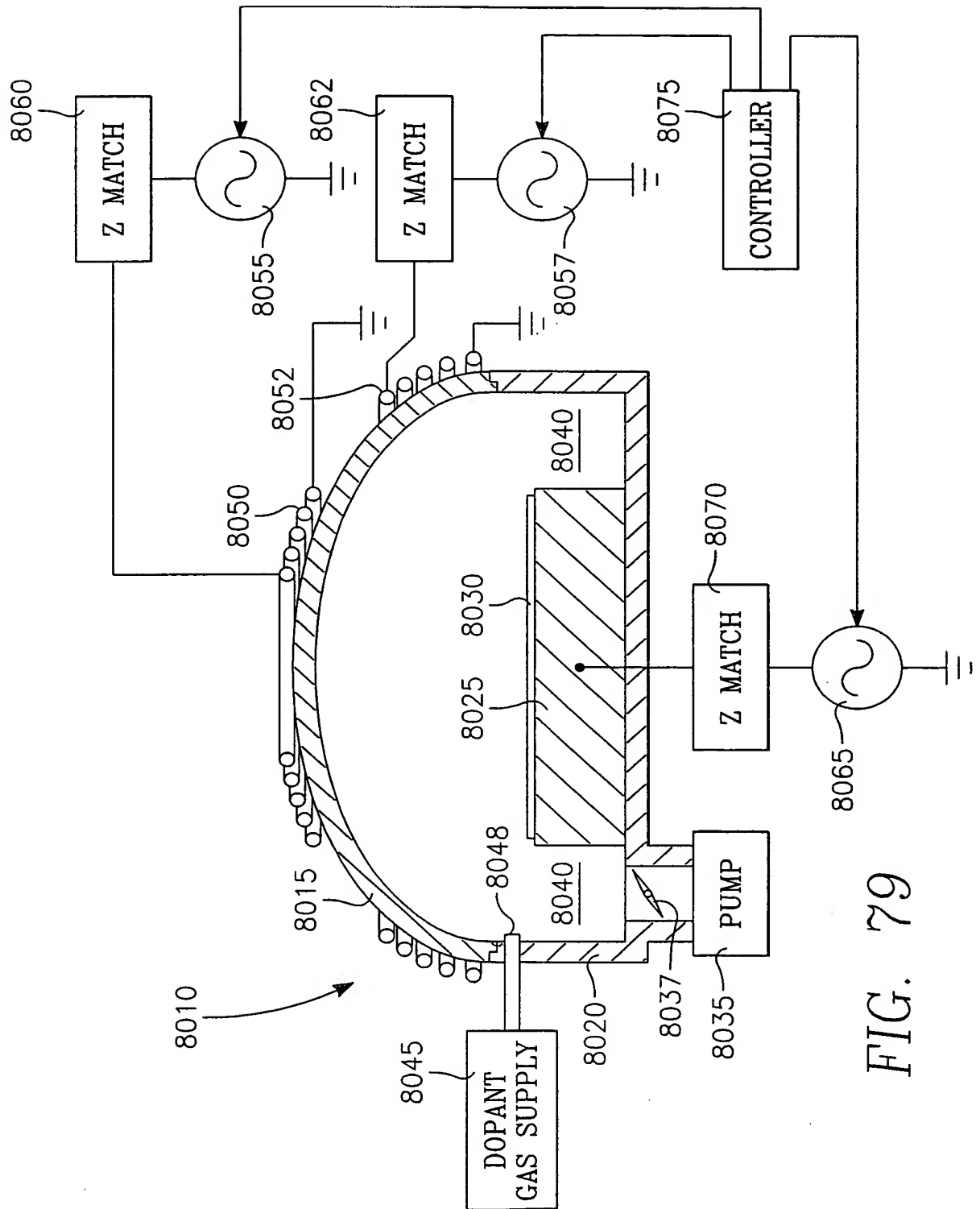


FIG. 79

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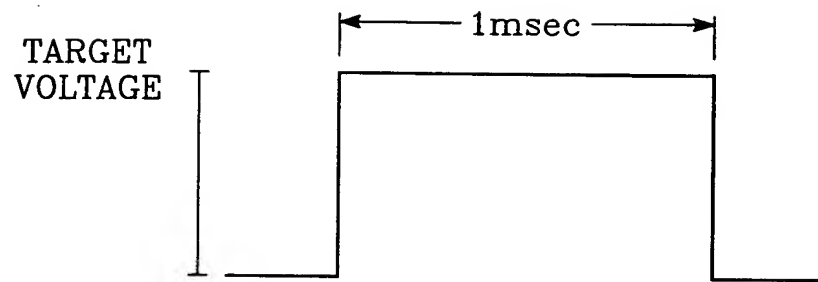


FIG. 80A

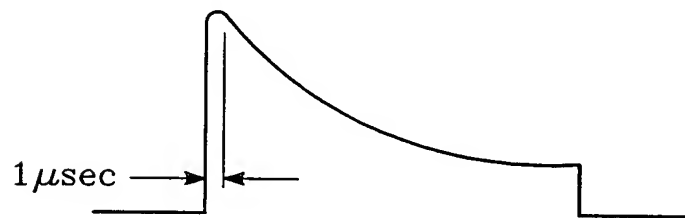


FIG. 80B

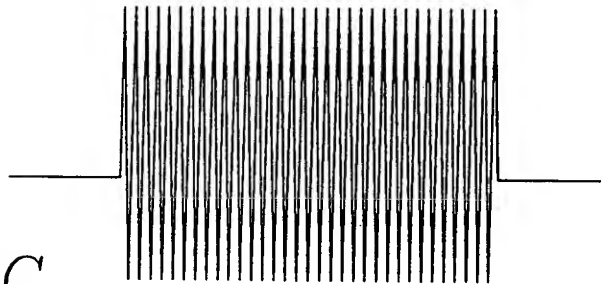
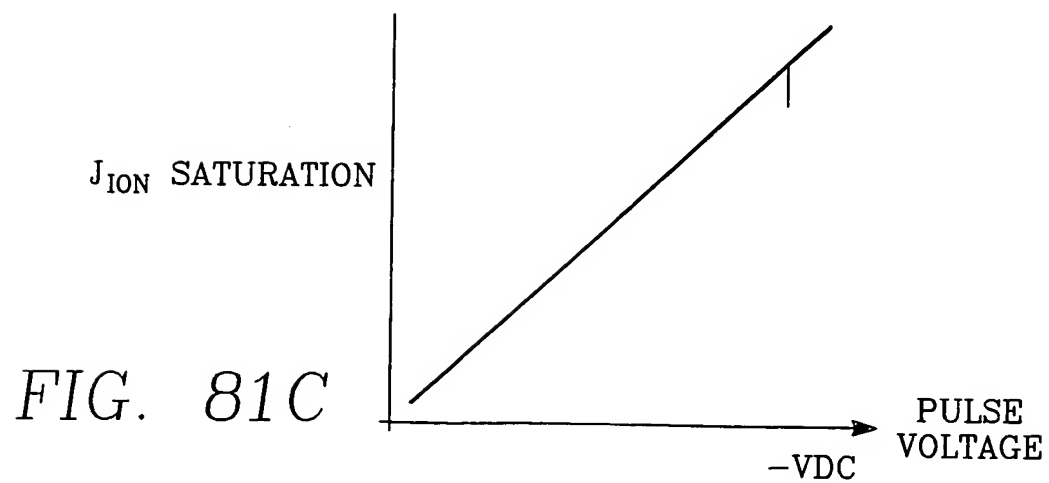
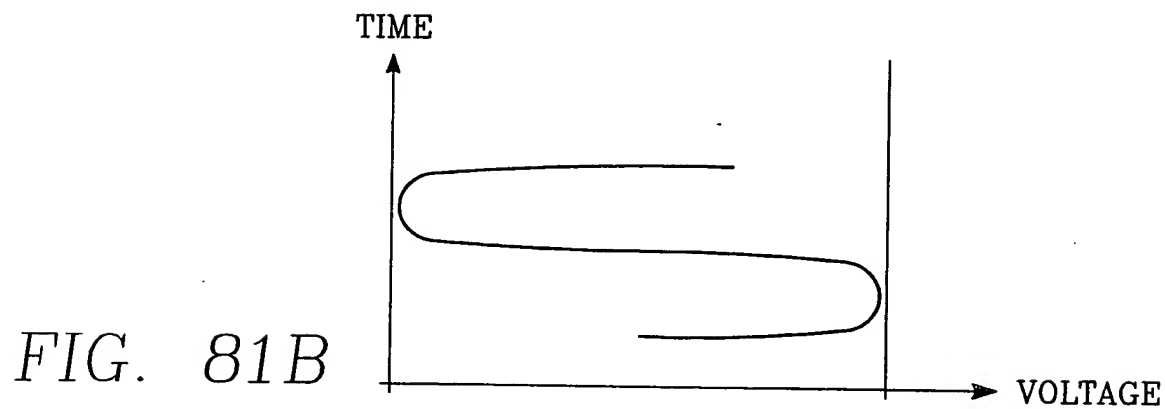
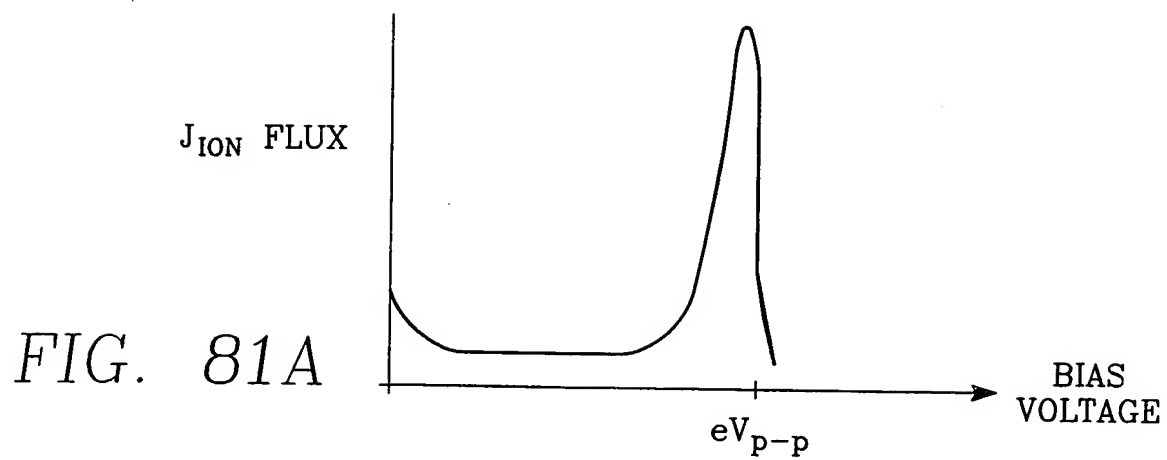


FIG. 80C

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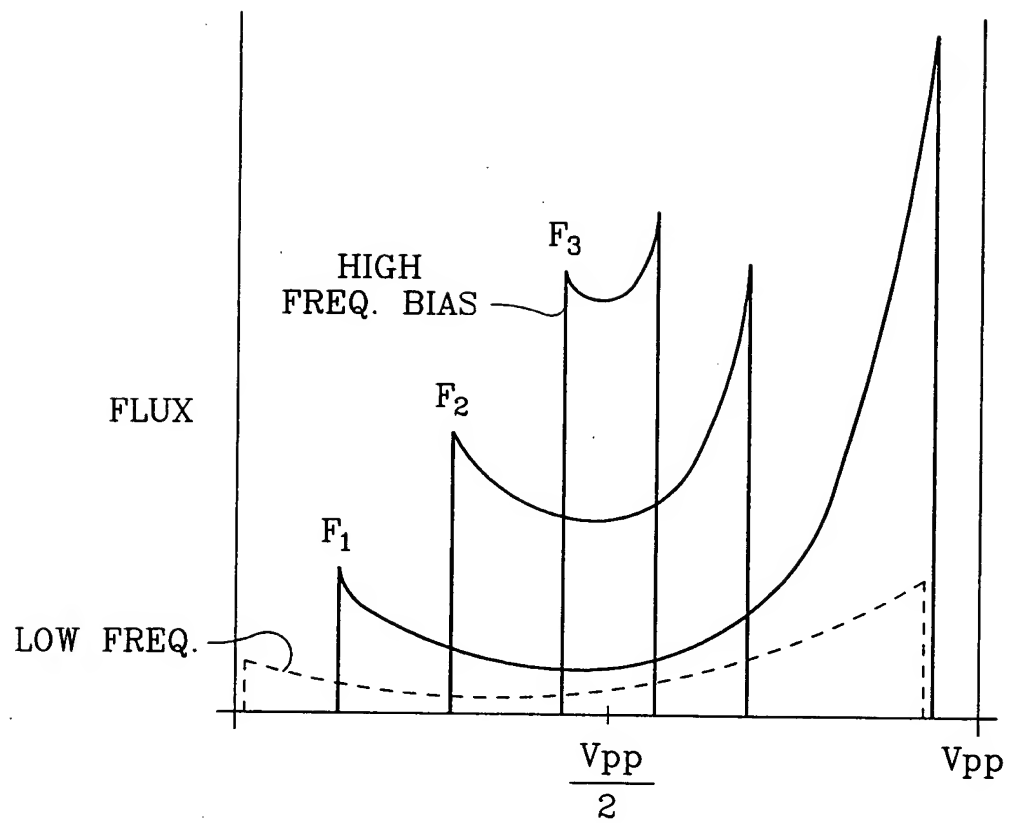


FIG. 81D

FIG. 82A  PUSH PULL

FIG. 82B  PUSH PULL


FIG. 82C  IN SYNC


FIG. 82D  IN SYNC


FIG. 82E  SYMMETRIC

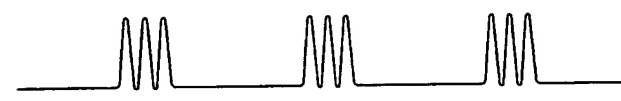
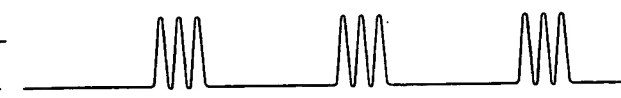
FIG. 82F  SYMMETRIC

FIG. 82G  NON-SYMMETRIC

FIG. 82H  NON-SYMMETRIC



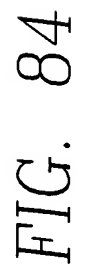


FIG. 84

FIG. 85

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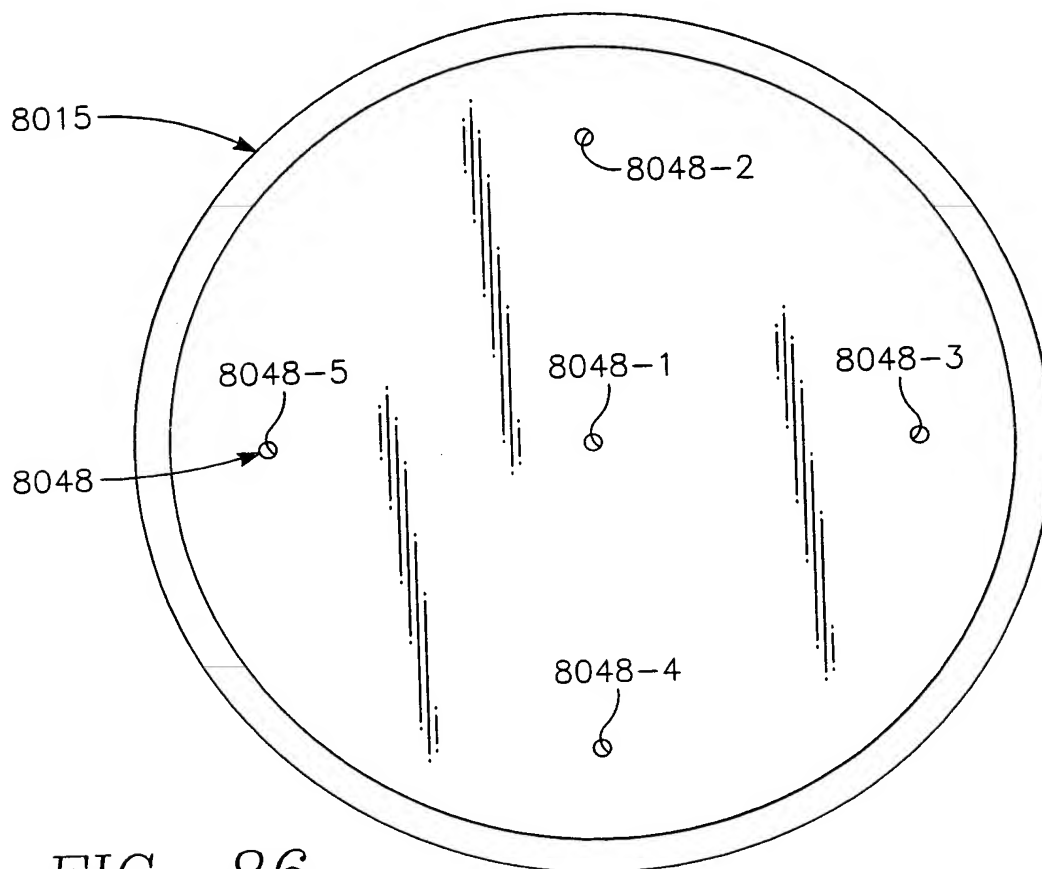


FIG. 86

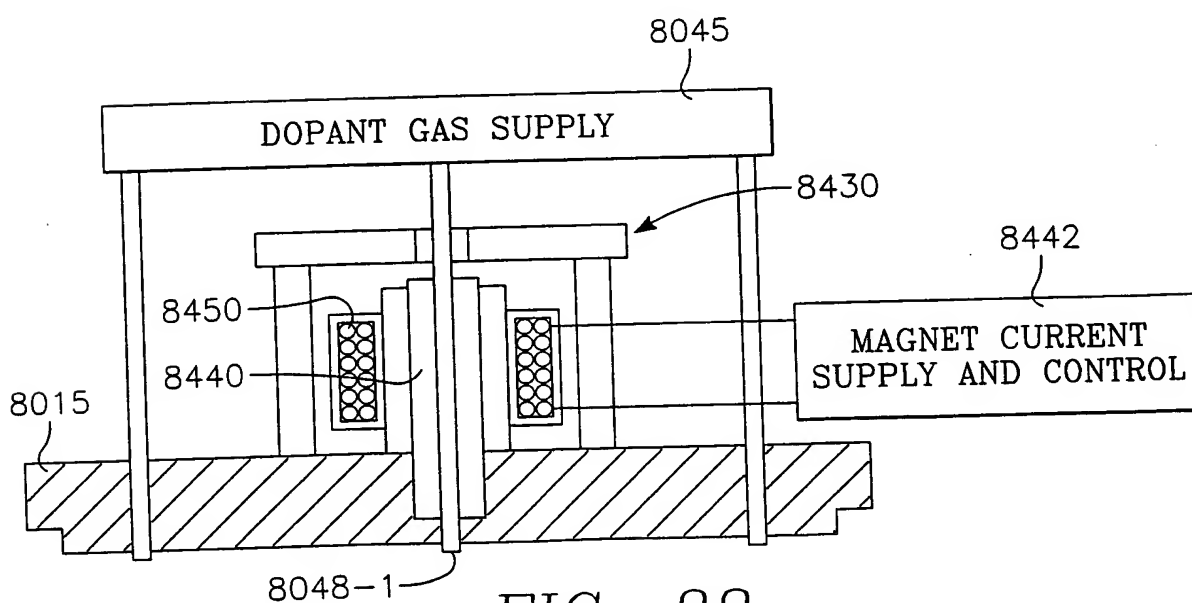


FIG. 88

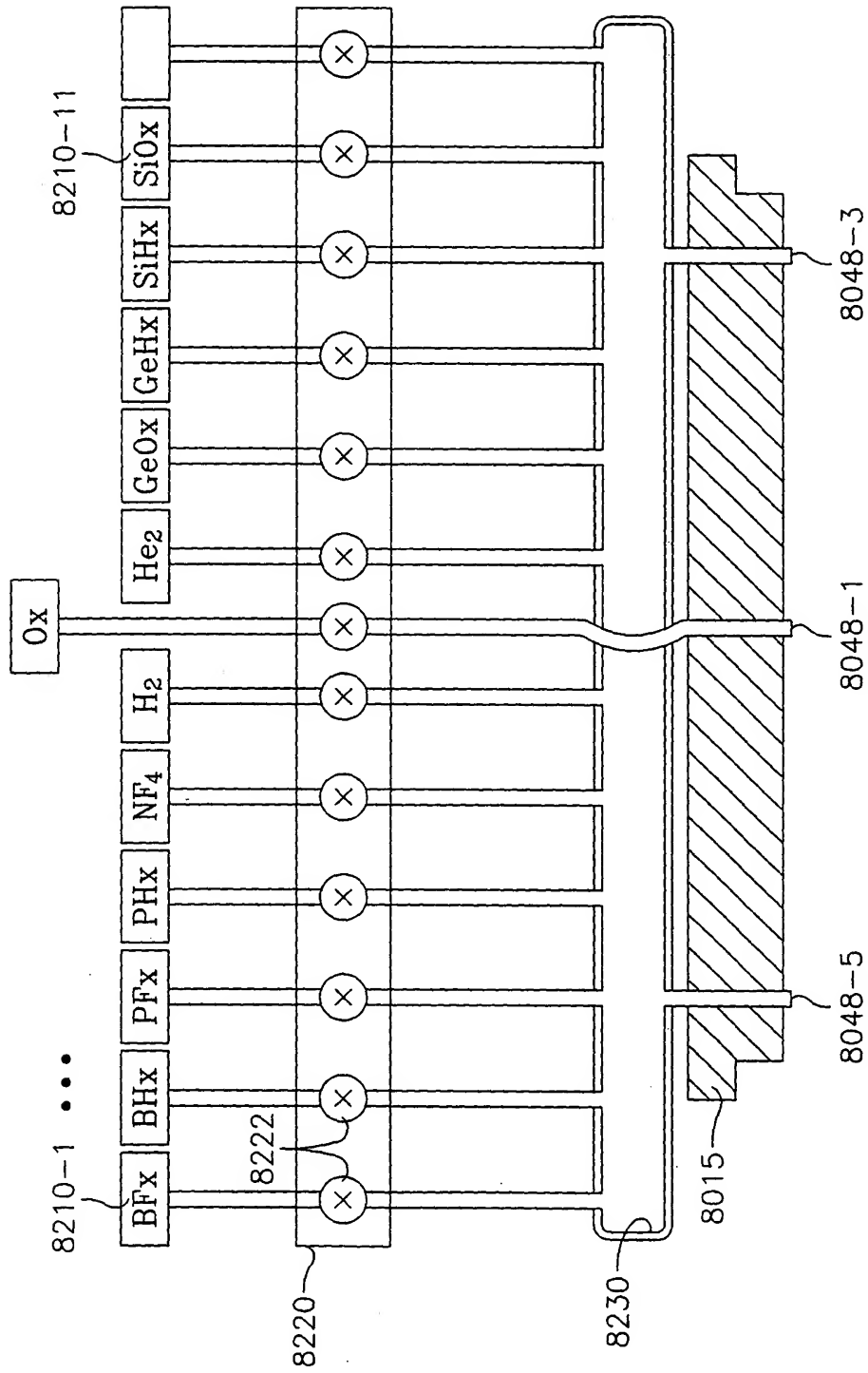


FIG. 87

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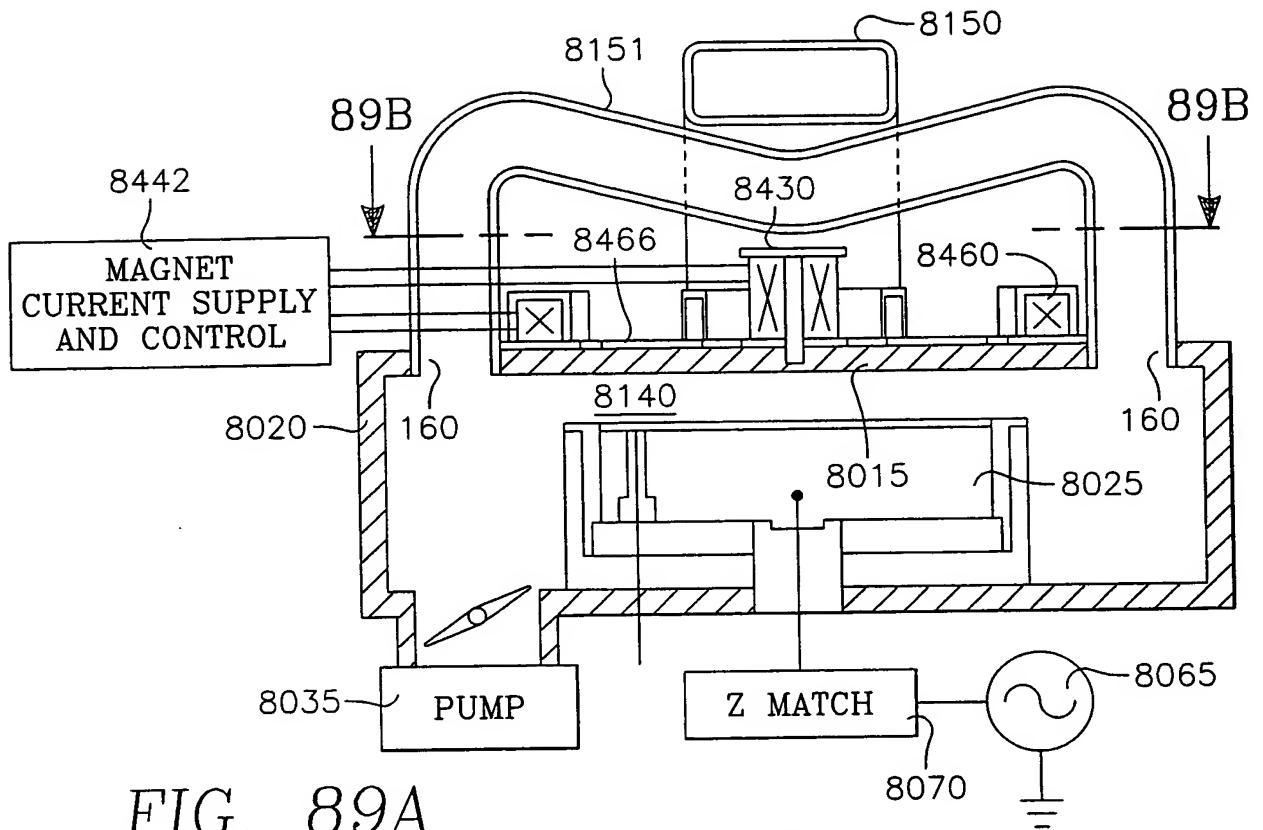


FIG. 89A

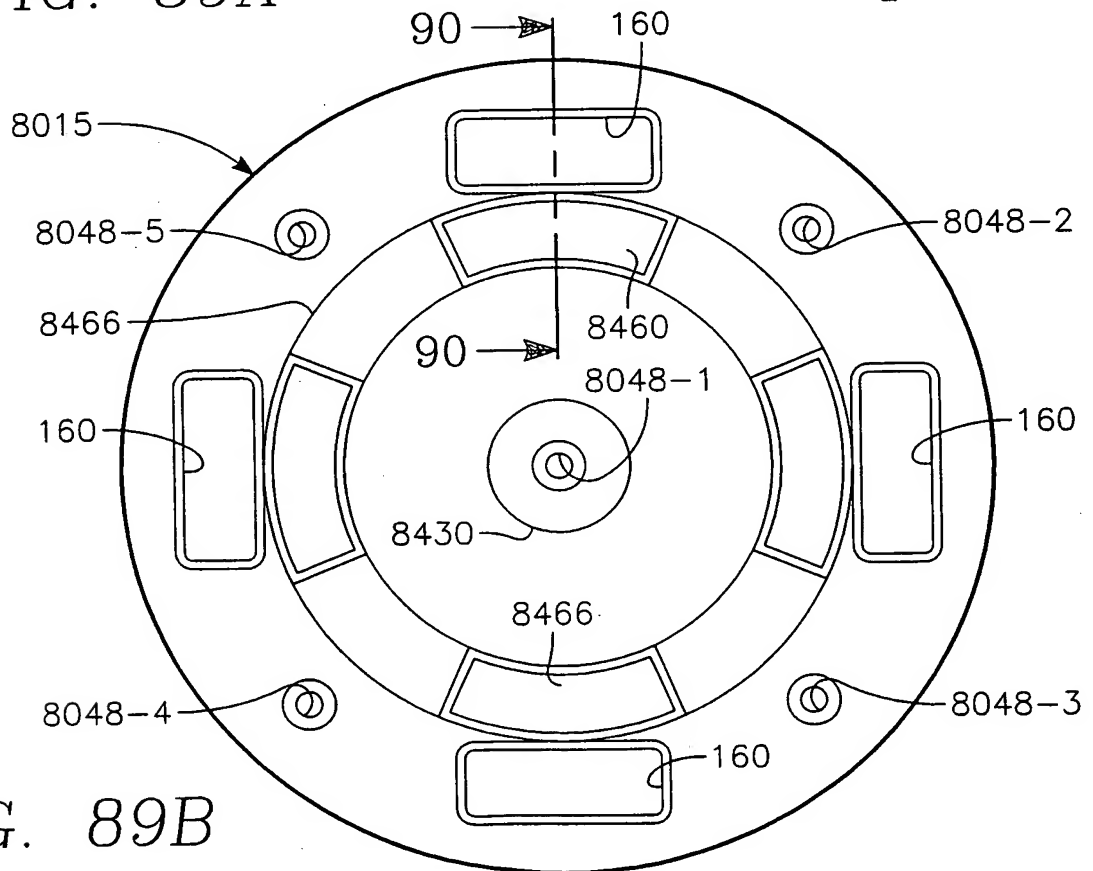


FIG. 89B

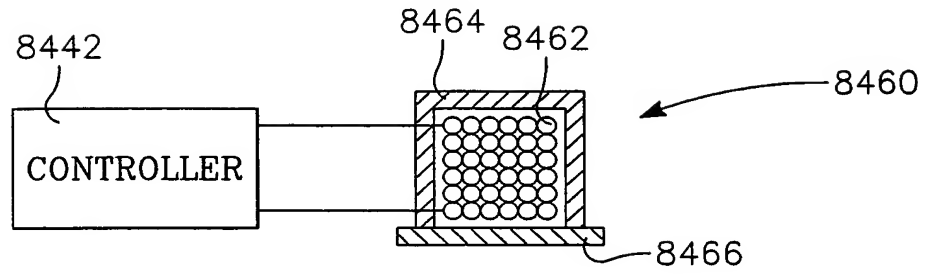


FIG. 90A

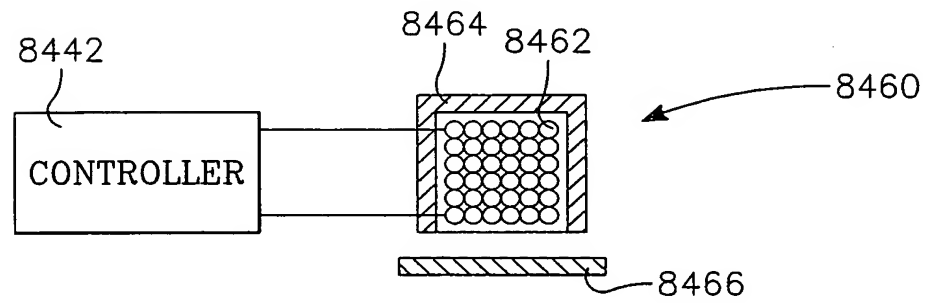


FIG. 90B

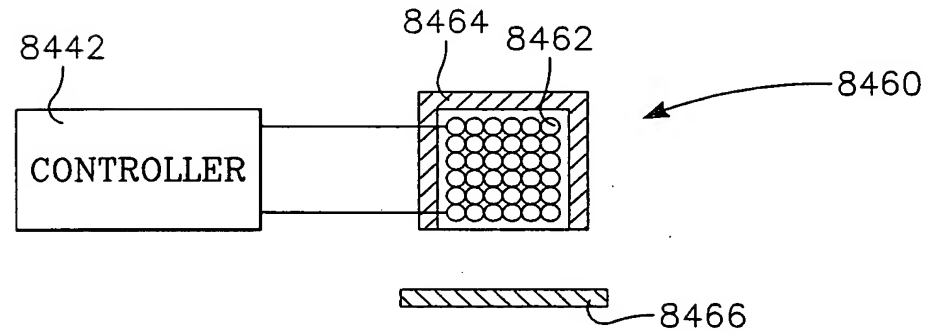


FIG. 90C

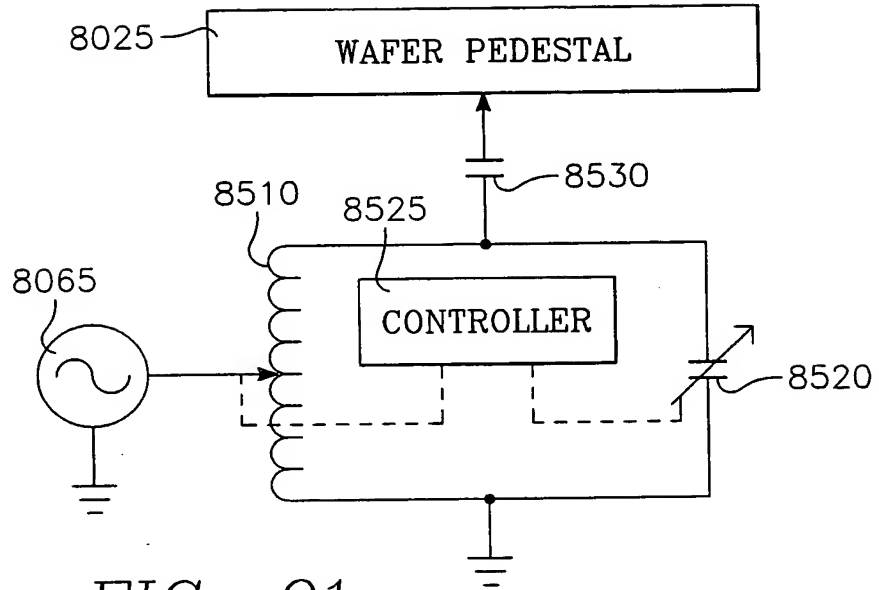


FIG. 91

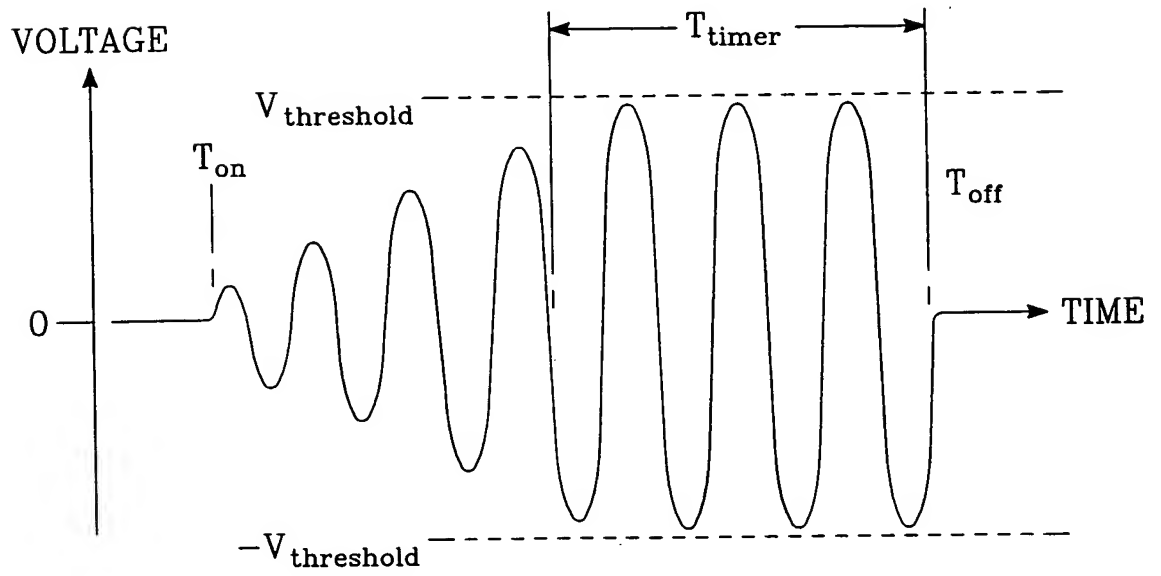


FIG. 92

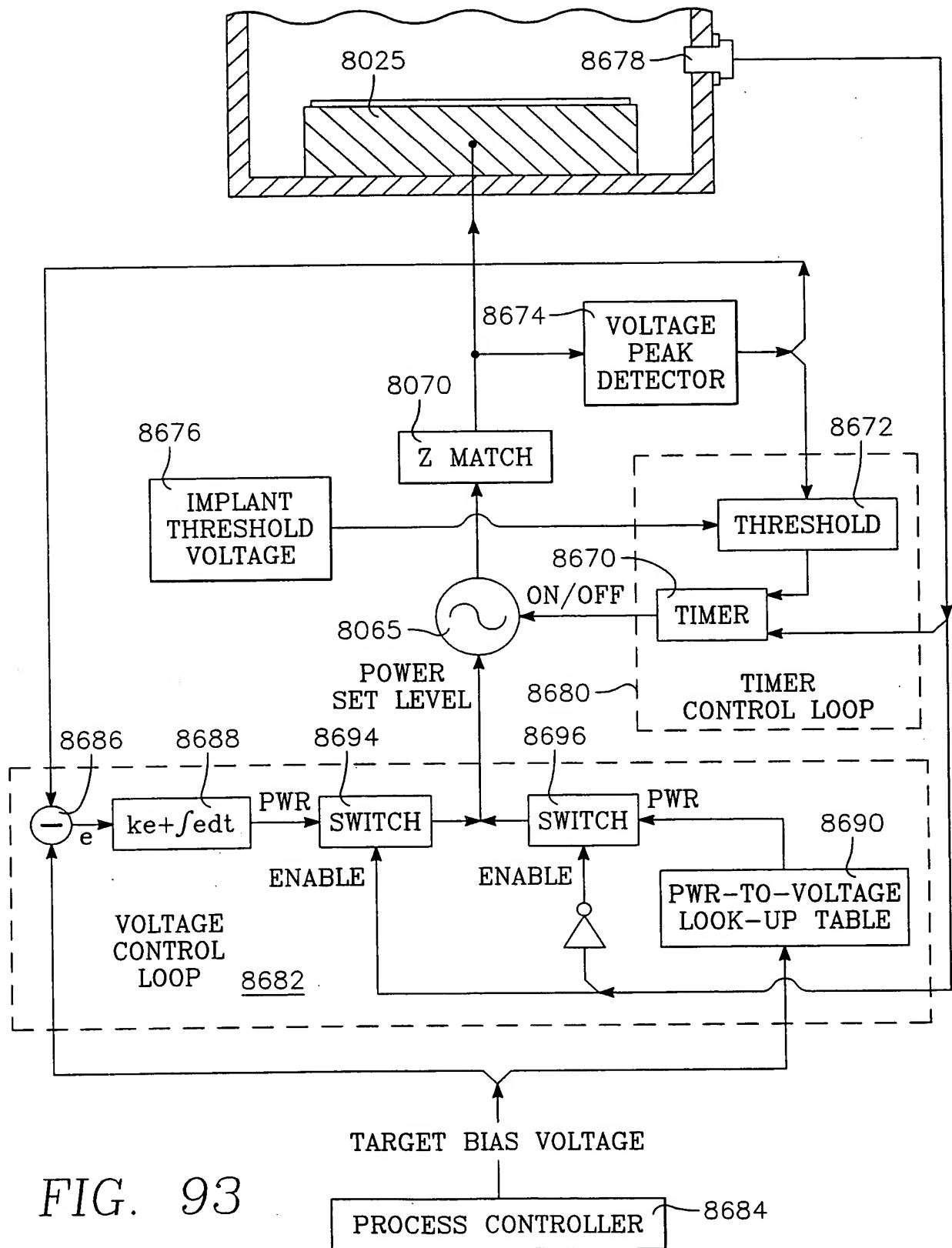


FIG. 93

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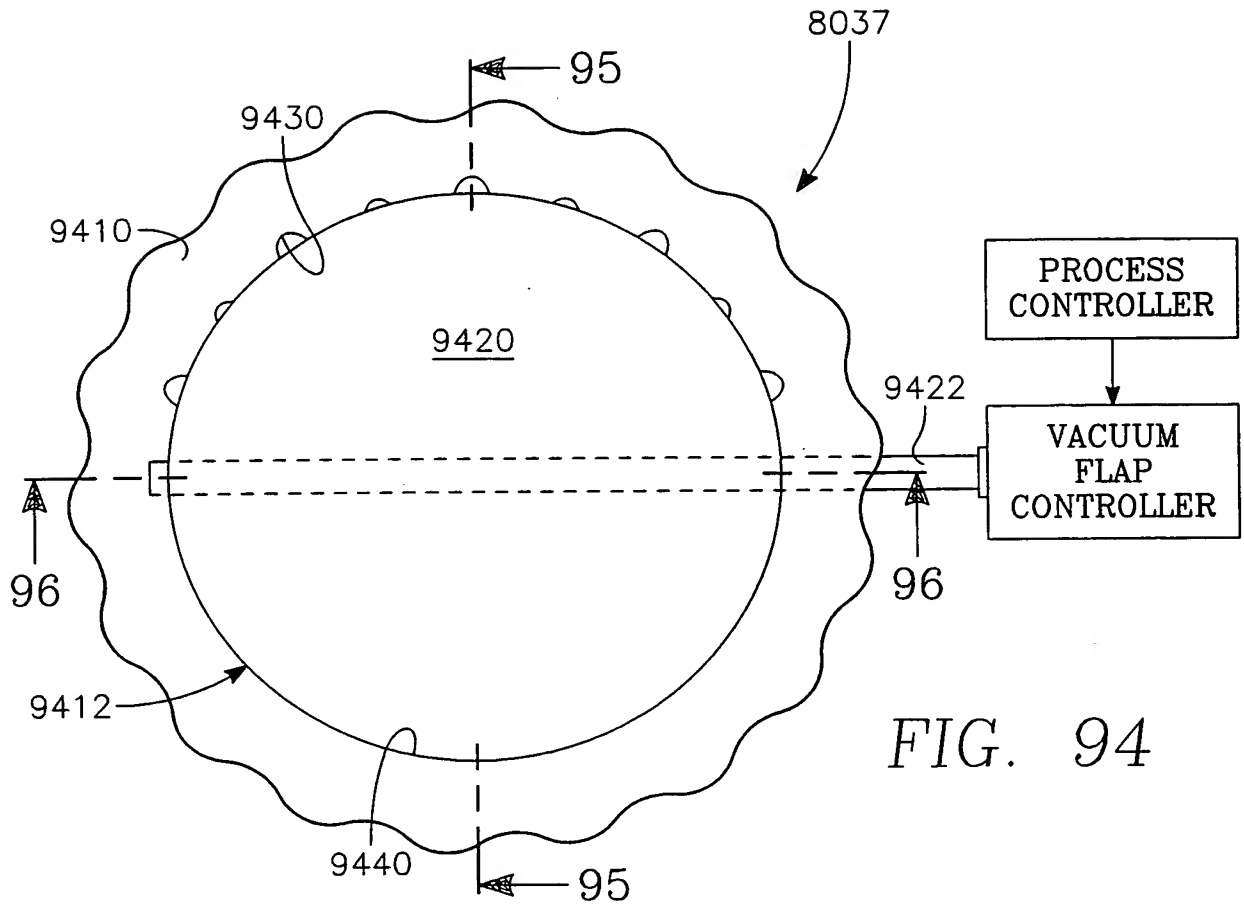


FIG. 94

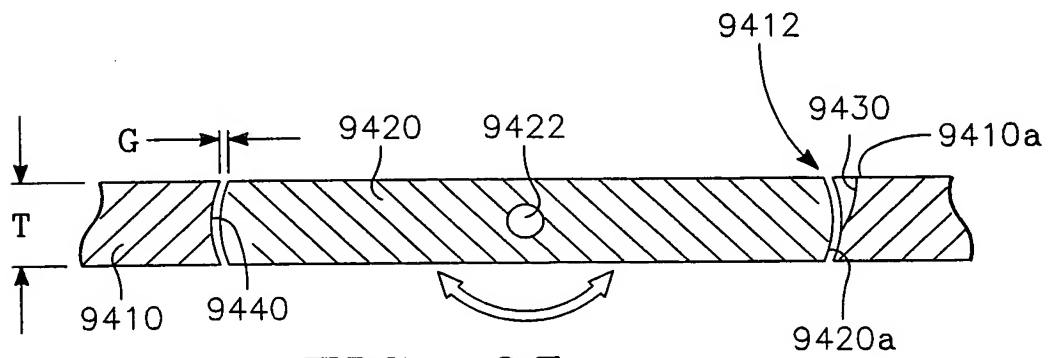


FIG. 95

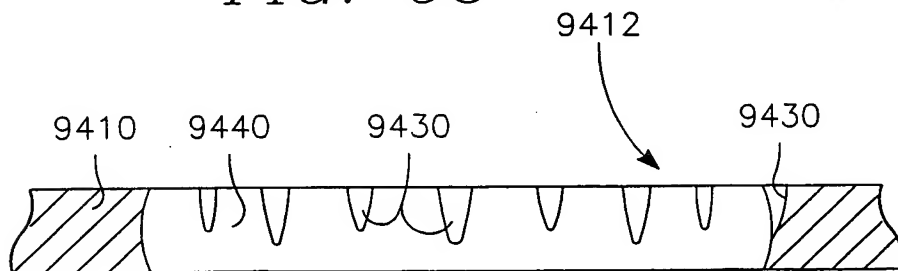


FIG. 96

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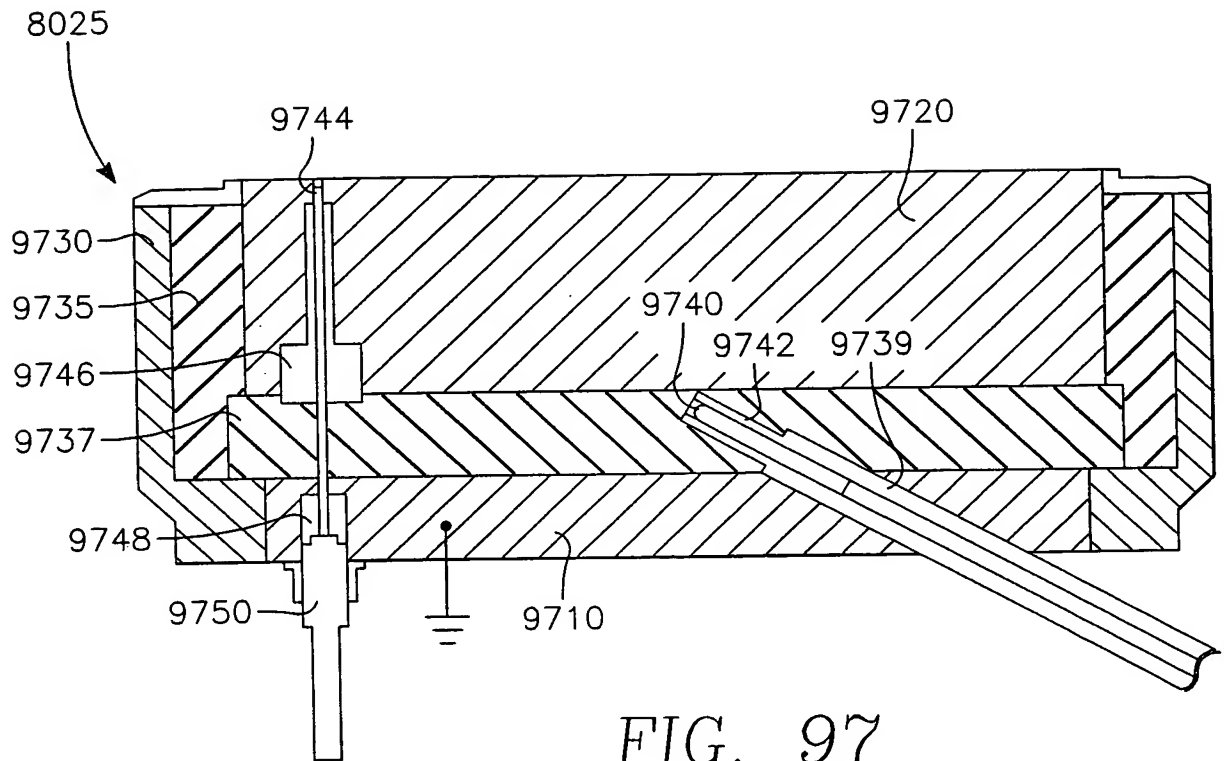


FIG. 97

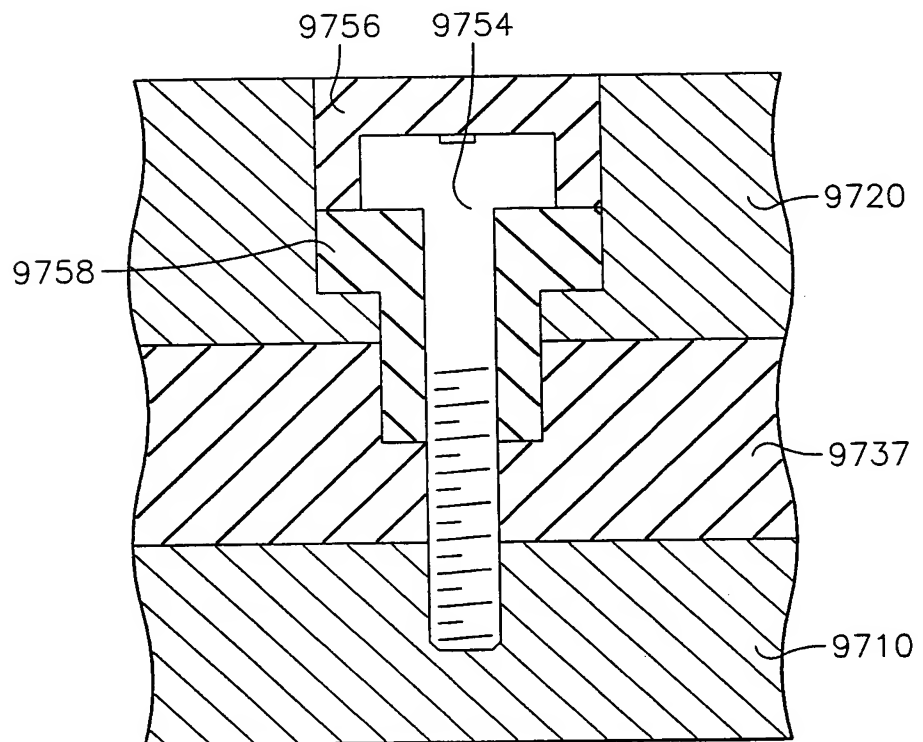


FIG. 98

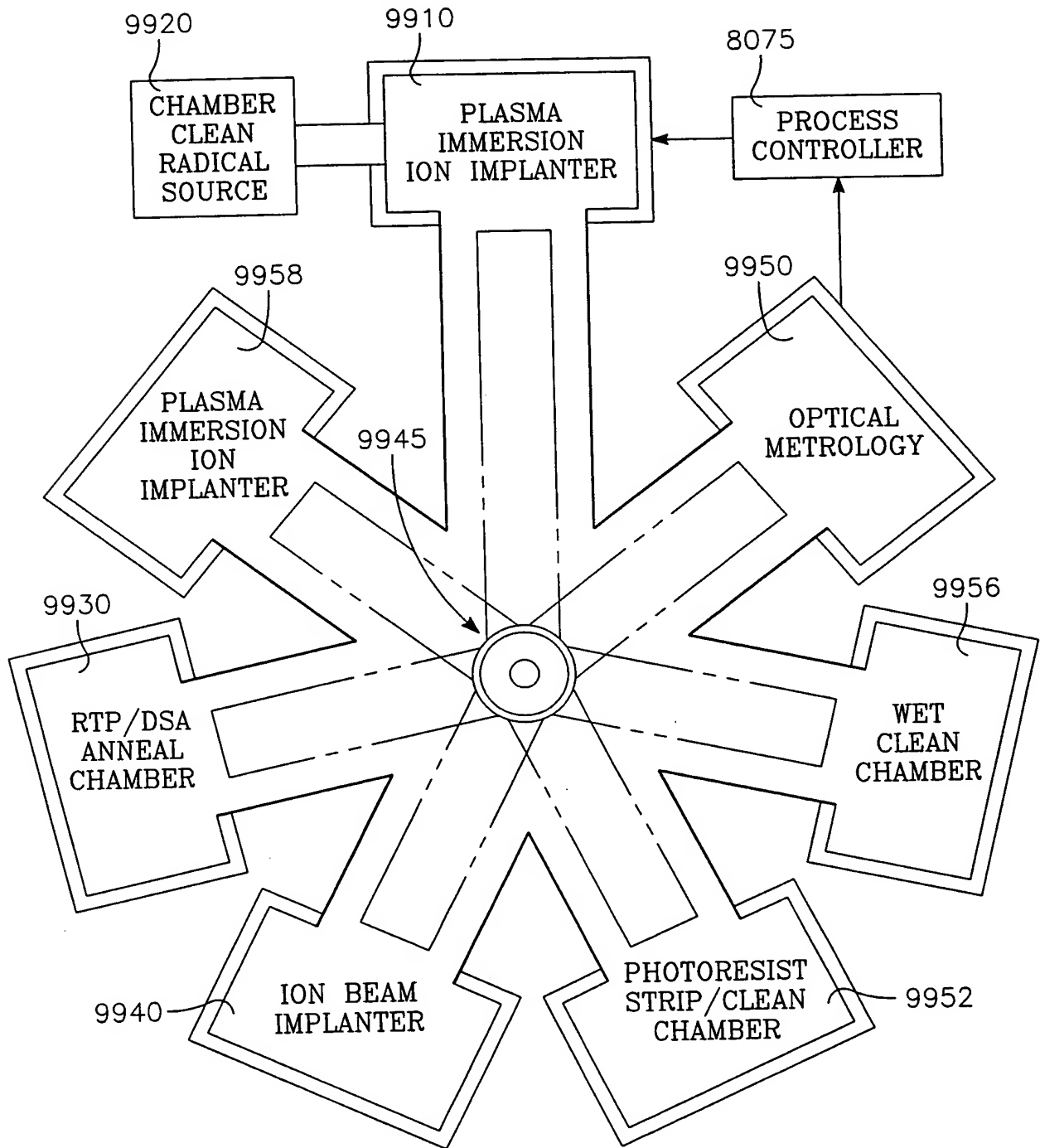


FIG. 99

ELECTRON
DENSITY η_e

FIG. 100

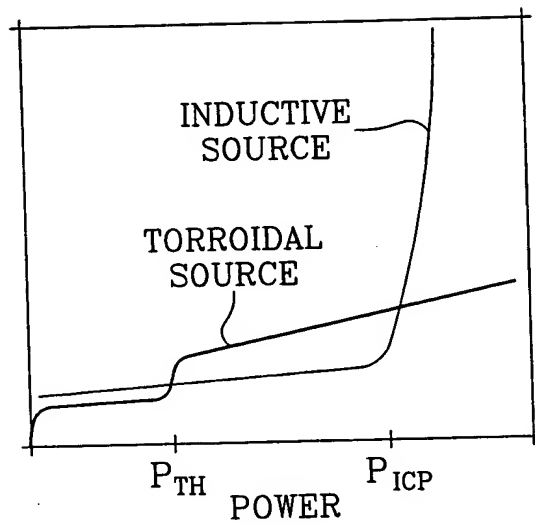
FREE
FLUORINE
DENSITY

FIG. 101

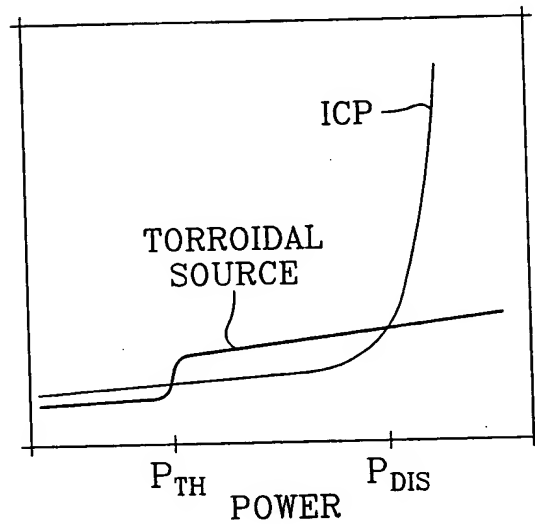
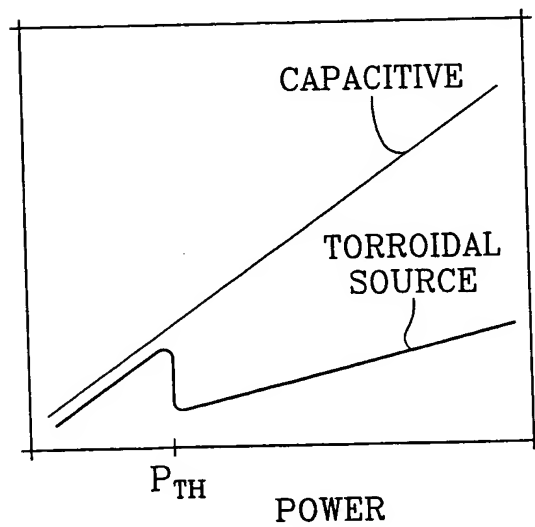
PLASMA
POTENTIAL $|V_p|$

FIG. 102



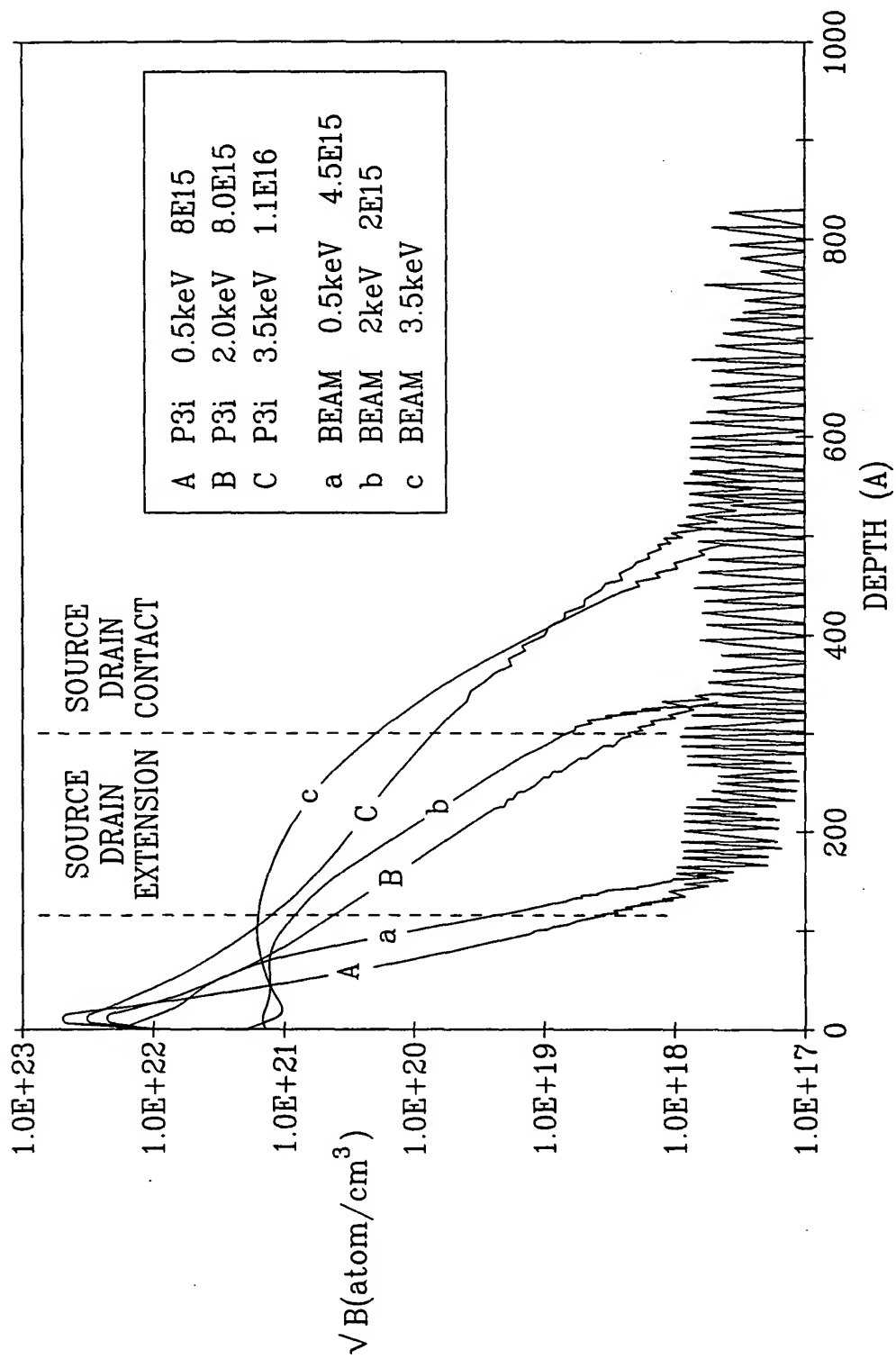


FIG. 103

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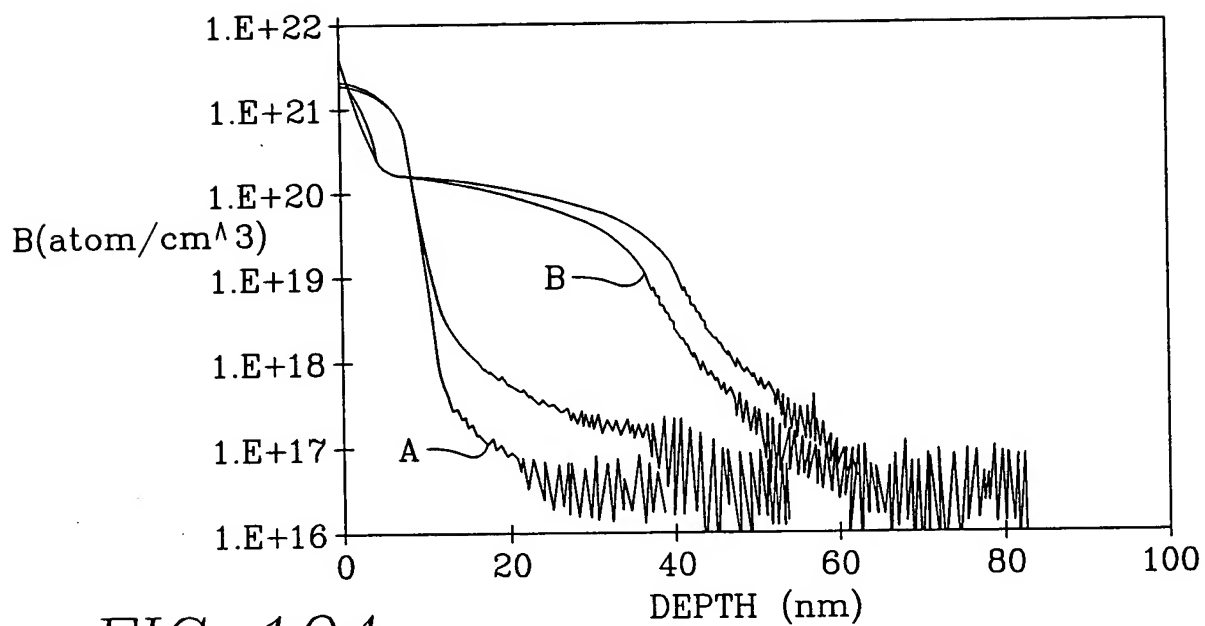


FIG 104

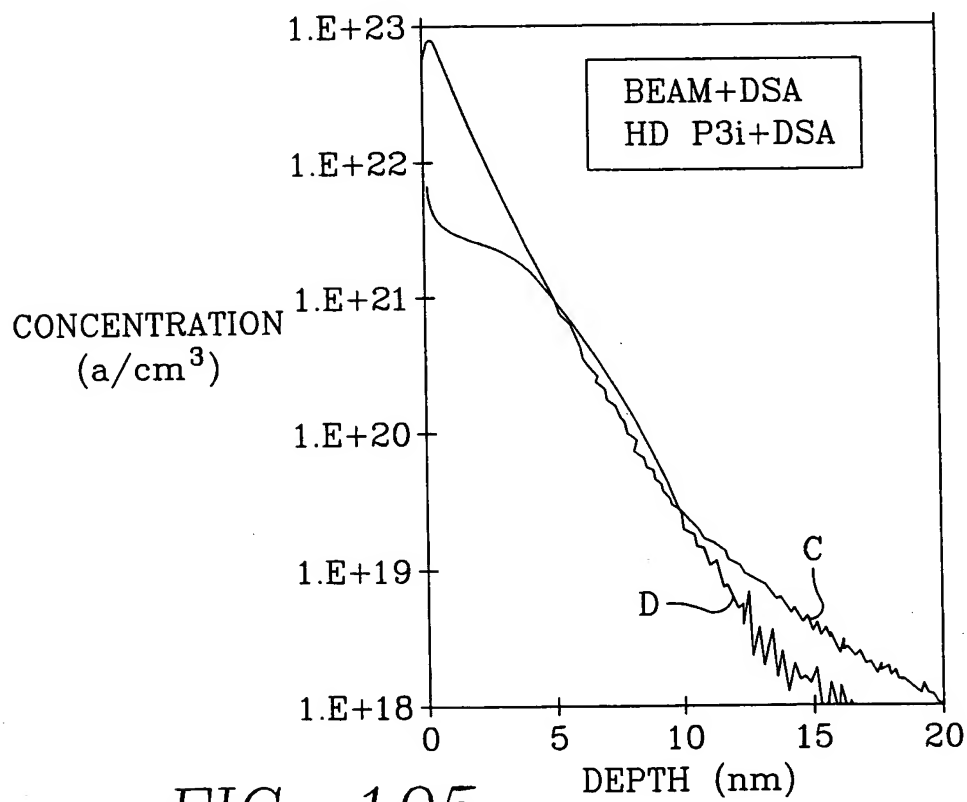


FIG. 105

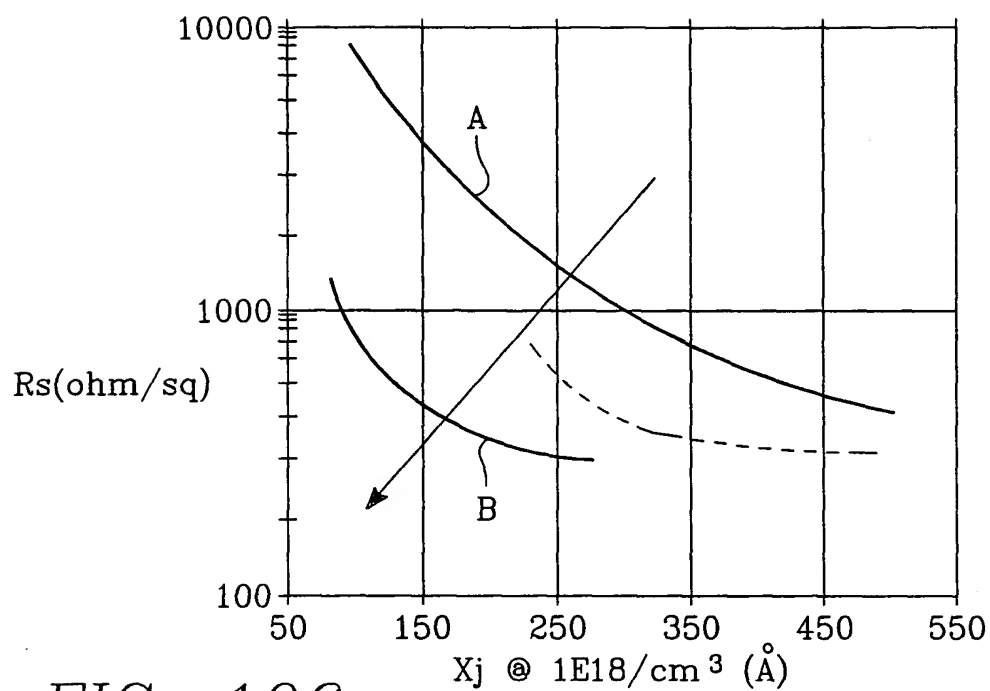


FIG. 106

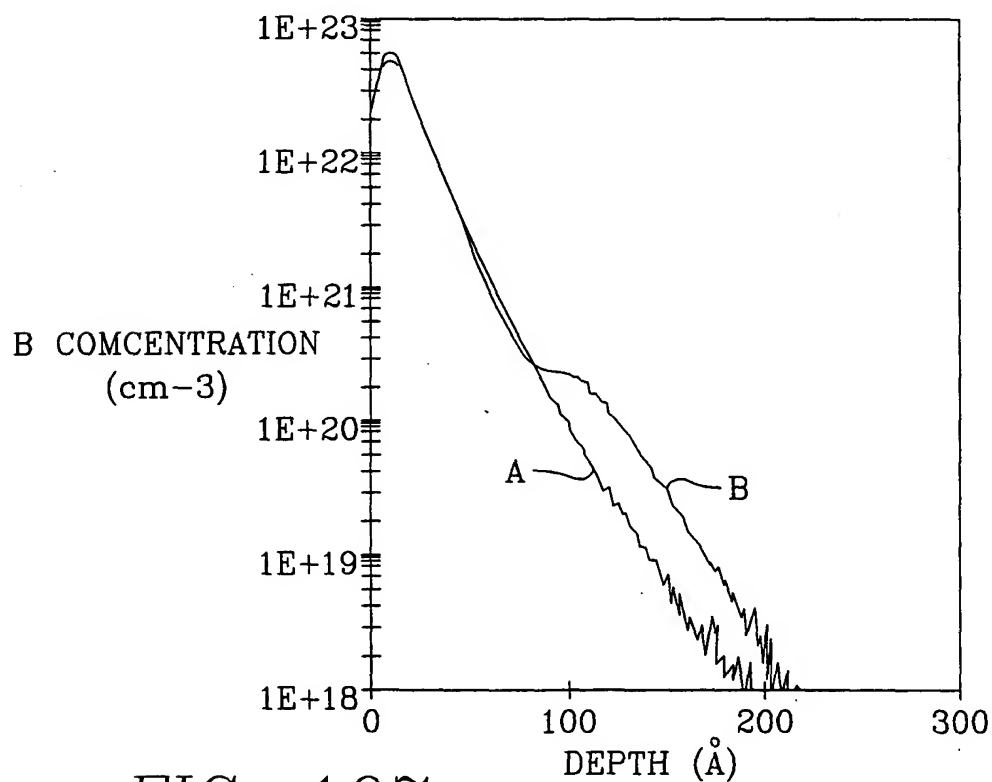


FIG. 107

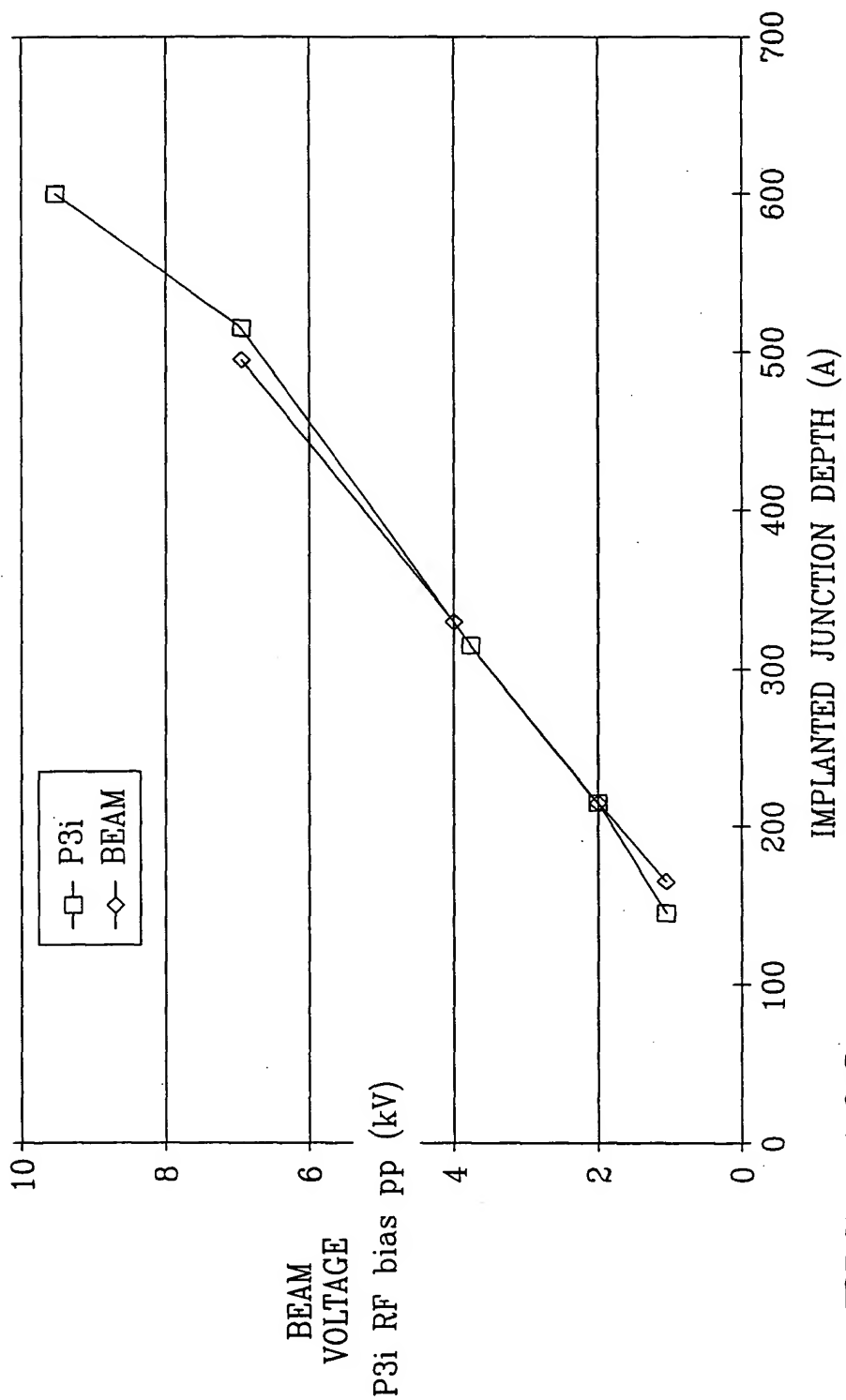


FIG. 108

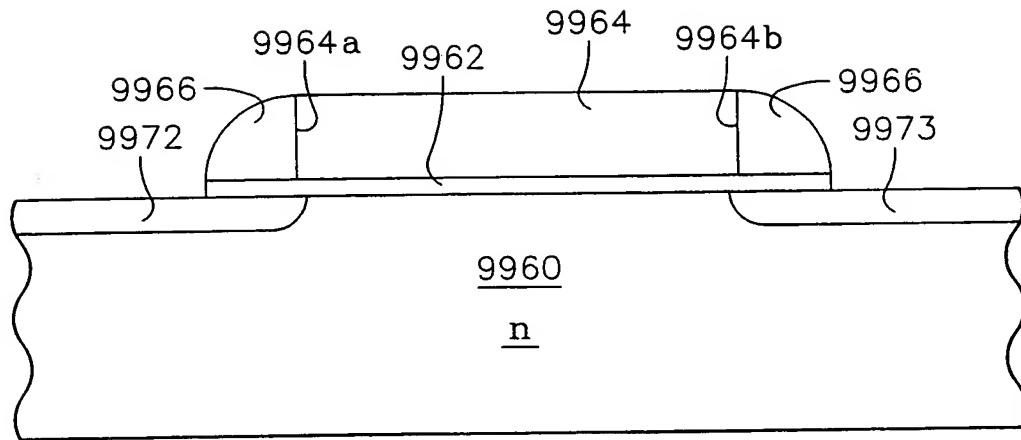


FIG. 109

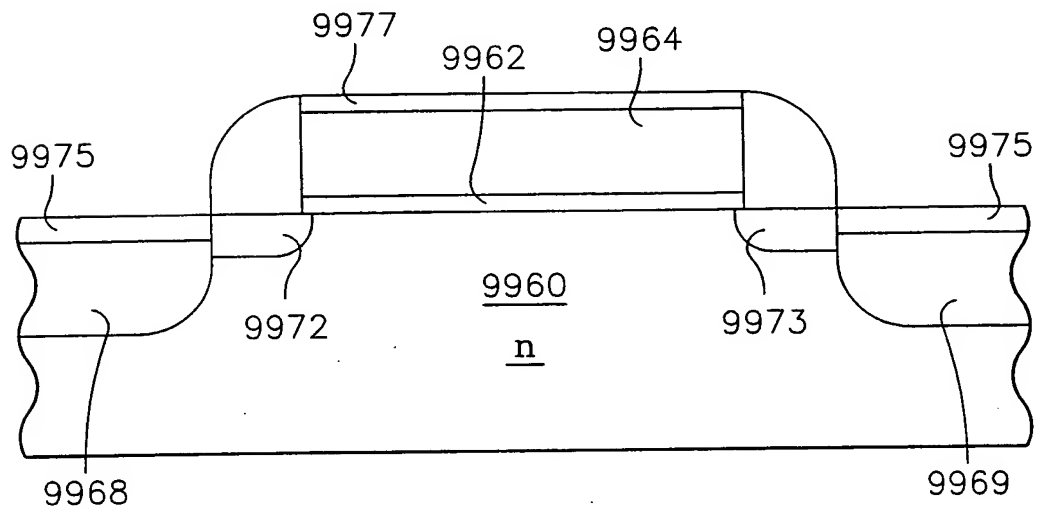


FIG. 110

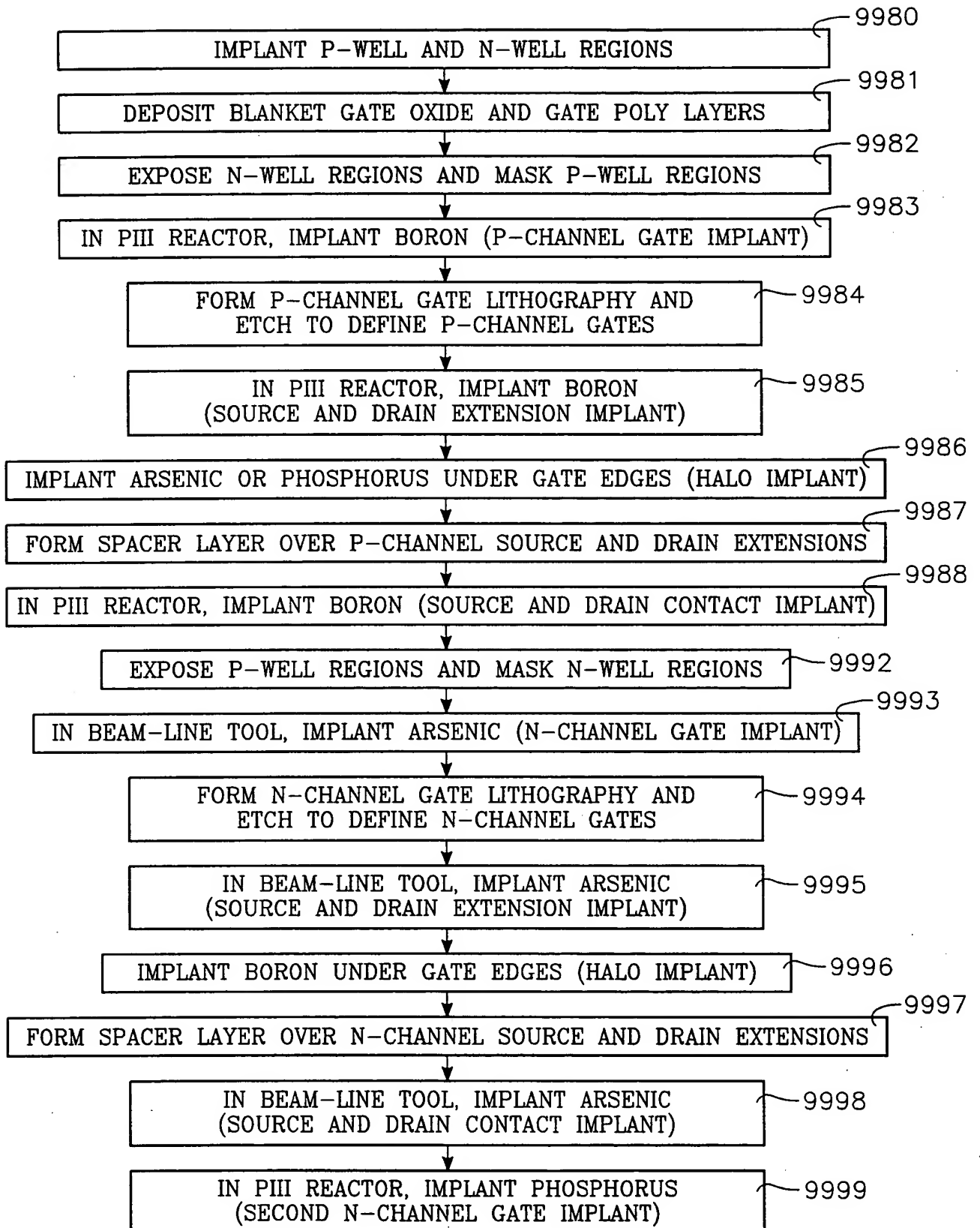


FIG. 111

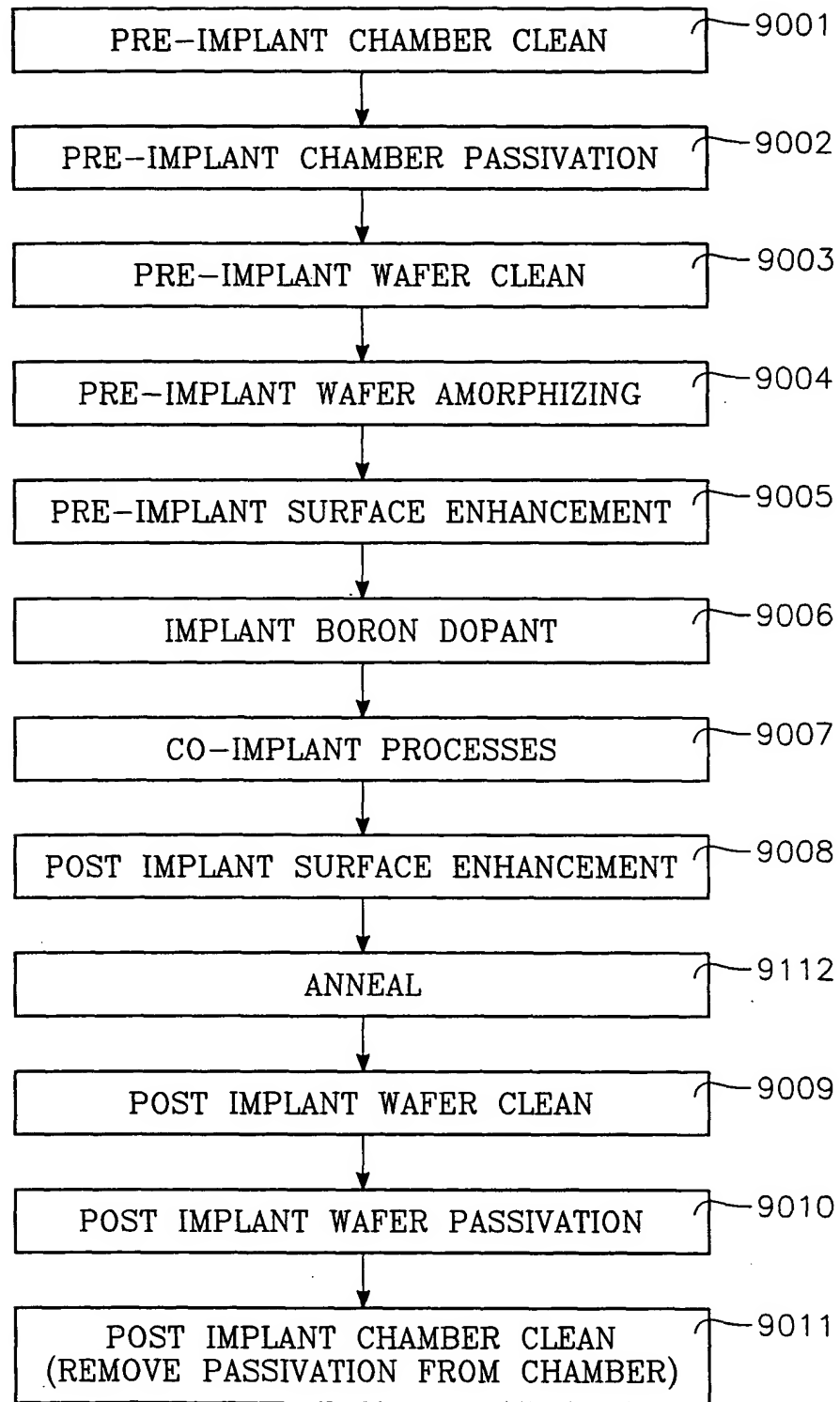


FIG. 112